INCH-POUND MIL 0-55310C <u>15 March 1994</u> SUPERSEDING MIL-0-55310B 10 May 1988

MILITARY SPECIFICATION

OSCILLATOR, CRYSTAL CONTROLLED,

GENERAL SPECIFICATION FOR

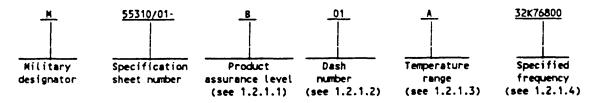
This specification is approved for use by all Departments and Agencies of the Department of Defense.

1. SCOPE

1.1 <u>Statement of scope</u>. This specification covers the general requirements and quality and reliability assurance requirements for bulkwave quartz crystal oscillators designed for frequency control or timekeeping in military electronic equipment. Statistical process control (SPC) techniques are required in the manufacturing process to minimize variation in production of crystal oscillators supplied to the requirements of this specification.

1.2 Classification.

1.2.1 <u>Hilitary Part or Identifying Number (PIN)</u>. The military PIN consists of the letter MMH, the basic number of the specification sheet, the dash number, and alphanumeric designators. An example of a PIN is as follows:



1.2.1.1 <u>Product assurance level</u>. The product assurance level is identified by a single letter B or S designating the device class.

1.2.1.2 Dash number. The dash number uniquely identifies the crystal oscillator.

1.2.1.3 Temperature range. Crystal oscillators shall be of the following temperature ranges:

A - -55°C to +125°C (except class S)

- 8 -55°C to +105°C
- C -20°C to +70°C
- D -55°C to +85°C
- E -40°C to +85°C
- J Other (see 3.1)

Beneficial comments (recommendations, additions, deletions) and any pertinent data which may be of use in improving this document should be addressed to: U.S. Army Research Laboratory, ATTN: AMSRL-EP-RD Fort Monmouth, NJ 07703-5601, by using the Standardization Document Improvement Proposal (DD Form 1426) appearing at the end of this document or by letter.

AMSC N/A

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1.2.1.4 <u>Specified nominal frequency</u>. The specified nominal frequency expressed in hertz is identified by a fixed field of eight characters consisting of seven digits and a letter (H, K, or M) representing, simultaneously, the decimal point and the appropriate multiplier as follows:

- a. Greater than or equal to .01 hertz and less than 1,000 hertz, the letter "H" is used to represent the decimal point and multiplier.
- b. Greater than or equal to 1,000 hertz, but less than 1 megahertz, the letter "K" is used to represent the decimal point and multiplier.
- c. Greater than or equal to 1 megahertz, the letter "M" is used to represent the decimal point and multiplier.

All digits preceding and following the letter (H, K, or M) of the group represent significant figures.

The following are examples of using the eight characters in constructing the specified frequency.

Designation

Frequency

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H0100000 to H9999999	.01 to .9999999 hertz, inclusive
1H000000 to 9H999999	1.0 to 9.999999 hertz, inclusive
10H00000 to 99H99999	10 to 99.999999 hertz, inclusive
100H0000 to 999H9999	100 to 999.9999 hertz, inclusive
1K000000 to 9K999999	1 to 9.999999 kilohertz, inclusive
10K00000 to 99K99999	10 to 99.99999 kilohertz, inclusive
100K0000 to 999K9999	100 to 999.9999 kilohertz, inclusive
1M000000 to 9M999999	1 to 9.999999 megahertz, inclusive
1000000 to 99099999	10 to 99.99999 megahertz, inclusive
100N0000 to 999M9999	100 to 999.9999 megahertz, inclusive

1.2.2 Types. The oscillators types are identified by a single number as follows:

Type 1 - Crystal Oscillators (XO) (see 6.3.1).

Type 2 - Voltage Controlled Crystal Oscillators (VCXO) (see 6.3.2).

- Type 3 Temperature Compensated Crystal Oscillators (TCXO) (see 6.3.3).
- Type 4 Oven Controlled Crystal Oscillators (OCXO) (see 6.3.4).
- Type 5 Temperature Compensated/Voltage Controlled Crystal Oscillators (TCVCXO) (see 6.3.5).
- Type 6 Oven Controlled/Voltage Controlled Crystal Oscillator (OCVCXO) (see 6.3.6).
- Type 7 Microcomputer Compensated Crystal Oscillator (MCXO) (see 6.3.7).
- Type 8 Rubidium-Crystal Oscillators (RbXO) (see 6.3.8).
- 2. APPLICABLE DOCUMENTS
- 2.1 Government documents.

2.1.1 <u>Specifications, standards, and handbooks</u>. The following specifications, standards, and handbooks form a part of this document to the extent specified herein. Unless otherwise specified, the issues of these documents are those listed in the issue of the Department of Defense Index of Specifications and Standards (DODISS) and supplement thereto, cited in the solicitation (see 6.2).

SPECIFICATIONS

FEDERAL

PPP-8-566	-	Boxes, Folding, Paperboard.
PPP-8-585	-	Box, Wood, Wirebound.
PPP-B-601	•	Boxes, Wood, Cleated-Plywood.
PPP-B-621	•	Boxes, Wood, Nailed and Lock-Corner.
PPP-B-636	-	Boxes, Shipping, Fiberboard.
PPP-B-676	-	Boxes Setup.

MILITARY

MIL-P-116	-	Preservation, Methods of.
MIL-C-3098	-	Crystal Units, Quartz, General Specification for.
NIL-S-19500	-	Semiconductor Devices, General Specification for.
HIL-1-23011	-	Iron Nickel Alloys for Sealing to Glasses and Ceramics.
HIL-T-23648	•	Thermistor (Thermally Sensitive Resistor), Insulated General Specification for.
MIL-H-38534	•	Hybrid Microcircuits, General specification for.
MIL-N-46025	-	Nickel Bar, Flat Wire (Ribbon) and Strip (For Electronic Use).
MIL-N-46026	•	Nickel Rod and Wire (Round) (For Electronic Use).
MIL-C-49468	-	Crystal Units, Quartz, Precision, General Specification for.
MIL-P-55110	-	Printed Wiring Boards.

(See supplement 1 for list of associated specifications.)

STANDARDS

FEDERAL

FED-STD-209	-	Clean Room and Work Station Requirements, Control	led Environments.
FED-STD-123	-	Marking for Shipment (Civil Agencies).	

MILITARY

MIL-STD-129	•	Marking for Shipment and Storage.
MIL-STD-202	٠	Test Methods for Electronic and Electrical Component Parts.
MIL-STD-275	•	Printed Wiring for Electronic Equipment.
MIL-STD-690	-	Failure Rate Sampling Plans and Procedures.
MIL-STD-790	-	Product Assurance Program for Electronic and Fiber Optic Parts Specifications.
MIL-STD-810	-	Environmental Test Nethods and Engineering Guidelines.
WIL-STD-883	-	Test Methods and Procedures for Microelectronics.
MIL-STD-1285	-	Marking of Electrical and Electronic Parts.
HIL-STD-1686	•	Electrostatic Discharge Control Program for Protection of Electrical and
		Electronic Arts, Assemblies and Equipment (Excluding Electrically Initiated
		Explosive Devices) (Metric).
MIL-STD-1772	-	Certification Requirements for Hybrid Microcircuits Facilities and Lines.
MIL-STD-2073-		DOD Material procedures for Development and Application of Packaging Requirements.
MIL-STD-45662		Calibration Systems Requirements.
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(Unless otherwise indicated, copies of the federal and military specifications, standards, and handbooks are available from the Defense Printing Service Detachment Office, Building 4D (Customer Service), 700 Robbins Avenue, Philadelphia, PA 19111-5094.)

2.1.2 Other Government documents, drawings, and publications. The following other Government documents, drawings, and publications form a part of this document to the extent specified herein. Unless otherwise specified, the issues are those cited in the solicitation.

National Institute of Standards and Technology (NIST) Technical Note 1337 - Characterization of Clocks and Oscillators.

Cataloging Handbook H4 - Commercial and Government Entity (CAGE).

(Copies of specifications, standards, and other Government documents required by contractors in connection with specific acquisition functions should be obtained from the contracting activity or as directed by the contracting activity.)

2.2 <u>Non-Government publications</u>. The following document forms a part of this document to the extent specified herein. Unless otherwise specified, the issues of the documents which are DoD adopted are those listed in the issue of the DODISS cited in the solicitation. Unless otherwise specified, the issues of documents not listed in the DODISS are the issues of the documents cited in the solicitation.

AMERICAN SOCIETY FOR TESTING AND MATERIALS (ASTM)

ASTM A-698 - Standard Method of Test for Magnetic Shield Efficiency in Attenuating Alternating Magnetic Fields. ASTM B-170 - Oxygen-Free Electrolytic Copper-Refinery Shapes, Specification for.

ASTM F-15 - Iron-Nickel-Cobalt Sealing Alloy, Specification for.

ASTM F-30 - Iron-Nickel Sealing Alloys, Specification for.

(Application for copies should be addressed to the American Society for Testing Materials, 1916 Race Street, Philadelphia, PA 19103).

ELECTRONIC INDUSTRIES ASSOCIATION (EIA)

RS-477 - Cultured Quartz.

EIA-557 - Statistical Process Control Systems.

(Application for copies should be addressed to the Electronic Industries Association, 2001 Eye Street, NW, Washington, DC 20005.)

(Non-Government standards and other publications are normally available from the organizations that prepare or distribute the documents. These documents also may be available in or through libraries or other informational services.)

2.3 <u>Order of precedence</u>. In the event of a conflict between the text of this document and the references cited herein (except for associated detail specifications or specification sheets), the text of this document shall take precedence. Nothing in this document, however, supersedes applicable laws and regulations unless a specific exemption has been obtained.

3. REQUIREMENTS

3.1 <u>Specification sheets</u>. The individual item requirements shall be as specified herein and in accordance with the applicable specification sheet. In the event of any conflict between the requirements of this specification and the specification sheet, the latter shall govern.

3.2 Quality (see 4.1.2).

3.2.1 Product assurance program (PAP).

3.2.1.1 <u>Discrete construction</u>. The product assurance program for oscillators manufactured using a discrete construction furnished under this specification shall be established and maintained in accordance with the procedures and requirements specified in MIL-STD-790.

3.2.1.2 <u>Hybrid construction</u>. The product assurance program for oscillators manufactured using a hybrid construction furnished under this specification shall be established and maintained in accordance with the procedures and requirements specified in MIL-STD-790. (NOTE: The qualifying activity for this specification may use pre-existing certification of the manufacturing facility in accordance with MIL-H-38534 and MIL-STD-1772 as an alternate.) In addition, the following requirements shall be met.

3.2.1.2.1 <u>Design</u>, processing, manufacturing equipment, and materials instructions. Oscillator design, processing, manufacturing equipment, and materials shall be documented in drawings, standards, specifications, or other appropriate media which shall cover the requirements and tolerances for all aspects of design and manufacturing including equipment test and prove-in, materials acquisition and handling, design verification testing and processing steps. As a minimum requirement, detailed documentation must exist for the following items and must be adequate to assure that quantitative controls are exercised, that tolerances or limits of control are sufficiently tight to assure a reproducible high quality product and that process and inspection records reflect the results actually achieved:

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- a. Incoming materials control.
- b. Masking, photoresist, and mask registration.
- c. Glassivation or passivation.
- d. Metallization and film deposition.
- e. Die, element, crystal, and substrate attachment.
- f. Wirebonding.
- g. Rework.
- h. Sealing.
- i. Crystal evaluation program.

3.2.1.2.2 <u>Cleanliness and atmosphere control in work areas</u>. The requirements for cleanliness and atmosphere control in each work area in which unsealed oscillators, or parts thereof, are processed or assembled shall be documented. Air particle counts shall be in accordance with Federal Standard 209. The manufacturer shall establish action and absolute control limits (at which point work stops until corrective action is completed) based on historical data and criticalness of the process in each particular area. For foreign material identification and control, see internal visual inspection requirements of MIL-STD-883, method 2017.

3.2.1.2.3 <u>Environment control</u>. The following are minimum environmental control requirements. The air particle counts for the classification indicated shall be as described in Federal Standard 209. All fabrication, assembly, and testing of hybrid construction oscillators prior to preseal visual shall be in an environment meeting class 100,000 particle count requirements. Devices awaiting preseal visual inspection, devices accepted at preseal visual inspection and awaiting further processing and noncontinuous production lots (Noncontinuous production shall occur when oscillators are held by the manufacturer, with no additional assembly work performed, for more than 30 days.) accumulated after element attach and prior to preseal visual shall be stored in a dry nitrogen environment. The preseal visual inspection and the preparation for sealing environment shall be in accordance with MIL-STD-883, methods 2017 and 2032. In addition, for class S devices, all photolithographic operations shall be performed in a class 100 environment.

3.2.1.2.4 <u>Rework provisions</u>. All rework permitted on oscillators shall be as specified herein. This documentation shall reflect the processes, procedures, and materials to be used including verification or test data, and be approved by the qualifying activity of this specification. Each process or procedure shall be designated as rework. This documentation shall indicate that a decision to rework is made solely by the manufacturer. A typical example of rework is the removal of a defective element and replacement with a new element.

3.2.1.2.4.1 General rework provisions.

- a. All temperature excursions during any rework shall not exceed the baselined rework limitations. Time and temperature limits shall be specified.
- b. The minimum distance between the glass to metal seals and the package sealing surface shall be at least .040 (nch (1.02 mm) (.050 inch (1.27 mm) for class S) after final seal to prevent damage to lead seals by welding adjacent to them. (Applies to seam welding only.)
- c. Any oscillator which is reworked after preseal visual inspection shall be subjected to full screening or rescreening as applicable. If a oscillator has not been subjected to a given required screen prior to rework, then that oscillator must be subjected to that screen after rework. For class S oscillators, full rescreening beginning with preseal visual inspection is required after any rework operation involving unlidded oscillators. For class B oscillators, if a oscillator has been subjected to a given screen prior to rework, then rescreening applies as follows:

- (1) Preseal visual inspection. Inspection for general damage (low magnification in accordance with MIL-STD-883, methods 2017 and 2032) which might have been caused by the rework and perform a complete methods 2017 or 2032 inspection of the reworked element or area (e.g., replaced die, wirebonds, etc.).
- (2) Stabilization bake, temperature cycle or shock, mechanical shock or centrifuge, seal, and external visual. Rescreen all rework oscillators 100 percent.
- (3) Burn-in. Oscillators which have had elements replaced or have been wirebonded or rewirebonded require 100 percent burn-in rescreen.
- d. For class S oscillators, any oscillator which is reworked after 100 percent nondestructive bond pull (or preseal burn-in, when applicable) shall be subjected to full screening or rescreening as applicable. If an oscillator has not been subjected to a given required screen prior to rework, then that oscillator must be subjected to that screen after rework. Full screening is required after any rework operation involving unlidded oscillators with clarification as follows:
 - (1) Preseal burn-in (when applicable) shall be repeated if the rework involves any active element replacement or wire bonding (or wire rebonding) of any active element.
 - (2) Nondestructive bond pull is only required on wires that were replaced or rebonded provided the oscillator has already been subjected to the 100 percent bond pull screen.
- e. When flux is required for rework, the specific flux and detailed procedures for its use and subsequent special cleaning operations shall be documented and approved in accordance with 3.2.1.2.1.
- f. Replacement elements shall not be bonded onto the chip element they are to replace.

3.2.1.2.4.2 <u>Element wire rebonding</u>. Wire rebonding of elements other than substrates shall be permitted with the following limitations:

- a. No scratched, voided, or discontinuous paths or conductor patterns on an element shall be repaired by bridging with or addition of bonding wire or ribbon.
- b. All rebonds shall be placed on at least 50 percent undisturbed metal (excluding probe marks that do not expose underlying oxide). No more than one rebond attempt at any design bond location shall be permitted. No rebonds shall touch an area of exposed oxide caused by lifted or blistered metal. A bond shall be defined as a wire to post or wire to pad bond. Bond-offs required to clear the bonder after an unsuccessful bond attempt need not be visible, shall not be cause for reject and shall not be counted as a rebond. For class S, the total number of rebond attempts (exclusive of total element replacement) shall be limited to a maximum of 10 percent of the total number of bonds in the hybrid microcircuit. The 10 percent limit on rebond attempts may be interpreted to the nearest whole number to the 10 percent value.

3.2.1.2.4.3 <u>Substrate wire rebonding</u>. Wire rebonding on substrates shall be permitted with the following limitations: No rebonds shall be made over intended bonding areas in which the top layer metallization has lifted, peeled, or has been damaged such that underlying metallization or substrate is exposed at the immediate bond site.

3.2.1.2.4.4 Compound bonding. Compound bonding for rework is permitted only as follows:

- a. A gold ball bond on a substrate wire, a gold ball or a crescent bond.
- b. Only monometallic compound bonds are permitted (i.e., the original bond wire and that used for compound bonding must be the same material and wire size).
- c. The new bond must cover at least 75 percent of the original bond or wire.
- d. The maximum number of compound bonds shall not exceed 10 percent of the total number of wires.

- e. A corrective action system must be utilized in order to reduce the number of compound bonds.
- f. All compound bonds shall be 100 percent nondestructive pull tested in accordance with MIL-STD-883, method 2023.
- g. A compound bond shall not be used to connect two wires.
- h. All compound bonds shall meet the visual criteria in MIL-STD-883, methods 2017 and 2032.
- 3.2.1.2.4.5 <u>Element replacement</u>. Element replacement shall be permitted with the following limitations:
 - a. Any polymer attached element may be replaced two times at a given location (not more than one time for class S) on any oscillator.
 - b. Any metallic attached element may be replaced one time at a given location.
 - c. Any metallic attach element onto a plated tab where the tab is attached to a substrate with a higher temperature metallic attach process, may be replaced two times.
 - d. Substrates may be removed and put into a new package one time.

3.2.1.2.4.6 <u>Seal rework</u>. The use of polymers to effect, improve, or repair any package seal shall not be permitted.

3.2.1.2.4.6.1 <u>Lid seal rework</u>. It shall be permissible to perform seal rework on oscillators that fail fine leak testing one time, only if tracer gas is included during the original sealing operation and under all of the following conditions:

- a. Fine leak testing, without pressurization (bomb), must be performed immediately after sealing prior to any other test.
- b. Oscillators shall be stored in a nitrogen environment for a maximum of 4 hours between initial seal and reseal without replacing the cover.
- c. Oscillators shall be submitted to a predetermined vacuum bake prior to reseal.
- d. Solder sealed packages may not be reworked in accordance with this procedure.

NOTE: The above leak testing shall not be used as a substitute for the fine leak testing required in 4.8.2.

3.2.2 <u>Statistical process control (SPC)</u>. The contractor shall implement and use statistical process control techniques in the manufacturing process for parts covered by this specification. The SPC program shall be developed and maintained in accordance with EIA-557. The SPC program shall be documented and maintained as part of the overall product assurance program as specified in MIL-STD-790. The implementation of statistical process control shall be 12 months from the date of this specification. Processes for application of SPC techniques may include but are not limited to:

- a) Wirebonding.
- b) Lid seal.
- c) Lead trim.
- d) Final lead finishing (solder dip, etc.).

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In addition, the manufacturer shall control water vapor content, in sealing, as part of the process control requirement.

3.2.4 <u>Electrostatic discharge (ESD) control program</u>. As part of the PAP, the manufacturer shall establish and maintain an ESD control program in accordance with MIL-STD-1686. Evidence of such compliance shall be verified by the qualifying activity of this specification as a prerequisite for qualification and continued qualification. This program shall be documented by ESD control plan which must be under document control. As a minimum, this plan must address the identification of ESD sensitive (ESDS) sub-components and end items, facilities, training, design protection, handling procedures, marking, cleaning, preservation, packaging, and quality assurance.

3.3 <u>Qualification</u>. Crystal oscillators furnished under this specification as class B or S shall be products which are qualified for listing on the applicable qualified products list (QPL) at the time set for opening of bids (see 4.6 and 6.4).

3.4 <u>Materials</u>. The materials used in construction of crystal oscillators shall be nonnutrient to fungus and shall not blister, outgas, soften, flow or show defects that adversely affect storage, operation at rated conditions, or environmental capabilities. When materials are not specified, materials shall be used which enable the crystal oscillators to meet the performance requirements of this specification. Acceptance or approval of any constituent material shall not be construed as a guarantee of the acceptance of the finished product.

3.4.1 <u>Quartz</u>. If the type of quartz for the resonator is specified, it shall conform with the following requirements.

3.4.1.1 <u>Cultured quartz</u>. If cultured quartz is specified (see 3.1), it shall have been cut from a bar which met the requirements of EIA standard RS-477. The Q-grade shall be as specified (see 3.1) but not worse than grade C for thickness-shear type resonators. For class S, the grower, autoclave ID, date code, and bar ID shall be traceable to the production lot(s) and shall be submitted to the acquiring activity upon request.

3.4.1.2 <u>Swept cultured quartz</u>. If swept cultured quartz is specified (see 3.1), the sweeper, sweep lot number, electrode description (material and application technique, e.g., pressure, sputtered, or evaporated), sweeping atmosphere, sweeping temperature, electric field, and current profiles shall be traceable to the production lot(s) and shall be submitted to the acquiring activity upon request.

3.4.1.3 <u>Natural quartz</u>. If natural quartz is specified (see 3.1), documentation substantiating the supplier shall be submitted to the acquiring activity upon request.

3.4.2 <u>Polymeric materials</u>. Polymeric materials may not exceed their cure temperature after final seal.

3.4.2.1 <u>Polymeric adhesives</u>. All adhesive polymeric materials used for hybrid construction shall meet the requirements of MIL-STD-883, method 5011 and shall be approved by the qualifying activity.

3.5 <u>Design and construction</u>. Crystal oscillator design and construction shall be in accordance with all the requirements specified herein and in the specification sheet (see 3.1).

3.5.1 Package.

3.5.1.1 <u>Discrete construction</u>. The outline dimensions of the package shall be as specified (see 3.1). Discrete construction crystal oscillators supplied under this specification shall be sealed in glass, metal or ceramic (or combination of these) packages. O-ring seals, when applicable, shall be permitted at an access hole in the package to allow frequency adjustment. Adhesive or polymeric material shall not be used for package cover/lid attachment, seal or repair. Use of any other package material shall require prior approval from the qualifying authority.

3.5.1.2 <u>Hybrid construction</u>. All hybrid construction oscillators supplied to this specification shall be hermetically sealed in glass, metal, or ceramic (or combinations of these) packages. No adhesive or polymeric materials shall be used for package lid attach (or seal). Flux shall not be used in the final sealing process. The minimum distance between the glass to metal seals and the package sealing surface for seam welded packages after final seal shall be .040 inch (1.02 mm) minimum for class B oscillators and .050 inch (1.27 mm) minimum for class S oscillators.

The internal water vapor content shall not exceed 5,000 ppm at +100°C for class S or class B oscillators, when tested in accordance with 4.8.56. Polymer impregnations or secondary seal (backfill, coating, or other uses of organic or polymeric materials to effect, improve the seal) of the oscillator package shall not be permitted. Packages for class S oscillators shall have a metal body with hard glass or ceramic seals, a hard glass body, or a ceramic body; and the lid shall be welded, brazed, soldered, or glass frit with a frit sealing temperature greater than +385°C. Glass frit sealed packages shall pass the lid torque test of MIL-STD-883, method 2024. Also for class S, the use of glass frit seal shall have glass on the mating surface only and the inside surface of the cavity shall not be coated with the seal glass.

NOTE: Packages containing beryllia shall not be ground, sandblasted, machined, or have other operations performed on them which will produce beryllia or beryllium dust. Furthermore, beryllium oxide packages shall not be placed in acids that will produce fumes containing beryllium.

3.5.2 <u>Metals</u>. Metal surfaces shall be corrosion resistant or shall be plated or treated to resist corrosion and shall meet the requirements specified in 3.5.4.

3.5.3 <u>Internal conductors (hybrid construction only</u>). Internal thin film conductors on a substrate (metallization stripes, contact areas, bonding interfaces, etc.) shall be designed so that no properly fabricated conductor shall experience in normal operation (at worst case specified operating conditions), a current density in excess of the maximum allowable value shown below for the applicable conductor material:

<u>Conductor material</u>	Maximum allowable <u>current density</u>
Aluminum (99.99 percent pure or doped) without glassivation	2 x 10 ⁵ A/cm ²
Aluminum (99.99 percent pure or doped) glassivated	5 x 10 ⁵ A/cm ²
Gold	6 x 10 ⁵ A/cm ²
All other (unless otherwise specified)	$2 \times 10^5 \text{ A/cm}^2$

The current density shall be calculated at the point of maximum current density (i.e., greatest current per unit cross section; see 3.5.3a) for the specified oscillator and schematic or configuration.

- a. Use a current value equal to the maximum continuous current (at full fanout for digitals or at maximum load for linears) or equal to the simple time-averaged current obtained at maximum rated frequency and duty cycle with maximum load, whichever results in the greater current value at the point of maximum current density. This current value shall be determined at the maximum recommended supply voltage and with the current assumed to be uniform over the entire conductor cross-sectional area.
- b. Use the minimum allowed metal thickness in accordance with manufacturing specifications and controls including appropriate allowance for thinning experienced in the metallization step (vis). The thinning factor over a metallization step is not required unless the point of maximum current density is located at the step.
- c. Use the minimum actual design conductor widths (not mask widths) including appropriate allowance for narrowing or undercutting experienced in metal etching.
- d. Areas of barrier metals and nonconducting material shall not be included in the calculation of conductor cross section.

3.5.4 Package and lead materials and finishes.

3.5.4.1 <u>Lead or terminal material</u>. Unless otherwise specified, the lead or terminal material shall conform to one of the following compositions:

- a. Type A: Iron-nickel-cobalt alloy: MIL-I-23011, class 1, ASTM F-15.
- b. Type B: Iron-nickel alloy (41 percent Ni): MIL-I-23011, class 5, ASTM F-30.
- c. Type C: Co-fired metallization such as nominally pure tungsten. The composition and application processing of these materials shall be subject to qualifying activity approval.
- d. Type D: Copper core-iron nickel ASTM F-30 alloy (50.5 percent Ni). The core material shall consist of copper (oxygen-free) ASTM B-170, grade 2.
- e. Type E: Copper core ASTM F-15 alloy. The core material shall consist of copper (oxygen-free) ASTM 8-170, grade 2.
- f. Type F: Copper (oxygen free) ASTN B-170, grade 2. This material shall not be used as an element of any glass-to-metal seal structure.
- g. Type G: Iron-nickel alloy (50.5 percent Ni): MIL-1-23011, class 2, ASTM F-30.
- h. Type H: Nickel: MIL-N-46025 (for ribbon leads) and MIL-N-46026 (for round wire leads).

3.5.4.2 <u>Lead finish</u>. The finish system on all external leads or terminals shall conform to one of the following (Pure tin finish shall not be used on any internal or external package surface or as a lead finish. In addition, tin plating shall not be used as an undercoat):

- a. Hot solder dip. The hot solder dip shall be homogeneous with a minimum thickness of 60 microinches (1.52 µm) for round leads and, for other shapes, a minimum thickness at the crest of the major flats of 200 microinches (5.08 µm) solder (SN60 or SN63). In all cases, the solder dip shall extend up to and beyond the effective seating plane for packages with standoffs or within .030 inch (0.76 mm) of the lead or package interface for leaded flush mounted oscillators. For leadless chip carrier oscillators, the hot solder dip shall cover a minimum of 95 percent of the metallized side castellation or notch and metallized areas above and below the notch except the index feature if not connected to the castellation. Terminal area intended for oscillator mounting shall be completely covered. The hot solder dip is applicable:
 - (1) Over a finish in accordance with entry 3.5.4.2b or c below, or
 - (2) Over electroplated nickel or electroless nickel phosphorous in accordance with 3.5.4.4.1, or
 - (3) Over the basis metal. When applied over the basis metal, underplate that is nonconforming, or other finishes that are nonconforming (e.g., fused tin less than 200 microinches (5.08 µm)), hot solder dip shall cover the entire lead to the glass seal or point of emergence of the lead or metallized contact through the package wall.
- b. Tin-lead plate. Tin-lead plating shall have in the plated deposit 3 percent to 50 percent by weight lead (balance nominally tin) homogeneously co-deposited. As plated tin-lead shall be a minimum of 300 microinches (7.62 µm) thick. As plated tin-lead shall contain no more than 0.05 percent by weight co-deposited organic material measured as elemental carbon.

Tin-lead plate is applicable:

- (1) Over electroplated nickel or electroless nickel phosphorous in accordance with 3.5.4.4.1.
- (2) Over the basis metal.
- c. Gold plate. Gold plating shall be a minimum of 99.7 percent gold, and only cobalt shall be used as the hardener. Gold plating shall be a minimum of 50 microinches (1.27 µm) and a maximum of 225 microinches (5.72 µm) thick. Gold plating shall be permitted only over nickel plate or undercoating in accordance with 3.5.4.4.1.

3.5.4.3 <u>Solder dip (retinning) leads</u>. Only the manufacturer may solder dip/retin the leads of the product supplied to this specification provided the solder dip/retin process has been approved by the qualifying activity.

3.5.4.3.1 <u>Qualifying activity approval</u>. Approval of the solder dip process will be based on one of the following options:

- a. When the original lead finish qualified was hot solder dip in accordance with 3.5.4.2a. The manufacturer shall use the same solder dip process for retinning as is used in the original manufacture of the product.
- b. When the lead originally qualified was not hot solder dip as prescribed in 3.5.4.3.1a, approval for the process to be used for solder dip shall be based on the following test procedure:
 - (1) Six samples of any oscillator of a individual specification sheet and specific lead finish shall be subjected to the manufacturer's solder dip process. Following the test, the oscillators shall be subjected to the subgroups 1 and 2 tests of the group A inspection. No defects are allowed.
 - (2) Two of the six samples shall be subjected to the solderability test. No defects are allowed.
 - (3) The remaining four samples are subjected to the resistance to solder heat test and then to the subgroups 1 and 2 tests of the group A inspection. No defects are allowed.
 - (4) In addition, the hot solder dip process must meet requirements of 3.5.4.2a.

3.5.4.3.2 <u>Solder dip/retinning options</u>. The manufacturer may solder dip/retin as follows:

- a. After the screening tests specified in 4.5. Oscillators shall then be subjected to remaining group A inspections.
- b. As a corrective action, if the lot fails the group A solderability test.
- c. After the group A inspection has been completed. Following the solder dip/retinning process, the group A inspection tests shall be repeated on the lot.

3.5.4.4 <u>Package body finish</u>. External metallic package elements other than leads or terminals (e.g., lids, covers, bases, seal rings, etc.) shall meet the applicable corrosion resistance and environmental requirements or shall be finished so that they meet those requirements using finishes conforming to one or more of the following as applicable (Pure tin finish shall not be used on any internal or external package surface or as a lead finish. In addition, tin plating shall not be used as an undercoat.):

- a. Solder in accordance with 3.5.4.2a.
- b. Tin-lead plate in accordance with 3.5.4.2b.
- c. Gold plate shall be a minimum of 99.7 percent gold and only cobalt shall be used as a hardener. Gold plating shall be a minimum of 10 microinches (0.25 μm) and a maximum of 225 microinches (5.72 μm) thick. The gold plate shall be applied over electroless or electroplated nickel or undercoating in accordance with 3.5.4.4.1.

Multilayered finish structures are acceptable provided the outer gold layer meets the minimum thickness of 10 microinches (0.25 μ m) and each of the nickel undercoats meets the thickness requirements of 3.5.4.4.1 with the total nickel thickness not to exceed 600 microinches (15.24 μ m).

d. Nickel plate in accordance with 3.5.4.4.1.

3.5.4.4.1 <u>Nickel plate or undercoating</u>. Electroplated nickel undercoating or finishes from a sulfamate nickel bath is preferred and shall be 50 to 350 microinches (1.27 µm to 8.89 µm) thick measured on major flats or diameters. Electroless nickel undercoating or finishes, when allowed, shall be 50 to 350 microinches (1.27 µm to 8.89 µm) thick measured on major flats or diameters. The addition of organic "wetting agents" is prohibited for either sulfamate or phosphorous nickel baths. Electroplate or electroless nickel plate (or combinations thereof) as well as nickel cladding may be used as the finish for package elements other than flexible leads or terminals provided the corrosion resistance and environmental requirements are met.

In all cases, electroplated nickel undercoating from a nickel sulfamate bath is preferred for lead finishes. Electroless nickel shall not be used as the undercoating on flexible or semiflexible leads (see MIL-STD-883, method 2004, test condition B_1 , - bending stress, procedure for flexible and semi-flexible leads) and shall be permitted only on rigid leads or package elements other than leads.

3.5.5 <u>Weight (when specified, see 3.1)</u>. The weight of the crystal oscillator shall be as specified.

3.5.6 <u>Construction technology</u>. The crystal oscillator shall be constructed using the construction technology specified (see 3.1) in accordance with the following.

3.5.6.1 <u>Discrete construction</u>. Construction consisting exclusively of discrete electronic parts (including surface mount devices) assembled and interconnected on a printed circuit board, or an insulating substrate.

3.5.6.2 <u>Hybrid construction</u>. Construction consisting of microelectronic circuit elements electrically and mechanically interconnected on an insulating substrate upon which resistors, capacitors, or conductors have been deposited, and used in a package that will be backfilled with an inert gas.

3.5.6.3 <u>Mixed construction</u>. Construction combining discrete and hybrid subassemblies.

3.5.7 <u>Components</u>. Components used in assembly of crystal oscillators shall be as specified below. Any exception taken to selection of parts specified below shall fall into the category of nonstandard parts and shall be submitted to the qualifying activity for approval.

3.5.7.1 <u>Quartz crystal</u>. Electrical connection shall be made to the quartz resonator electrodes by an electrically conductive adhesive, solder, thermocompression bond, ultrasonic bond, parallel-gap weld, electroplated metal bond, or by another method proving intimate metal-to-metal continuity. Interference, friction, crimped, or similar joining of parts unreinforced by solder, welding, etc. shall not be used.

3.5.7.1.1 <u>Crystal unit</u>. Crystal units using solder seal shall not be employed. If specified, crystal units shall meet the requirements of MIL-C-3098 or MIL-C-49468, as specified (see 3.1).

3.5.7.1.2 <u>Uncased quartz resonators</u>. Interference, friction, crimped, or similar joining of parts unreinforced by solder, welding, adhesive, etc., shall not be used to support or provide electrical contact for the quartz resonator. Oscillators using uncased quartz resonators shall be hermetically sealed in vacuum or in a dry backfill gas. The type of gas, purity, moisture, temperature, and pressure at sealing shall be traceable to the production lot(s) and shall be submitted to the acquiring activity upon request. Frequency adjustment of the resonator by abrasion of the electrode or exposure to a halogen vapor shall be prohibited.

3.5.7.2 <u>Packaged passive discrete parts</u>. Packaged passive discrete parts shall be established reliability (ER) parts with minimum failure rate (FR) level P for class B and level R for class S in accordance with MIL-STD-690. When parts of established reliability are not available, QPL parts shall be used. When a QPL part is not available, parts shall be tested to the applicable military specification, e.g., thermistors shall be tested to the applicable requirements of MIL-T-23648.

3.5.7.3 <u>Packaged semiconductor devices</u>. Packaged semiconductor devices shall be JANTX or JANTXV (when specified, see 3.1.) for class B and JANS for class S oscillators. When not available, devices shall be tested and screened in accordance with MIL-S-19500 to the equivalent JANTX, JANTXV, or JANS requirements for similar types.

3.5.7.4 <u>Packaged integrated circuits</u>. Packaged integrated circuits shall be class B or class S QPL parts or in accordance with Standard Military Drawings when a QPL part is not available. All others shall be compliant with the requirements of MIL-STD-883 applicable to non-JAN devices.

3.5.7.5 <u>Hybrid microcircuit elements</u>. Hybrid microcircuit elements used in the manufacture of hybrid construction crystal oscillators shall be in accordance with the requirements of appendix A.

3.5.8 <u>Printed wiring</u>. Resin impregnated glass fiber reinforced printed wiring board design shall conform to MIL-STD-275 and shall meet the requirements of MIL-P-55110.

3.5.9 <u>Overall frequency accuracy (see 6.3.9) (when specified, see 3.1)</u>. The crystal oscillator shall be designed to meet the overall frequency accuracy specified. Certification shall be provided to the qualifying activity indicating that all contributing sources of frequency error have been considered in the design, and that a worst case frequency error analysis was performed.

3.5.10 <u>Calibration</u>. The crystal oscillator shall be designed for the method of calibration specified (see 3.1) in accordance with the following.

3.5.10.1 Manufacturer calibrated. There shall be no provision for frequency adjustment.

3.5.10.2 <u>Manufacturer and user frequency offset calibrated (see 6.3.10)</u>. Frequency adjustment to marked frequency offset shall be at specified reference temperature and nominal supply voltage and load (see 3.7.2).

3.5.10.3 <u>Hanufacturer and user nominal frequency calibrated</u>. Frequency adjustable to nominal frequency shall be at specified reference temperature and nominal supply voltage and load.

3.5.11 <u>Load test circuit (when specified, see 3.1)</u>. The crystal oscillator shall be designed to operate with the specified load test circuit under the conditions specified.

3.5.12 <u>Design for nuclear survivability (when specified, see 3.1)</u>. Parts, materials, processes, design details, and operating principles shall be selected to insure nuclear survivability over the range of levels specified (see 3.1). Analysis of the design shall be made and documented to indicate the most probable modes of degradation and malfunction, and to support its effectiveness in achieving radiation hardness. Certification shall be provided to the qualifying activity that the oscillator has been designed for nuclear survivability, and that an analysis has been performed which indicates that the oscillator has no anomalous behavior and will not fail to function in its intended mode (see 3.6.47).

3.6 Performance.

3.6.1 Seal. When tested as specified in 4.8.2, the following requirements shall be met, as applicable.

3.6.1.1 <u>O-ring-solder seal (nonhermetic)</u>. Oscillators employing solder seal or combination O-ring-solder seal shall be tested as specified in 4.8.2.1. Leakers will be identified by a single bubble or a stream of bubbles. Oscillators from which a single bubble is observed is considered a reject.

3.6.1.2 <u>Hermetic seal</u>. Oscillators employing hermetic seal shall be tested as specified in 4.8.2.2 and meet the requirements of 3.6.1.2.1 or 3.6.1.2.2.

3.6.1.2.1 <u>Discrete or mixed construction</u>. When oscillators are tested as specified in 4.8.2.2.1, they shall meet the requirements as specified, see 3.1.

3.6.1.2.2 <u>Hybrid construction</u>. When oscillators are tested as specified in 4.8.2.2.2, they shall meet the requirements as specified, see 3.1.

3.6.1.3 <u>High vacuum seal (types 4 and 6) (when specified, see 3.1) (see 6.3.11)</u>. Oscillators employing a high vacuum seal shall have a leakage rate not to exceed the value specified. When specified (see 3.1), the oscillator shall be final baked and sealed at a pressure not to exceed the value specified (see 4.8.2.3).

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3.6.2 Supply voltage.

3.6.2.1 <u>Oscillator supply voltage</u>. When measured as specified in 4.8.3.1, the oscillator supply voltage magnitude, tolerance, polarity, peak-to-peak ripple and ripple frequency, regulation, noise, and ramp rate (turn-on) shall be as specified (see 3.1).

3.6.2.2 Oven supply voltage (types 4 and 6). When measured as specified in 4.8.3.2, the oven supply voltage magnitude, tolerance, polarity, peak-to-peak ripple and ripple frequency, regulation, and noise shall be as specified (see 3.1).

3.6.2.3 <u>Modulation-control input voltage (types 2, 5, and 6)</u>. When measured as specified in 4.8.3.3, the oscillator modulation voltage and magnitude, tolerance, polarity, frequency limits, dc reference level, dc control voltage magnitude, polarity, range, slew rate, peak-to-peak ripple and ripple frequency, regulation, and noise shall be as specified (see 3.1).

3.6.3 <u>Overvoltage survivability</u>. When tested as specified in 4.8.4, the application of an overvoltage at the supply terminals shall not impair performance of the oscillator.

3.6.4 Input current-power.

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3.6.4.1 <u>Oscillator input current-power</u>. When measured as specified in 4.8.5.1, the oscillator input current-power shall not exceed the value specified (see 3.1).

3.6.4.2 Oven input current-power (types 4 and 6). When measured as specified in 4.8.5.2, the oven peak and steady-state (after stabilization) input current-power shall not exceed the value specified (see 3.1).

3.6.4.3 <u>Syntonization energy (type 8) (see 6.3.12)</u>. When measured as specified in 4.8.5.3, the energy required by the rubidium reference to syntonize the crystal oscillator to within the specified frequency tolerance shall not exceed the value specified (see 3.1).

3.6.5 <u>Initial accuracy at reference temperature (see 6.3.13) (when specified, see 3.1)</u>. When tested at the specified reference temperature, as specified in 4.8.6, the output frequency referenced to nominal frequency shall not exceed the limits specified. Nonfrequency-adjustable oscillators shall be capable of meeting this requirement within the specified period following shipment (see 3.1). Support data shall be provided to the qualifying activity showing that nonfrequency-adjustable oscillators are capable of meeting this requirement within the specified period following shipment.

3.6.6 Frequency adjustment (frequency-adjustable oscillators).

3.6.6.1 <u>Mechanical-frequency-adjustment (when applicable) (see 6.3.14)</u>. When tested as specified in 4.8.7.1, the mechanical-frequency-adjustment range, referenced to nominal frequency or marked frequency offset, as applicable (see 3.5.10), and resolution shall be as specified. For an external-frequency-adjustment oscillator (see 6.3.15) the external-frequency-adjustment element, e.g., potentiometer, shall be as specified (see 3.1).

3.6.6.2 <u>Electrical-frequency-control (when applicable) (see 6.3.16)</u>. When tested as specified in 4.8.7.2, the electrical-frequency-control range corresponding to the specified input control voltage shall be as specified (see 3.1).

3.6.7 <u>Frequency warmup (see 6.3.17) (when specified, see 3.1)</u>. When measured as specified in 4.8.8, the time for the output frequency, referenced to final frequency as specified, to stabilize within the specified frequency tolerance shall not exceed the value specified.

3.6.8 <u>Initial frequency aging (types 4 and 6) (see 6.3.18) (when specified, see 3.1)</u>. When tested as specified in 4.8.9, the initial frequency aging shall not exceed the specified value.

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3.6.9 Initial frequency-temperature accuracy (see 6.3.19).

3.6.9.1 <u>Initial frequency-temperature accuracy (one-half temperature cycle) (when not specified by</u> <u>3.6.9.2, 3.6.9.3 or 3.6.9.4</u>). When measured as specified in 4.8.10.1, the frequency-temperature accuracy shall not exceed the limits specified. Nonfrequency-adjustable oscillators shall be capable of meeting this requirement within the specified period following shipment (see 3.1). Support data shall be provided to the qualifying activity showing that nonfrequency-adjustable oscillators are capable of meeting this requirement within the specified period following shipment.

3.6.9.2 <u>Initial frequency-temperature accuracy including hysteresis (see 6.3.20) (when specified, see</u> <u>3.1)</u>. When measured as specified in 4.8.10.2, the frequency-temperature accuracy including hysteresis shall not exceed the limits specified. Nonfrequency-adjustable oscillators shall be capable of meeting this requirement within the specified period following shipment (see 3.1). Support data shall be provided to the qualifying activity showing that nonfrequency-adjustable oscillators are capable of meeting this requirement within the specified period following shipment.

3.6.9.3 <u>Initial frequency-temperature accuracy including trim effect (one-half temperature cycle) (see 6.3.21) (when specified, see 3.1)</u>. When measured as specified in 4.8.10.3, the frequency temperature accuracy including trim effect for a specified temperature range and frequency-adjustment range shall not exceed the limits specified.

3.6.9.4 <u>Initial frequency-temperature accuracy including hysteresis and trim effect (see 6.3.20 and 6.3.21) (when specified, see 3.1)</u>. When measured as specified in 4.8.10.4, the frequency temperature accuracy including hysteresis and trim effect for a specified temperature range and frequency-adjustment range shall not exceed the limits specified.

3.6.10 Frequency-temperature stability (see 6.3.22) (when specified in Lieu of 3.6.9, see 3.1).

3.6.10.1 <u>Frequency-temperature stability (one-half temperature cycle) (when specified, see 3.1)</u>. When measured as specified in 4.8.11.1, the frequency-temperature stability shall not exceed the limits specified. If specified, a frequency versus temperature curve of the oscillator shall be generated in the format specified. This curve shall be supplied, annotated by oscillator serial number, for each oscillator produced.

3.6.10.2 <u>Frequency-temperature stability including hysteresis (when specified, see 3.1)</u>. When measured as specified in 4.8.11.2, the frequency-temperature stability including hysteresis shall not exceed the limits specified. If specified, a frequency versus temperature curve of the oscillator shall be generated in the format specified. This curve shall be supplied, annotated by oscillator serial number, for each oscillator produced.

3.6.10.3 <u>Frequency-temperature stability including trim effect (one-half temperature cycle) (when</u> <u>specified, see 3.1)</u>. When measured as specified in 4.8.11.3, the frequency temperature stability including trim effect for a specified temperature range and frequency-adjustment range shall not exceed the limits specified. If specified, a frequency versus temperature curve of the oscillator shall be generated in the format specified. This curve shall be supplied, annotated by oscillator serial number, for each oscillator produced.

3.6.10.4 <u>Frequency-temperature stability including hysteresis and trim effect (when specified, see 3.1)</u>. When measured as specified in 4.8.11.4, the frequency temperature stability including hysteresis and trim effect for a specified temperature range and frequency-adjustment range shall not exceed the limits specified. If specified, a frequency versus temperature curve of the oscillator shall be generated in the format specified. This curve shall be supplied, annotated by oscillator serial number, for each oscillator produced.

3.6.11 <u>Frequency-temperature slope at reference temperature (see 6.3.23) (when specified, see 3.1)</u>. When measured as specified in 4.8.12, the frequency temperature slope at the reference temperature shall not exceed the limits specified.

3.6.12 <u>Frequency-thermal transient stability (when specified, see 3.1)</u>. When measured as specified in 4.8.13, the thermal response time and overshoot or undershoot of the transient frequency excursion resulting from a specified temperature change shall not exceed the limits specified.

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3.6.13 <u>Frequency-voltage tolerance (see 6.3.24)</u>. When measured as specified in 4.8.14, the frequency-voltage tolerance referenced to output frequency at nominal supply voltage shall not exceed the limits specified (see 3.1).

3.6.14 <u>Frequency-load tolerance (see 6.3.25) (when specified, see 3.1)</u>. When measured as specified in 4.8.15, the frequency-load tolerance referenced to output frequency at nominal load shall not exceed the limits specified.

3.6.15 <u>Retrace (see 6.3.26) (when specified, see 3.1)</u>. When tested as specified in 4.8.16, the frequency retrace, referenced to an initial output frequency, shall not exceed the limits specified.

3.6.16 Short-term stability (see 6.3.27, 6.3.29, and 6.3.30) (when specified, see 3.1).

3.6.16.1 <u>Phase noise, steady-state (when specified, see 3.1)</u>. When measured as specified in 4.8.17.1, the phase noise, I(f), under steady-state (quiescent) conditions shall not exceed the values bounded by straight line segments drawn on log-log axis through specified points.

3.6.16.2 <u>Phase noise, random vibration (when specified, see 3.1)</u>. When measured as specified in 4.8.17.2, the phase noise, $\mathfrak{A}(f)$, shall not exceed the values specified for the random vibration levels and spectra specified.

3.6.16.3 <u>Phase noise, acoustic (when specified, see 3.1)</u>. When measured as specified in 4.8.17.3, the phase noise, $\mathfrak{Q}(f)$, shall not exceed the values specified for the acoustic intensities and spectra specified.

3.6.16.4 <u>Amplitude noise (when specified, see 3.1)</u>. When measured as specified in 4.8.17.4, the amplitude noise, $S_{\epsilon}(f)$, shall not exceed the values bounded by straight line segments drawn on log-log axes through the specified points.

3.6.16.5 <u>Allan variance (when specified, see 3.1)</u>. When measured as specified in 4.8.17.5, the Allan variance shall not exceed the values bounded by straight line segments drawn on log-log axes through the specified points.

3.6.17 Acceleration sensitivity (see 6.3.30) (when specified, see 3.1).

3.6.17.1 <u>Acceleration sensitivity, steady-state (when specified, see 3.1)</u>. When tested as specified in 4.8.18.1, the frequency change per unit of acceleration shall not exceed the value specified at any acceleration level from 5 g to the maximum specified.

3.6.17.2 <u>Acceleration sensitivity, 2 g tip-over (when specified, see 3.1)</u>. When tested as specified in 4.8.18.2, the acceleration sensitivity due to 2 g tip-over shall not exceed the value specified. If specified, the maximum acceleration sensitivity shall be in the direction specified. If specified, the direction of the acceleration sensitivity vector (expressed in terms of its three unit vectors) shall be recorded and supplied with a serial number for each oscillator produced.

3.6.17.3 <u>Acceleration sensitivity, vibration (when specified, see 3.1)</u>. When tested as specified in 4.8.18.3, the low level acceleration sensitivity shall not exceed the value specified for the maximum acceleration specified. If specified, the maximum acceleration sensitivity shall be in the direction specified. If specified, the direction of the acceleration sensitivity vector (expressed in terms of its three unit vectors) shall be recorded and supplied with a serial number for each oscillator produced.

3.6.18 Magnetic field sensitivity (when specified, see 3.1) (see 6.3.31).

3.6.18.1 <u>Magnetic field sensitivity, dc</u>. When tested in accordance with 4.8.19.1, the oscillator's dc magnetic field sensitivity shall not exceed the value specified for the field strength specified. If specified, the maximum magnetic field sensitivity shall be along the direction specified.

3.6.18.2 <u>Magnetic field sensitivity, ac</u>. When tested in accordance with 4.8.19.2, the oscillator's alternating magnetic field sensitivity shall not exceed the value specified for the field strength and frequencies specified. If specified, the maximum magnetic field sensitivity shall be along the axis specified.

3.6.19 <u>Output waveform</u>. When tested as specified in 4.8.20, the type of output waveform from the oscillator shall be as specified (see 3.1).

3.6.20 Output voltage-power (see 4.8.21).

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3.6.20.1 <u>Output voltage</u>. When measured as specified in 4.8.21.1, the output voltage shall not exceed the limits specified (see 3.1).

3.6.20.2 <u>Output power (sinusoidal waveform) (when specified, see 3.1)</u>. When measured as specified in 4.8.21.2, the output power shall not exceed the limits specified.

3.6.20.3 <u>Output logic voltage levels (square wave output waveform</u>). When measured as specified in 4.8.21.3, the output logic voltage levels for TTL and CMOS compatible oscillators shall not exceed the limits specified in table I, unless otherwise specified. For ECL and other logic families, output logic voltage levels shall not exceed the limits specified (see 3.1).

Compatible logic	Minimum "1" level	Maximum ⇔0* level
TTL	2.40 volts	0.50 volt
CNOS/HCNOS	0.9 V _{DD}	0.1 V _{DD}

TABLE 1. Output logic voltage levels.

3.6.21 <u>Rise and fall times (see 6.3.32 and 6.3.33) (square wave output waveform)</u>. When tested as specified in 4.8.22, the rise and fall times shall not exceed the limits specified at the measurement levels specified (see 3.1).

3.6.22 <u>Duty cycle (see 6.3.34) (square wave output waveform)</u>. When tested as specified in 4.8.23, the duty cycle of the output waveform shall not exceed the limits specified at the measurement levels specified (see 3.1).

3.6.23 <u>Harmonic and subharmonic distortion (see 6.3.35) (when specified, see 3.1)</u>. When measured as specified in 4.8.24, the harmonic and subharmonic distortion shall not exceed the values specified within the bandwidth as specified.

3.6.24 <u>Spurious response (see 6.3.36) (when specified, see 3.1)</u>. When measured as specified in 4.8.25, the nonharmonically related spurious responses shall be at least the specified number of decibels below the main response within the bandwidth as specified.

3.6.25 <u>Output impedance (when specified, see 3.1</u>). When tested as specified in 4.8.26, the output impedance of the oscillator shall not exceed the limits specified.

3.6.26 <u>Re-entrant isolation (multi-output oscillators) (when specified, see 3.1)</u>. When measured as specified in 4.8.27, the re-entrant isolation between output ports of the multi-output oscillator at specified signal frequency and level shall be as specified.

3.6.27 <u>Output suppression (gated oscillator) (when specified, see 3.1)</u>. When measured as specified in 4.8.28, the reduction in output level when other output stages are cutoff by the specified gating signal shall be as specified.

3.6.28 <u>Startup time (when specified, see 3.1)</u>. When measured as specified in 4.8.29, the time interval for the oscillator output to achieve continuous waveform at 90 percent of final amplitude following application of power, unless otherwise specified, shall not exceed the value specified.

3.6.29 <u>Modulation-control input impedance (types 2, 5, and 6)</u>. When tested as specified in 4.8.30, the modulation-control input impedance across the modulation-control input terminals shall not exceed the limits specified for the range of input signal frequency specified (see 3.1).

3.6.30 Frequency deviation (types 2, 5, and 6) (see 4.8.31).

3.6.30.1 <u>Total deviation, dc control (see 6.3.37) (when not specified by 3.6.30.2)</u>. When measured as specified in 4.8.31.1, the total frequency deviation of the output signal from center frequency for the specified dc control voltage range shall exceed the limits specified (see 3.1).

3.6.30.2 <u>Total deviation, modulation (when specified, see 3.1)</u>. When measured as specified in 4.8.31.2, the total frequency deviation of the output signal from center frequency for the specified peak-to-peak modulation voltage and reference frequency shall exceed the limits specified (see 3.1).

3.6.30.3 <u>Deviation (slope) sensitivity (when specified, see 3.1)</u>. When measured as specified in 4.8.31.3, the frequency deviation (slope) sensitivity defined by the slope of the output frequency-control voltage transfer characteristic shall not exceed the limits specified.

3.6.30.4 <u>Deviation slope polarity</u>. When tested as specified in 4.8.31.4, the frequency deviation slope polarity corresponding to a positive increase of control voltage shall be as specified (see 3.1).

3.6.30.5 <u>Deviation linearity (see 6.3.38) (when not specified by 3.6.30.6)</u>. When tested as specified in 4.8.31.5, the deviation linearity of the output frequency control voltage transfer characteristic shall not exceed the value specified (see 3.1).

3.6.30.6 <u>Modulation distortion (see 6.3.39) (when specified, see 3.1)</u>. When measured as specified in 4.8.31.6, the modulation distortion resulting from nonlinearity of the output frequency-modulation voltage transfer characteristic shall not exceed the value specified for the modulation voltage magnitude and frequency specified (see 3.1).

3.6.30.7 <u>Modulation frequency response (see 6.3.40) (when specified, see 3.1)</u>. When tested as specified in 4.8.31.7, the modulation frequency response shall be flat within the limits specified over the frequency range specified (see 3.1).

3.6.31 <u>Accumulated time error (when specified, see 3.1)</u>. When tested as specified in 4.8.32, the time integral of fractional frequency change for a specified time interval resulting from specified time variant conditions (temperature, acceleration, radiation, etc.) shall not exceed the values specified.

3.6.32 Clock accuracy (type 7) (see 6.3.41).

3.6.32.1 <u>Clock accuracy (corrected pulse train output)</u>. When tested as specified in 4.8.33.1, the clock accuracy of a microcomputer compensated crystal oscillator with a time-corrected pulse train output, operating over the specified conditions (temperature, acceleration, radiation, etc.) for the specified duration after syntonization and synchronization, shall not exceed the value specified (see 3.1).

3.6.32.2 <u>Clock accuracy (digital time-of-day output)</u>. When tested as specified in 4.8.33.2, the clock accuracy of a microcomputer compensated crystal oscillator with a digital clock time of day output, operating over the specified conditions (temperature, acceleration, radiation, etc.) for the specified duration after syntonization and synchronization, shall not exceed the value specified (see 3.1).

3.6.33 Built-in-test (BIT) (types 4 and 6) (when specified, see 3.1).

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3.6.33.1 <u>BIT, oven operating temperature (when specified, see 3.1)</u>. When tested as specified in 4.8.34.1, the BIT output voltage levels corresponding to either a "fault" or an "operational" oven operating temperature condition shall not exceed the limits specified.

3.6.33.2 <u>BIT, oven supply voltage (when specified, see 3.1)</u>. When tested as specified in 4.8.34.2, the BIT output voltage levels corresponding to either a "fault" or an "operational" oven supply voltage condition shall not exceed the limits specified.

3.6.33.3 <u>BIT, R-F output voltage (when specified, see 3.1)</u>. When tested as specified in 4.8.34.3, the BIT output voltage levels corresponding to either a "fault" or an "operational" r-f output voltage condition at the threshold level specified shall not exceed the limits specified.

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3.6.34 Frequency aging (see 6.3.42).

3.6.34.1 <u>Frequency aging (types 1 and 2)</u>. When tested as specified in 4.8.35.1, the frequency aging at specified temperature shall not exceed the specified limits as follows:

- a. Maximum change over a 30 day period (see 3.1).
- b. Projected maximum change over a 1 year period (unless otherwise specified, e.g., 5 years, etc.) (see 3.1). Support data shall be provided to the qualifying activity showing that the projected aging performance will be met.

3.6.34.2 <u>Frequency aging (types 3, 4, 5, 6, 7, and 8)</u>. When tested as specified in 4.8.35.2, the frequency aging at a specified temperature shall not exceed the specified limits as follows:

- a. Total change from day 0 to day 30.
- b. Projected total change for 1 year (unless otherwise specified, e.g., 5 years, etc.) (see 3.1).
- c. Aging rate per day at day 30 (when specified, see 3.1).
- d. Change between any successive time periods (when specified, see 3.1).

3.6.35 <u>Input power aging (types 4 and 6) (see 6.3.43) (when specified, see 3.1)</u>. When tested as specified in 4.8.36, the input power aging rate of a hermetic or high vacuum seal oven controlled crystal oscillator shall not exceed the value specified.

3.6.36 <u>Conducted interference (when specified, see 3.1)</u>. When tested as specified in 4.8.37, the conducted interference at the specified terminals of the oscillator shall not exceed the peak-to-peak ripple specified within the bandwidth specified.

3.6.37 <u>Frequency-environment tolerance (see 6.3.44</u>). When tested as specified in 4.8.38, the frequency deviation, referenced to an initial frequency, due to the specified environmental condition shall not exceed the limits specified (see 3.1).

3.6.38 Vibration.

3.6.38.1 <u>Vibration, sinusoidal (nonoperating)</u>. After undergoing the test specified in 4.8.39.1, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1), the requirements specified in 3.6.4, 3.6.20, and 3.6.37 shall be met. The requirements of 3.6.10 shall be met when specified.

3.6.38.2 <u>Vibration, sinusoidal (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.39.2, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1), during the test, the requirements specified in 3.6.4 and 3.6.20 shall be met. The requirements in 3.6.16.2 and 3.6.17.3 shall be met when specified.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.38.3 <u>Vibration, random (nonoperating) (when specified, see 3.1)</u>. After undergoing the test as specified in 4.8.39.3, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1), the requirements specified in 3.6.4, 3.6.20, and 3.6.37 shall be met.

3.6.38.4 <u>Vibration, random (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.39.4, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1), during the test, the requirements specified in 3.6.4 and 3.6.20 shall be met. The requirements in 3.6.16.2 shall be met when specified.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.39 <u>Acoustic noise (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.40, this oscillator shall be capable of operation. Unless otherwise specified (see 3.1) during the test, the requirements specified in 3.6.4 and 3.6.20 shall be met. The requirements in 3.6.16.3 shall be met when specified.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.40 Shock (specified pulse) (see 4.8.41).

3.6.40.1 <u>Shock (specified pulse) (nonoperating)</u>. After undergoing the test specified in 4.8.41.1, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1) the requirements specified in 3.6.1, 3.6.4, 3.6.9 (frequency-adjustable oscillators only), 3.6.13, 3.6.20, and 3.6.37 shall be met. The requirements of 3.6.10 shall be met when specified.

3.6.40.2 <u>Shock (specified pulse) (operating) (when specified, see 3.1)</u>. While undergoing the test specified in 4.8.41.2, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1) during the test, the requirements specified in 3.6.31 shall be met over the interval specified.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.41 Acceleration (when specified, see 3.1).

3.6.41.1 <u>Acceleration (nonoperating) (when specified, see 3.1)</u>. After undergoing the test specified in 4.8.42.1, the oscillator shall be capable of operation. The requirements specified in 3.6.1, 3.6.4, 3.6.20, and 3.6.37 shall be met.

3.6.41.2 <u>Acceleration (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.42.2, the oscillator shall be capable of operation at all acceleration levels to the maximum specified. Unless otherwise specified, during the test, the requirements specified in 3.6.4, 3.6.17.1, and 3.6.20 shall be met.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.42 <u>Explosion (operating) (when specified, see 3.1)</u>. When tested as specified in 4.8.43, the explosion mixture in the test chamber surrounding and external to the oscillator shall not explode, whether or not an explosion occurs within the oscillator. The oscillator shall be electrically operable after the test.

3.6.43 <u>Magnetic field (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.44, the oscillator shall be capable of operation. Unless otherwise specified (see 3.1) during the test, the requirements in 3.6.4 and 3.6.19 shall be met. The requirement of 3.6.18 shall be met when specified.

Unless otherwise specified (see 3.1), following the above tests, the requirements of 3.6.37 shall be met.

3.6.44 <u>Thermal shock (nonoperating)</u>. When tested as specified in 4.8.45, the oscillator shall not show a sign of mechanical damage. After the test, the requirements specified in 3.6.4, 3.6.20, and 3.6.37 shall be met. Unless otherwise specified (see 3.1), the requirements in 3.6.10 shall be met when specified.

3.6.45 Ambient pressure.

3.6.45.1 <u>Ambient pressure (nonoperating)</u>. When tested at the specified storage temperature (see 3.1) as specified in 4.8.46.1, the oscillator shall be capable of storage at a reduced pressure. Unless otherwise specified (see 3.1), after the test, the requirements specified in 3.6.4, 3.6.20, and 3.6.37 shall be met.

3.6.45.2 <u>Ambient pressure (operating) (when specified, see 3.1)</u>. While undergoing the test as specified in 4.8.46.2, the oscillator shall be capable of operation at all pressures from atmospheric pressure (101 kPa) to the pressure specified (see 3.1). Unless otherwise specified (see 3.1), during the test, the requirements specified in 3.6.4 and 3.6.20 shall be met.

Unless otherwise specified (see 3.1), following the above test, the requirements of 3.6.37 shall be met.

3.6.46 <u>Storage temperature</u>. After undergoing the test at the specified storage temperatures (see 3.1) as specified in 4.8.47, the requirements specified in 3.6.1, 3.6.4, 3.6.9 (frequency-adjustable oscillators only), 3.6.13, 3.6.20, and 3.6.37 shall be met. The requirements in 3.6.10 shall be met when specified.

3.6.47 <u>Radiation hardness (operating) (when specified, see 3.1)</u>. When tested as specified in 4.8.48, the oscillator shall meet the requirements specified below. Unless otherwise specified (see 3.1), after the radiation tests, the requirements specified in 3.6.4, 3.6.9 (frequency-adjustable oscillators only), 3.6.13, and 3.6.20 shall be met. The requirements of 3.6.10 and 3.6.31 shall be met when specified.

3.6.47.1 <u>Total dose (when specified, see 3.1)</u>. When tested as specified in 4.8.48.1, the radiation-induced changes in output frequency shall not exceed the values specified.

3.6.47.2 <u>Dose rate (when specified, see 3.1)</u>. When tested as specified in 4.8.48.2, the maximum radiation-pulse-induced changes in output frequency shall not exceed the values specified. The radiation-pulse-induced changes in frequency after the specified time interval shall not exceed the values specified. If specified (see 3.1), the accumulated time error (see 3.6.31) over the specified time interval shall not exceed the value specified.

3.6.47.3 <u>Neutrons (when specified, see 3.1)</u>. When tested as specified in 4.8.48.3, the neutron-induced changes in output frequency shall not exceed the values specified.

3.6.48 <u>Resistance to soldering heat</u>. After undergoing the test specified in 4.8.49, the oscillator shall be capable of operation. The requirements specified in 3.6.1, 3.6.4, 3.6.9 (frequency-adjustable oscillators only), 3.6.13, 3.6.20, and 3.6.37 shall be met. The requirements in 3.6.10 shall be met when specified.

3.6.49 <u>Moisture resistance (when specified, see 3.1)</u>. When tested as specified in 4.8.50, there shall be no resultant impairment or damage sufficient to cause failure of the oscillators. After the test, the requirements specified in 3.6.4, 3.6.20, and 3.6.37 shall be met.

3.6.50 <u>Salt atmosphere (corrosion)</u>. When tested as specified in 4.8.51, there shall be no warping, cracking, peeling, excessive corrosion or in the case of plated metals, corrosion which has passed through the plating and exposed the base metal. Unless otherwise specified (see 3.1), after the test, the requirements specified in 3.6.1, 3.6.4, 3.6.20, and 3.6.37 shall be met.

3.6.51 Terminal strength (lead integrity) (see 4.8.52).

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3.6.51.1 <u>Terminals</u>. When tested as specified in 4.8.52.1, the external terminals shall be firmly attached or embedded within the base or connector and shall be capable of withstanding the specified pull or bends (see 3.1) without evidence of damage. After this test, the requirements in 3.6.1 shall be met.

3.6.51.2 <u>Pins (when applicable)</u>. When tested as specified in 4.8.52.2, external pins shall be capable of withstanding the specified force (see 3.1) without evidence of damage. After this test, the requirements in 3.6.1 shall be met.

3.6.51.3 <u>Solder pads (when applicable</u>). When tested as specified in 4.8.52.3, the solder pads of leadless chip carrier and similar devices shall be capable of withstanding the specified delamination (peel) stress without any evidence of damage. After this test, the requirements in 3.6.1 shall be met.

3.6.52 <u>Solderability</u>. When tested as specified in 4.8.53, the terminals of the oscillators shall conform to the criteria specified in method 208 of MIL-STD-202.

3.6.53 <u>Resistance to solvents</u>. When tested as specified in 4.8.54, there shall be no evidence of physical damage and the marking shall remain legible.

3.6.54 <u>Fungus (when specified, see 3.1)</u>. All external materials shall be nonnutrient to fungus growth or shall be suitably treated to retard fungus growth. The manufacturer shall certify that all external materials are fungus resistant or shall perform the test specified in 4.8.55. There shall be no evidence of fungus growth on the external surfaces.

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3.7 <u>Marking</u>. Marking shall be in accordance with method 1 of MIL-STD-1285 and shall include the military PIN, source code, serial number (see 3.7.1), date code, the electrostatic discharge sensitivity identifier (see 3.7.3), and the "JAN" brand (see 3.7.4).

Date and source code shall be in accordance with NIL-STD-1285. At the option of the manufacturer, the military PIN may appear on two lines. In this event, the PIN shall be on successive lines and divided between the temperature range and frequency. Unless otherwise specified (see 3.1), the marking shall not be less than .035 inch (0.89 mm) in height and shall be arranged as illustrated (see 3.1). The following is an example of the complete marking:

12345	-	CAGE code
9224J	-	Date code and JAN marking
M55310/01-B01A	-	First part of military PIN
32K76800	-	Remainder of military PIN
XXXXXX	-	Serial number

The date code shall be the date of the final seal of the oscillator.

3.7.1 <u>Serial number</u>. Prior to post burn-in electrical testing, each oscillator shall be marked with a unique serial number assigned consecutively.

3.7.2 <u>Frequency offset at reference temperature (see 3.5.10.2) (when applicable)</u>. Frequency adjustable oscillators that are required to be calibrated to a frequency offset from nominal frequency, unique to each oscillator, shall be marked as follows:

±X.X Hz at XX°C

The frequency offset shall be rounded to the nearest tenth of a hertz unless otherwise specified.

3.7.3 <u>Electrostatic discharge sensitivity (ESD) identifier</u>. Oscillators shall be marked with a sensitive electronic device symbol as specified in MIL-STD-1285, or if room does not permit, the outline or solid form of an equilateral triangle (i.e., \triangle) shall be used and may also be used as a pin 1 identifier. The equilateral triangle will designate these oscillators as sensitive to ESD in the range of 0 - 1,999 volts and shall be handled as such.

3.7.4 <u>Electrostatic</u>

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<u>"JAN" brand</u>. The United States Government has adopted, and is exercising legitimate control over the certification marks "JAN" and "J", respectively to indicate that items so marked or identified are manufactured to, and meet all the requirements of military specifications. Accordingly, items acquired to, and meeting all of the criteria specified, herein and in applicable specifications shall bear the certification mark "JAN" except that items too small to bear the certification mark "JAN" shall be placed on the first line above or below the PIN or the "J" with the date code (example: J9230). Items furnished under contracts or orders which either permit or require deviation from the conditions or requirements specified herein or in applicable specifications shall not be are "JAN" or "J". In the event an item fails to meet the requirements of this specification and the applicable specification shell remove the "JAN" or the fails to meet the requirements of this specification and the upplicable specification shell not be used on products acquired to contractor drawings or specifications. The United States Government has obtained Certificate of Registration No. 504,860 for the certification mark "JAN".

3.7.5 <u>Beryllium oxide package identifier</u>. If an oscillator package contains beryllium oxide, the oscillator shall be marked with the designation 'BeO'.

3.8 <u>Workmanship</u>. Oscillators, including all parts, shall be manufactured, processed, and tested in a careful and workmanlike manner in accordance with good engineering practice, with the requirements of this specification and with the production practices, workmanship instructions, inspection and test procedures, and training aids prepared by the manufacturer in fulfillment of the product assurance program (see 4.1.2.1).

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4. QUALITY ASSURANCE PROVISIONS

4.1 <u>Responsibility for inspection</u>. Unless otherwise specified in the contract or purchase order, the contractor is responsible for the performance of all inspection requirements (examinations and tests) as specified herein. Except as otherwise specified in the contract or purchase order, the contractor may use his own or any other facilities suitable for the performance of the inspection requirements herein, unless disapproved by the Government. The Government reserves the right to perform any of the inspections set forth in this specification where such inspections are deemed necessary to ensure supplies and service conform to prescribed requirements.

4.1.1 <u>Responsibility for compliance</u>. All items shall meet all requirements of sections 3 and 5. The inspection set forth in this specification shall become a part of the contractor's overall inspection system or quality program. The absence of any inspection requirements in the specification shall not relieve the contractor of the responsibility of ensuring that all products or supplies submitted to the Government for acceptance comply with all requirements of the contract. Sampling inspection, as part of manufacturing operations, is an acceptable practice to ascertain conformance to requirements, however, this does not authorize submission of known defective material, either indicated or actual, nor does it commit the Government to accept defective material.

4.1.2 Quality.

4.1.2.1 <u>Product assurance program (PAP)</u>. A PAP shall be established to meet the requirements of MIL-STD-790 and as specified herein (see 3.2.1). Evidence of such compliance shall be verified by the qualifying activity of this specification as a prerequisite for qualification and continued qualification.

4.1.2.2 <u>Statistical process control (SPC)</u>. An SPC program shall be established and maintained in accordance with EIA-557. Evidence of such compliance shall be verified by the qualifying activity of this specification as a prerequisite for qualification and continued qualification.

4.1.3 <u>Test equipment and inspection facilities</u>. The manufacturer shall insure that test and measuring equipment and inspection facilities of sufficient accuracy, quality, and quantity are established and maintained to permit performance of required inspections. The establishment and maintenance of a calibration system to control the accuracy of the measuring and test equipment shall be in accordance with MIL-STD-45662.

4.2 <u>Classification of inspections</u>. The inspections specified herein are classified as follows:

- a. Materials inspection (see 4.4).
- b. Screening (see 4.5).
- c. Qualification inspection (see 4.6).
- d. Quality conformance inspection (see 4.7).

4.3 Inspection conditions.

4.3.1 <u>Standard test conditions</u>. Unless otherwise specified herein, inspections shall be performed in accordance with the test conditions specified in the "GENERAL REQUIREMENTS" of the applicable military standard, i.e., NIL-STD-202, NIL-STD-810, or NIL-STD-883. When a standard test method is not specified, the standard test conditions of NIL-STD-202 shall apply.

4.3.2 <u>Test fixture</u>. Each test shall be performed with the oscillator mounted in the appropriate test fixture.

4.3.3 <u>Special test methods</u>. Special test procedures are applicable only to special purpose items. These special procedures must be specified in any acquisition documents. However, all test procedures not specified herein shall be verified and approved by the preparing activity prior to implementation. Prior approval of such test methods shall not be construed as a guarantee of the acceptance of the finished product.

4.3.4 <u>Equilibrium conditions</u>. Unless otherwise specified (see 3.1), all electrical tests shall be conducted under equilibrium conditions. When test conditions cause a significant change with time of the characteristic being measured, means of compensation for such effects should be specified; for example, the period of time that the oscillator shall be maintained at specified test conditions before making a measurement of output frequency.

4.3.5 <u>Standard environmental conditions</u>. Unless otherwise specified (see 3.1), all measurements shall be made at an ambient temperature of +25°C ±3°C. Unless otherwise specified (see 3.1), the standard point relative humidity (RH) shall be from 35 to 65 percent RH pre-seal, and from 35 to 75 percent RH post-seal.

4.3.6 <u>Power supplies</u>. DC power sources used in the testing of crystal controlled oscillators should not have a ripple content large enough to affect the desired accuracy of measurement; ac power sources should be transient-free. When the ripple or transient content of the power sources is critical to the measurement being performed, they must be fully defined in the specification sheet (see 3.6.2).

4.3.7 <u>Basic test conditions</u>. The basic test configuration for electrical performance measurement shall be as depicted on figure 1. Unless otherwise specified (see 3.1), all measurements shall be performed at specified nominal supply voltage and load impedance controlled to an accuracy of 1 percent.

4.3.8 <u>Precautions</u>. The measurement configurations and procedures for specific electrical tests (see 4.8) are the preferred methods. Should measuring apparatus modify the characteristic being inspected, due allowance must be made for any loading effects.

4.3.9 <u>Air flow conditions for temperature tests</u>. When oscillators are to be measured at temperatures other than +25°C ±3°C, adequate air circulation shall be provided to insure good temperature control. Temperature chambers shall be employed which provide an air flow sufficient to insure a gradient no greater than +2°C for the group of oscillators under test. Unless otherwise specified (see 3.1), in this preferred configuration, the temperature sensor shall be placed in the return flow of the air stream to measure reference point temperature. If still air is specified (see 3.1), or if forced air circulation affects oscillator performance, still air conditions may be simulated by enclosing the oscillator in a draft shield consisting of a thermally conducting box with the internal dimensions such as to provide an even temperature distribution around the oscillator. In this configuration, the reference point temperature is as measured at the draft shield, unless otherwise specified. When a draft shield is used, it must be retained for both high and low temperature tests and sufficient air flow maintained in the chamber.

4.3.10 <u>Precision of measurement</u>. The limits stated in the specification sheet are absolute. Tolerances on measurement instruments and methods shall be taken into account when determining actual experimental limits. Unless otherwise specified (see 3.1), the precision and accuracy of test methods and equipment used for the evaluation of oscillator performance shall be at least a factor of 10 better than the tolerances to be determined. (For example, a voltmeter accuracy of ±0.1 percent to determine level to a tolerance of ±1 percent).

4.4 <u>Materials inspection</u>. Materials inspection shall consist of certification supported by verifying data that the materials used in fabricating the oscillators are in accordance with the applicable referenced specifications or requirements prior to shipment of completed oscillators.

4.5 <u>Screening</u>. Oscillators to be delivered in accordance with this specification shall have been subjected to and passed all the screening tests of table 11 or table 111 for the applicable oscillator class and construction, in the order shown. Where a hybrid subassembly and a discrete subassembly are used in a single type of oscillator, the hybrid portion is to be subjected to screening in accordance with table 111, class B or S, as specified, except acceleration shall be 5,000 g's. This shall be done prior to assembly into the discrete component package. Electrical test parameters, values, limits, and conditions for the hybrid portion of the oscillator only shall be established by the manufacturer and approved by the qualifying activity. The complete oscillator shall then be subjected to the specified screening requirements for the discrete oscillator (see table 11). The electrical test parameters, values, limits, and conditions for the completed oscillator shall be as specified in the specification sheet (see 3.1).

TABLE 11. Screening (100 percent) for oscillators of discrete component construction. 1/

Test inspection	Class S	Class B
	method-condition	method-condition
Random vibration	MIL-STD-202, method 214, condition I-B, duration 5 minutes per axis	N/A
Thermal shock	MIL-STD-202, method 107, condition A-1	MIL-STD-202, method 107, condition A
Electrical test: Input current-power Output waveform Output voltage-power As specified	4.8.5 4.8.20 4.8.21 3.1	 3.1
Burn-in (load)	Maximum specified oper- lating temperature (see 3.1), nominal supply voltage and burn-in load, 240 hours minimum	Maximum specified oper- ating temperature (see 3.1), nominal supply voltage and burn-in load, 160 hours minimum
Electrical test: Input current-power Output waveform Output voltage-power As specified	4.8.5 4.8.20 4.8.21 3.1	4.8.5 4.8.20 4.8.21 3.1
Seal test	NIL-STD-202, method 112, (see 4.8.2)	Mil-STD-202, method 112, (see 4.8.2)
Radiographic <u>2</u> /	MIL-STD-202, method 209	N/A

<u>1</u>/ Includes mixed construction technology (see 4.5).

2/ Unless otherwise specified (see 3.1), the unit shall have one view taken with the x-ray penetrating in the Y direction (perpendicular to the largest package surface) and a second view 90° relative to the first view. Radiographic examination and acceptance criteria shall be as specified (see 3.1).

Test inspection	Class S method-condition	Class B method-condition	
Nondestructive bond pull	MIL-STD-883, method 2023	N/A	
Internal visual	(see 4.5.1)	(see 4.5.1)	
Stabilization bake <u>1</u> / (prior to seal)	MIL-STD-883, method 1008, condition C (+150°C), 48 hours minimum	MIL-STD-883, method 1008, condition C (+150°C), 24 hours minimum	
Thermal shock	MIL-STD-883, method 1011, condition A	H/A	
Temperature cycling	MIL-STD-883, method 1010, condition B	MIL-STD-883, method 1010, condition B	
Constant acceleration	MIL-STD-883, method 2001, condition A, Y ₁ only (5000 g's)	MIL-STD-883, method 2001, condition A, Y ₁ only (5000 g's)	
Seal (fine and gross leak) <u>2</u> /	(see 4.8.2.2.2)	(see 4.8.2.2.2)	
Particle impact noise detection (PIND)	MIL-STD-883, method 2020, condition B	N/A	
Electrical test: Input current-power Output waveform Output voltage-power As specified	4.8.5 4.8.20 4.8.21 3.1	 3.1	
Burn-in (load)	+125°C, nominal supply voltage and burn-in load, 240 hours minimum	+125°C, nominal supply voltage and burn-in load, 160 hours minimum	
Electrical test:	Nominal and extreme supply voltages, specified load, +23°C and temperature extremes, record all test parameters by serial number.	Nominal supply voltage, specified load, +23°C and verify frequency at the temperature extremes.	
Input current-power Output waveform Output voltage-power As specified	4.8.5 4.8.20 4.8.21 3.1	4.8.5 4.8.20 4.8.21 3.1	
Radiographic <u>3</u> /	MIL-STD-883, method 2012	N/A	

TABLE III. Screening (100 percent) for oscillators of hybrid construction.

1/ Vacuum bake and maintain oscillators in dry nitrogen atmosphere until sealed.

- $\overline{2}$ / For class S oscillators, the seal test may be performed in any sequence between the final electrical test and external visual but it shall be performed after all shearing and forming operations on the terminals. For class B oscillators, the seal test shall be performed in any sequence between the constant acceleration test and external visual except that they shall be performed after all shearing and forming operations on the terminals.
- 3/ At the option of the contractor, radiographic inspection may be performed following PIND test to expedite screening test completion. Recorded screening data shall indicate the test sequence.

4.5.1 <u>Internal visual inspection for crystal oscillators of hybrid construction</u>. Internal visual inspection shall be in accordance with NIL-SID-883, methods 2017 and 2032, and supplemented by the manufacturer's documentation for crystal attachment. During the time interval between final internal visual inspection and preparation for sealing, hybrid crystal oscillators shall be stored in a dry, nitrogen environment, or in a vacuum bake oven as specified in table 111. The following details shall apply:

- a. The first internal visual inspection shall be performed prior to installation of the crystal element.
- b. The final internal visual inspection shall occur after crystal resonator installation and prior to cover seal.
- 4.5.2 Pre burn-in electrical testing.
 - a. Pre burn-in electrical testing is optional for class B crystal oscillators except where delta limit measurements are required. However, crystal oscillators may be tested to remove defects prior to further screening and to form a basis for application of percent defective allowable (PDA) criteria.
 - b. Electrical characteristics to be measured shall be as specified in table II, table III, and the applicable specification sheet (see 3.1).

4.5.3 <u>Burn-in</u>. Unless otherwise specified in the specification sheet, PDA shall be applicable only to +23°C and/or +25°C static tests, as specified, and the 100 percent nondestructive bond pull test (for class "S" oscillators only). If not otherwise specified, the maximum PDA for class 8 shall be 10 percent (or one oscillator, whichever is greater). The maximum PDA for class S shall be 2 percent (or one oscillator, whichever is greater). The maximum PDA for class S shall be 2 percent (or one oscillator, whichever is greater). The period of failure accountability shall include burn-in through final electrical test. The nondestructive bond pull test, for class "S" oscillators only, shall have a separate PDA requirement of 5 percent (or one oscillator, whichever is greater).

4.5.4 Lots resubmitted for burn-in. Burn-in lots may be resubmitted to burn-in one time only. Resubmitted lots shall be kept separate from new lots and shall be inspected for all specified characteristics using a tightened inspection PDA. For 10 percent PDA use tightened PDA of 7 percent, for 5 percent use tightened PDA of 3 percent, for 3 percent and for 2 percent use a tightened PDA of 1.5 percent.

4.5.5 <u>Failures</u>. All oscillators that fail any test criteria in the screening sequence shall be removed from the lot at the time of observation or immediately at the conclusion of the test in which failure was observed. Once rejected and verified as a failure, acceptable rework may be performed in accordance with the following:

- a. Rework of hybrid oscillators shall be in accordance with 3.2.1.2.4.
- b. Following rework, hybrid oscillators shall be subjected to all tests in the screening table (see table III) beginning with the test at which failure occurred.

27

4.6 <u>Qualification inspection</u>. Qualification inspection shall be performed at a laboratory acceptable to the government (see 6.4) on sample units produced with equipment and procedures normally used in production.

4.6.1 <u>Sample</u>. The number of sample units comprising a sample of crystal oscillators to be subjected to qualification inspection shall be as specified in appendix B. Sample units shall have previously passed all the requirements of the screening tests of table II or table III for the class and type of construction for which qualification is requested.

4.6.2 <u>Test routine</u>. Qualification samples shall be subjected to the tests of table IV. All sample units shall be subjected to the tests of group I and II and subgroup 1 of group III. The samples shall then be divided into three groups and subjected to the tests of subgroups 2, 3, and 4 of group III, in the order shown. Subgroup 5 inspections, for hybrid construction oscillators only, shall be performed on three samples (or five samples, see table IV), and may either be selected from samples which have previously been subjected to other qualification inspections or may be additional samples.

4.6.3 <u>Failures</u>. Failures in excess of those allowed in table IV shall be cause for refusal to grant qualification.

4.6.4 <u>Retention of qualification</u>. To retain qualification, the contractor shall forward a report at 24-month intervals to the qualifying activity. The qualifying activity shall establish the initial reporting date. The report shall consist of:

- a. The results of the test performed for inspection of product for delivery (groups A and B), indicating, as a minimum, the number of lots that have passed, the number that have failed, and the group which they failed. The results of tests of all reworked lots shall be identified and accounted for.
- b. The results of tests performed for periodic inspection (group C, see 4.7.2.1), including the number and mode of failures. The test report shall include results of all periodic inspection tests performed and completed during the 24-month period. If the test results indicate nonconformance with specification requirements, and corrective action acceptable to the qualifying activity has not been taken, action may be taken to remove the failing product from the qualified products list.
- c. The results of a failure analysis conducted on all failed units establishing the cause of failure and the corrective actions that would eliminate subsequent failures of a similar type.

Failure to submit the report within 60 days after the end of the 24-month period may result in loss of qualification for the product. In addition to the periodic submission of inspection data, the contractor shall immediately notify the qualifying activity at any time during the 24-month period that the inspection data indicates failure of the qualified product to meet the requirements of this specification.

In the event that no production occurred during the reporting period, a report shall be submitted certifying that the company still has the capabilities and facilities necessary to produce the item. If during three consecutive reporting periods there has been no production, the manufacturer may be required, at the discretion of the qualifying activity, to submit oscillators of the same type to testing in accordance with groups A, B, and C tests.

4.7 <u>Quality conformance inspection</u>.

4.7.1 <u>Inspection of product for delivery</u>. Inspection of product for delivery shall consist of the screening tests (see 4.5) and groups A and B inspections. Class S oscillators shall not be delivered until they have successfully completed groups A and B inspections. Unless otherwise specified, class B oscillators may be delivered after sample units have passed group A inspection and prior to sample units completing group B inspection (see 4.7.1.3).

4.7.1.1 Production and inspection lot.

4.7.1.1.1 <u>Production lot</u>. A production lot shall consist of all oscillators covered by a single specification sheet and single PIN. Manufacture of all parts in the lot shall have been started, processed, assembled, and tested as a group. Lot identity shall be maintained throughout the manufacturing cycle.

TABLE IV. Qualification inspection.

Inspection	Requirement paragraph	Test paragraph	Number of sample units	Number o failures
	_			
GROUP I				
Visual and mechanical inspection	3.1, 3.4, 3.5, 3.7, 3.8	4.8.1	All sample units	0
Seal	3.6.1	4.8.2		
Electricals	3.6.2 through	4.8.3		
	3.6.33.3, as	through		
	applicable	4.8.34.3		
GROUP 11				
Frequency aging	3.6.34	4.8.35	All sample units	0
Input power aging (types 4 and 6)	3.6.35	4.8.36]	
(when specified)		1		
GROUP III				
Subgroup 1				
Conducted interference (when specified)	3.6.36	4.8.37	All sample units	0
Vibration	3.6.38	4.8.39		
Acoustic noise (when specified)	3.6.39	4.8.40		
Shock	3.6.40	4.8.41		
Acceleration (when specified)	3.6.41	4.8.42		
Explosion (when specified)	3.6.42	4.8.43		
Subgroup 2				
Magnetic field (operating)		4.8.44	One-half of sample units	0
(when specified)	3.6.43	4.8.45	Une-math of sample units	
Thermal shock	3.6.44	4.8.46		
Ambient pressure	13.6.46	4.8.47		i
Storage temperature	3.0.40	4.0.47		
Radiation hardness (operating)	3.6.47	6.8.48		i i
(when specified)	13.0.4/	4.0.40		
Subgroup 3				
Resistance to soldering heat	3.6.48	4.8.49	One-fourth of sample units	0
Moisture resistance	3.6.49	4.8.50		
Salt atmosphere	3.6.50	4.8.51		
Subgroup 4				
 Terminal strength (lead integrity)	3.6.51	4.8.52	One-fourth of sample units	0
Solderability	3.6.52	4.8.53		
Resistance to solvents	3.6.53	4.8.54		
Fungus (when specified)	3.6.54	4.8.55		
Subgroup 5				
Internal water vapor content	3.5.1.2	4.8.56	3 sample units	0
(applicable to hybrid construction		1	or	
only)	Ì	1	5 sample units	1

29

4.7.1.1.2 <u>Inspection lot</u>. A inspection lot shall consist of all oscillators of the same type produced under essentially the same conditions, and offered for inspection at one time over a period not to exceed 13 weeks. For class S oscillators, an inspection lot shall consist of one production lot.

4.7.1.2 <u>Group A inspection</u>. Group A inspection shall consist of the inspections specified in table V, in the order shown. Manufacturer has option for sequence in which electrical tests are performed.

4.7.1.2.1 Sampling procedure (subgroup 1).

4.7.1.2.1.1 <u>Class B oscillators</u>. A sample of parts shall be randomly selected from each inspection lot in accordance with table VI. If one or more defects are found, the lot shall be retested or re-examined for that characteristic which contributed to the failure. After corrective action and removal of defects, a new sample of parts shall be randomly selected in accordance with table VI. If one or more defects are found in the second sample, the lot shall be rejected and shall not be supplied to this specification.

4.7.1.2.1.2 <u>Class S oscillators</u>. Class S oscillators shall be subjected to 100 percent inspection as specified in table V. Rejects shall be removed from the lot. Lots having more than 5 percent or 1 unit rejects, whichever is greater, shall not be furnished on the contract or purchase order.

4.7.1.2.2 <u>Sampling procedure (subgroup 2)</u>.

4.7.1.2.2.1 <u>Class B oscillators</u>. A sample of parts shall be randomly selected from each inspection lot in accordance with table VI. If one or more defects are found, the lot shall be rescreened and defects removed. After screening and removal of defects, a new sample of parts shall be randomly selected in accordance with table VI. If one or more defects are found in the second sample, the lot shall be rejected and shall not be supplied to this specification.

4.7.1.2.2.2 <u>Class S oscillators</u>. Class S oscillators shall be subjected to 100 percent inspection as specified in table V. Rejects shall be removed from the lot.

4.7.1.2.3 <u>Sampling procedure (subgroup 3)</u>. Five samples shall be selected randomly from each inspection lot and subjected to the subgroup 3 solderability test. The manufacturer may use electrical rejects from the subgroup 1 tests and/or screening rejects that have been subjected to burn-in, as a minimum, for all or part of the samples to be used for solderability testing. As an alternative, the manufacturer may use empty test packages for the solderability test provided the empty packages have been subjected to the same environmental conditions and processes as the completed oscillators. If there is one or more defects, the lot shall be considered to have failed.

4.7.1.2.3.1 <u>Rejected lots (subgroup 3)</u>. In the event of one or more defects, the inspection lot is rejected. The manufacturer may use one of the following options to rework the lot:

- a. Five samples from each production lot that was used to form the failed inspection lot shall be individually submitted to the solderability test as required in 4.7.1.2.3. Production lots that pass the solderability test are available for shipment. Production lots failing the solderability test can be reworked only if submitted to the solder dip procedure in 4.7.1.2.3.1b.
- b. The manufacturer submits the failed lot to a 100 percent solder dip using an approved solder dip process in accordance with 3.5.4.2a. Following the solder dip process, the subgroup 1 electrical inspections and the subgroup 3 solderability test shall be repeated on the lot. If there are one or more defects, the lot shall be considered rejected and shall not be furnished against the requirements of this specification.

4.7.1.2.4 <u>Disposition of sample units</u>. Sample units which have been subjected to subgroups 1 and 2 of the group A inspection may be delivered on the contract after successful completion of group B tests. Oscillators subjected to subgroup 3 of the group A inspection shall not be delivered on a contract or purchase order.

Inspection	Requirement paragraph	Test method paragraph	Sampling procedure
Subgroup 1			
Electricals	3.6.2 through 3.6.33.3 (as applicable)	4.8.3 through 4.8.34.3	4.7.1.2.1
Subgroup 2		4.0.54.5	
Visual and mechanical	3.1, 3.4, 3.5, 3.7, and 3.8	4.8.1	4.7.1.2.2
<u>Subgroup 3</u>			
Solderability 1/	3.6.52	4.8.53	4.7.1.2.3

TABLE V. Group A inspection.

1/ This solderability test can be eliminated if the manufacturer has demonstrated process control under the SPC program (see 3.2.2), and has been approved by the qualifying activity. If the design, material, construction, or processing of the part is changed or, if there are any quality problems, or failures, the qualifying activity may require resumption of the specified testing. Deletion of testing does not relieve the manufacturer from meeting the test requirement in case of dispute.

Lot Siz e	Sample Size			
	Group A		Group B	
	Subgroup 1	Subgroup 2 Class B	Class B	
	Class B			
1 to 13	100 percent	100 percent	100 percent	
14 to 50	100 percent	13	13	
51 to 150	50	13	13	
151 to 280	50	20	20	
281 to 500	50	29	29	
501 to 1,200	75	34	34	
1,201 to 3,200	116	42	42	
3,201 to 10,000	116	50	50	
10,001 to 35,000	135	60	60	
35,001 to 150,000	170	74	74	
150,001 to 500,000	200	90	90	
500,001 and over	244	102	102	

TABLE VI. Groups A and B, zero defect sampling plan.

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4.7.1.3 <u>Group B inspection</u>. Group B inspection shall consist of the frequency aging test and input power aging test (when specified), (see 3.6.34, 3.6.35, 4.8.35, and 4.8.36).

4.7.1.3.1 <u>Class B oscillators</u>. A sample of parts shall be randomly selected from inspection lots that have currently passed group A inspection in accordance with table VI. If one or more defects are found, the sample has failed. Group B inspection for class B oscillators must be completed within 6 months of shipment. If the manufacturer can demonstrate that the group B inspections have been performed five consecutive times with zero failures, the frequency of these tests, with the approval of the qualifying activity can be performed on a 6-month basis. If the design, material, construction, or processing of the part is changed or, if there are any quality problems or failures, the qualifying activity may require resumption of the original test frequency.

4.7.1.3.1.1 <u>Failed sample(s)</u>. If a sample fails to pass group B inspection, the cognizant inspection activity and the qualifying activity shall be notified immediately. The manufacturer shall take corrective action on the materials or processes, or both, as warranted, and on all units of product which can be corrected and which were manufactured under essentially the same conditions, with essentially the same materials, process, etc., and which are considered subject to the same failure. Delivery of class B oscillators prior to completion of group B testing shall be discontinued until corrective action, acceptable to the government, has been taken. As an alternative, if the inspection lots have not been shipped, the inspection lots shall be subjected to 100 percent inspection and defectives removed.

4.7.1.3.2 <u>Class S oscillators</u>. Group B inspection for class S oscillators shall consist of 100 percent inspection.

4.7.1.3.2.1 <u>Rejected lots</u>. Lots having more than 5 percent total rejects or 1 reject, whichever is greater, shall not be furnished on contracts.

4.7.1.3.3 <u>Disposition of sample units</u>. Sample units which have passed group B inspection may be delivered on the contracts or purchase order if the lot is accepted.

4.7.2 <u>Periodic inspection</u>. Periodic inspection shall consist of group C inspection. Except where these inspections show noncompliance with the applicable requirements (see 4.7.2.1.4), delivery of products which have passed groups A and B shall not be delayed pending the results of these periodic inspections.

4.7.2.1 <u>Group C inspection</u>. Group C inspection shall consist of the test specified in table VII, in the order shown. Group C inspection shall be performed on sample units randomly selected from inspection lots which have currently passed the groups A and B inspections.

- a. If class S oscillators are produced, class S oscillators shall be used in retaining qualification for class S or class B oscillators. Class B oscillators will be used in retaining qualification for class B only.
- b. Further performance of group C tests shall be required by the qualifying activity for any of the following reasons:
 - (1) Repeated failures of the same group A tests (four or more lots).
 - (2) Unsatisfactory reports confirmed by the qualifying activity.
 - (3) Change of oscillator design.
 - (4) Change of material.
 - (5) Change of processes.

4.7.2.1.1 <u>Sampling plan</u>. A minimum of eight sample units shall be selected from lots produced during the 12-month period following qualification. To retain qualification for the frequency and temperature range for which qualification was originally granted, samples shall be selected on the following basis:

- a. Four sample units from lots produced having the lowest frequency, widest operating temperature range, and most stringent frequency-temperature accuracy over that range.
- b. Four sample units having the lowest frequency, widest operating temperature range, and most stringent frequency-temperature accuracy over that range from each group of lots produced of the intermediate frequencies. Groups are determined on the following basis:
 - (1) A crystal resonator change, for example, fundamental mode, third or fifth overtone, etc.
 - (2) A change in the printed wiring board for discrete component construction or the substrate for hybrid construction.
 - (3) A change in the component configuration on the printed wiring board or substrate.
- c. Four sample units from lots produced having the highest frequency, widest operating temperature range, and most stringent frequency-temperature accuracy over that range.

4.7.2.1.2 <u>Failures</u>. If one or more sample units fail to pass group C inspection, the sample lot shall be considered to have failed. In that event, the qualifying activity shall be notified immediately (see 4.6.4).

4.7.2.1.3 <u>Disposition of sample units</u>. Sample units which have been subjected to group C inspection shall not be delivered on the contract or purchase order, unless otherwise specified.

4.7.2.1.4 <u>Noncompliance</u>. If a sample fails to pass group C inspection, the manufacturer shall notify the qualifying activity of such failure and take corrective action on the materials or processes, or both, as warranted, and on all units of product which can be corrected and which were manufactured using essentially the same materials and processes, and which are considered subject to the same failure. Acceptance and shipment of the product shall be discontinued until corrective action, acceptable to the qualifying activity has been taken. After the corrective action has been taken, group C inspection shall be repeated on additional sample units (all tests and inspections, or the test which the original sample failed, at the option of the qualifying activity). Groups A and B inspections may be reinstituted; however, final acceptance and shipment shall be withheld until the group C inspection has shown that the corrective action was successful. In the event of failure after reinspection, information concerning the failure shall be furnished to the qualifying activity.

4.7.3 <u>Inspection of packaging</u>. The sampling and inspection of the preservation and interior packing, and container marking shall be in accordance with the groups A and B quality conformance inspection requirements of MIL-P-116. The sampling and inspection of the packing and marking for shipment and storage shall be in accordance with the specification and the marking requirements of MIL-STD-129.

4.8 Methods of inspection.

4.8.1 <u>Visual and mechanical inspection</u>. Oscillators shall be inspected to verify that the material, design, construction, physical dimensions, marking, and workmanship are in accordance with the applicable requirements (see 3.1, 3.4, 3.5, 3.7, and 3.8).

4.8.2 <u>Seal (see 3.6.1)</u>. Oscillators shall be tested in accordance with 4.8.2.1, 4.8.2.2, or 4.8.2.3, as applicable.

4.8.2.1 <u>O-ring-solder seal (nonhermetic) (see 3.6.1.1)</u>. Oscillators employing O-ring seal or solder seal or combinations of both, shall be tested in accordance with MIL-STD-202, method 112. The following details shall apply:

Test condition D or E.

4.8.2.2 <u>Hermetic seal (see 3.6.1.2)</u>. Hermetic seal oscillators shall be tested in accordance with 4.8.2.2.1 or 4.8.2.2.2, as applicable. The fine leak test shall always precede the gross leak test.

33

Inspection	Requirement paragraph	Test paragraph
<u>Subgroup 1</u> (all sample units)		
Conducted interference (when specified)	3.6.36	4.8.37
Vibration	3.6.38	4.8.39
Acoustic noise (when specified)	3.6.39	4.8.40
Shock	3.6.40	4.8.41
Acceleration (when specified)	3.6.41	4.8.42
Explosion (when specified)	3.6.42	4.8.43
Subgroup 2 (one-half of sample units)		
Magnetic field (operating) (when specified)	3.6.43	4.8.44
Thermal shock	3.6.44	4.8.45
Ambient pressure	3.6.45	4.8.46
Storage temperature	3.6.46	4.8.47
Radiation hardness (operating) (when specified)	3.6.47	4.8.48
Subgroup 3 (one-fourth of sample units)		
Resistance to soldering heat	3.6.48	4.8.49
Moisture resistance	3.6.49	4.8.50
Salt atmosphere	3.6.50	4.8.51
<u>Subgroup 4</u> (one-fourth of sample units)		
 Terminal strength (lead integrity)	3.6.51	4.8.52
Resistance to solvents	3.6.53	4.8.54
Fungus (when specified)	3.6.54	4.8.55

TABLE VII. Group C inspection.

4.8.2.2.1 <u>Discrete or mixed construction</u>. Hermetic seal oscillator using discrete or mixed construction technology (see 3.5.6.1 and 3.5.6.3) shall be tested in accordance with MIL-STD-202, method 112. The following details shall apply:

- a. Fine leak:
 - (1) Test condition C.
 - (2) Procedure:
 - (a) III (without tracer gas as normally supplied).
 - (b) IV (with tracer gas as normally supplied).
 - (3) Leakage rate sensitivity: 10 percent of specified leak rate.
- b. Gross leak:

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Test condition D or E.

4.8.2.2.2 <u>Hybrid construction</u>. Hermetic seal oscillators using hybrid construction (see 3.5.6.2) shall be tested in accordance with MiL-STD-883, method 1014. The following details shall apply:

a. Fine leak: Test condition A1, A2, or B.

b. Gross leak: Test condition C.

NOTE: MIL-STD-202, method 112, test condition D or E may be substituted for the fine leak and MIL-STD-202, method 112, test condition E for the gross leak tests, above.

4.8.2.3 <u>High vacuum seal (types 4 and 6) (when specified, see 3.1) (see 3.6.1.3)</u>. High vacuum seal oscillators shall be tested in accordance with MIL-STD-883, method 1014. The test details of 4.8.2.2.2 shall apply except that the radioisotope fine leak counting station (test condition B) shall have a minimum sensitivity corresponding to a leak rate of 10⁻¹¹ atm cc/s of krypton⁸⁵.

NOTE: If a leakage rate lower than 1 x 10^{-10} atm cc/s is specified, the leak detection method to be employed shall be approved by the qualifying activity.

4.8.3 Supply voltage.

4.8.3.1 Oscillator supply voltage (see 3.6.2.1). Loaded as specified (see 3.1), the applicable voltage magnitude, tolerance, polarity, regulation, peak-to-peak ripple and ripple frequency, noise, and ramp rate (turn-on) shall be measured across the input terminals of the oscillator.

4.8.3.2 <u>Oven supply voltage (types 4 and 6) (see 3.6.2.2)</u>. With the oscillator energized as in 4.8.3.1, the applicable oven voltage magnitude, tolerance, polarity, regulation, peak-to-peak ripple and ripple frequency, and noise shall be measured across the input terminals of the oven.

4.8.3.3 <u>Modulation-control input voltage (types 2, 5, and 6) (see 3.6.2.3)</u>. With the oscillator energized as in 4.8.3.1, the applicable modulation magnitude, tolerance, polarity, frequency limits, dc level (imits or dc control magnitude, polarity, range, peak-to-peak ripple and ripple frequency, regulation, and noise shall be measured across the input terminals of the oscillator.

4.8.4 <u>Overvoltage survivability (see 3.6.3)</u>. The oscillator shall be subjected to an overvoltage 20 percent above the maximum specified supply voltage, for a duration of 1 minute, unless otherwise specified. The applied overvoltage for oscillators employing CMOS devices shall not exceed 16.5 volts.

4.8.5 Input current-power.

4.8.5.1 <u>Oscillator input current-power (see 3.6.4.1)</u>. The input current shall be measured or power calculated (P = EI) from measured values of voltage and current.

4.8.5.2 <u>Oven input current-power (types 4 and 6) (see 3.6.4.2)</u>. The oven input current shall be measured or oven input power calculated ($P \approx EI$) from measured values of voltage and current. For peak current-power measurement, it may be necessary to use a recording type instrument for the measurement of voltage and current in order to determine transient values with adequate resolution. The following details shall apply:

a. Measurement temperature: Lowest specified ambient (unless otherwise specified, see 3.1).

b. Stabilization time: 60 ±10 minutes (unless otherwise specified, see 3.1).

4.8.5.3 <u>Syntonization energy (type 8) (see 3.6.4.3)</u>. The input current I(t) of the rubidium reference shall be measured as a function of time during the syntonization period t, and the syntonization energy, Q, shall be calculated from measured values of I(t) and the supply voltage E as follows:

$$Q = E \int_0^t I(t) dt$$

which is approximated using the Trapezoidal Rule for n = 10 equally spaced intervals, unless otherwise specified, see 3.1.

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The following detail shall apply:

Measurement temperature: Lowest specified ambient.

NOTE: The crystal oscillator portion of the RbXO shall have been fully stabilized and the rubidium reference shall be temperature stabilized in the OFF state prior to the test. Termination of the syntonization period shall be automatic.

4.8.6 <u>Initial accuracy at reference temperature (when specified, see 3.1) (see 3.6.5)</u>. The initial frequency accuracy shall be tested immediately following stabilization at the reference temperature. Unless otherwise specified (see 3.1), frequency-adjustable oscillators shall be adjusted (calibrated) to nominal frequency or marked frequency offset, as applicable, in the interval between completion of stabilization and the measurement of final output frequency. The following details shall apply:

- a. Measurement temperature: +25°C ±1°C (unless otherwise specified, see 3.1).
- b. Stabilization time: Types 1 and 2, 8 ±5 minutes, types 3, 5, and 7, 20 ±5 minutes, types 4 and 6, 60 ±10 minutes, type 8, immediately after syntonization to the rubidium reference (unless otherwise specified, see 3.1).

Qualification data in support of showing the capability for meeting this requirement within 30 days or the specified period (see 3.1) following shipment of nonfrequency-adjustable oscillators shall take into account the frequency changes measured in the group B frequency aging test.

4.8.7 Frequency adjustment (see 3.6.6).

4.8.7.1 <u>Mechanical-frequency-adjustment (frequency-adjustable oscillators) (see 3.6.6.1)</u>. The mechanical frequency-adjustment range and resolution shall be tested following stabilization. It shall be determined by frequency measurement that the output signal is capable of being set to either nominal frequency or marked frequency offset, as applicable, with the specified resolution and adjusted over the specified frequency adjustment range. For voltage controlled oscillators, the modulation/control voltage input terminal shall have applied to it the specified dc reference level voltage conditions (see 3.6.2.3). The test details of 4.8.6 shall apply.

4.8.7.2 <u>Electrical-frequency-control (when specified, see 3.1) (see 3.6.6.2)</u>. The electronic frequency control range corresponding to the specified input control voltage (see 3.6.2.3) shall be determined by frequency measurement. The test details of 4.8.6 shall apply.

4.8.8 <u>Frequency warmup (when specified, see 3.1) (see 3.6.7)</u>. The time for an oscillator output to stabilize within specified limits shall be measured. After energizing the oscillator, the frequency shall be recorded at intervals not to exceed one-tenth of the specified warmup time. If the frequency crosses the tolerance limits more than once, the longest crossover time shall determine the warmup. Figure 2 shows a typical plot of output frequency after "turn on". The warmup time, t_g , is the time taken for the output frequency (defined to occur at time t_f) within the tolerances specified. The following details shall apply:

- a. Measurement temperature: As specified (see 3.1).
- b. Time (t_f) to final frequency (unless otherwise specified, see 3.1):
 - (1) Types 1 and 2, 10 ±3 minutes.
 - (2) Types 3, 5, 7, 20 ±5 minutes.

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(3) Types 4, 6, and 8 (OCXO only), 60 ±10 minutes.

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4.8.9 <u>Initial frequency aging (types 4 and 6) (when specified, see 3.1) (see 3.6.8)</u>. Prior to the test, the unenergized oscillator shall be subjected to the specified storage temperature for the storage period specified. Within 24 hours of the end of the storage period, the oscillator shall be brought to thermal equilibrium at the measurement temperature, and shall be energized. The oscillator's frequency shall be measured at specified intervals over the initial aging period(s). The maximum frequency change, or maximum rate of frequency change (if specified, see 3.1), measured over this period shall not exceed the value(s) specified. The following details shall apply:

a. Storage period and temperature: 24 hours at -40°C (unless otherwise specified, see 3.1).

b. Start of initial aging period: End of specified warmup time (unless otherwise specified, see 3.1).

c. Duration of initial aging period: 48 hours (unless otherwise specified, see 3.1).

d. Neasurement temperature: +25°C ±1°C (unless otherwise specified, see 3.1).

e. Measurement interval: 1 hour (unless otherwise specified, see 3.1).

NOTE: The initial frequency aging test may be performed as an extension of the frequency warmup test (see 4.8.8) provided the specified storage conditions are met.

4.8.10 Initial frequency-temperature accuracy (see 3.6.9).

4.8.10.1 <u>Initial frequency-temperature accuracy (one-half temperature cycle) (see 3.6.9.1)</u>. Prior to this test, frequency-adjustable oscillators shall be stabilized at the specified reference temperature and calibrated to nominal frequency (or marked frequency offset if applicable).

Initially, the oscillator shall be stabilized at the lowest specified temperature. After stabilization, the first frequency and temperature are recorded. The temperature is then increased in steps, as specified, allowing stabilization after each step before data is taken, until the highest temperature is reached. The initial frequency-temperature accuracy is determined by:

f-T accuracy = \pm MAX [δf_{max} , δf_{min}]

where MAX [] is the maximum value among δf_{max} and δf_{min} . δf_{max} and δf_{min} are computed as follows:

 $\delta f_{max} = | (f_{max} - f_{nom})/f_{nom}|$

 $\delta f_{min} = | (f_{min} - f_{nom})/f_{nom}|$

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where f_{max} is the maximum frequency measured during the temperature run, f_{min} is the minimum frequency measured during the temperature run, and f_{nom} is the nominal frequency. The following details shall apply:

- a. Calibration (frequency-adjustment) temperature (when applicable): +25°C ±1°C (unless otherwise specified, see 3.1).
- b. Temperature increment: As specified (see 3.1).

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c. DC reference level (types 2, 5, and 6): As specified (see 3.6.2.3). If not specified, set to center of control voltage range, e.g., if range is +2 volts to +6 volts, set to +4 volts.

Qualification data in support of showing the capability for meeting this requirement within the specified period following shipment of nonfrequency-adjustable oscillators shall take into account the frequency changes measured in the group B frequency aging test.

37

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4.8.10.2 <u>Initial frequency-temperature accuracy including hysteresis (when specified, see 3.1) (see 3.6.9.2</u>). The oscillator shall be tested over a complete temperature cycle. Initially it shall be frequency-adjusted (when applicable) and tested as specified in 4.8.10.1. After stabilization at the highest specified temperature, the temperature is decreased in steps, as specified, and data acquired in a similar manner until the lowest specified temperature is reached. The frequency-temperature accuracy shall be determined as in 4.8.10.1. Test details and qualification data of 4.8.10.1 apply.

4.8.10.3 <u>Initial frequency-accuracy including trim effect (one-half temperature cycle) (when specified, see 3.1) (see 3.6.9.3)</u>. The oscillator shall be subjected to a one-half temperature cycle, as in 4.8.10.1, with each of three frequency adjusted conditions as follows:

Condition 1: Oscillator frequency adjusted to nominal frequency (or marked frequency offset, if applicable) at the reference temperature.

Condition 2: Oscillator frequency adjusted to positive limit of specified frequency-adjustment range at the reference temperature.

Condition 3: Oscillator frequency adjusted to negative limit of specified frequency-adjustment range at the reference temperature.

The initial frequency-temperature accuracy shall be determined by:

f-T accuracy = $\pm MAX [\delta f1_{max}, \delta f1_{min}, \delta f2_{max}, \delta f2_{min}, \delta f3_{max}, \delta f3_{min}]$

where MAX [] is the maximum value among $\delta f's$ in the bracket. The $\delta f's$ are computed as follows:

 $\delta f1_{max} = | (f1_{max} - f1)/f1 |$ $\delta f1_{min} = | (f1_{min} - f1)/f1 |$ $\delta f2_{max} = | (f2_{max} - f2)/f2 |$ $\delta f2_{min} = | (f2_{min} - f2)/f2 |$ $\delta f3_{max} = | (f3_{max} - f3)/f3 |$ $\delta f3_{min} = | (f3_{min} - f3)/f3 |$

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where f1, f2, and f3 are the frequencies to which the oscillator is adjusted at the reference temperature for the three conditions. The max and min refer to the maximum and minimum frequencies measured during the respective temperature runs. The test conditions of 4.8.10.1 apply.

Alternate test method: When applicable, the test may be performed in a single frequency-temperature run by switching in the appropriate frequency-adjust elements (or control voltage, if applicable) at each temperature. The switched frequency-adjust elements or control voltages must adequately simulate actual conditions at the trim terminals. When the alternate method is used, evidence that the alternate test method yields the correct test results shall be provided to the qualifying activity along with the test data.

4.8.10.4 <u>Initial frequency-temperature accuracy including hysteresis and trim effect (when specified, see</u> <u>3.1) (see 3.6.9.4)</u>. The oscillator shall be subjected to a complete temperature cycle, as specified in 4.8.10.2, with each of the three frequency adjusted conditions. The initial frequency-temperature accuracy shall be determined as in 4.8.10.3. The test details of 4.8.10.1 shall apply.

4.8.11 <u>Frequency-temperature stability (when specified, see 3.1) (see 3.6.10)</u>.

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4.8.11.1 <u>Frequency-temperature stability (one-half temperature cycle) (when specified, see 3.1) (see 3.6.10.1)</u>. The oscillator shall be frequency-adjusted (when applicable) and then subjected to a one-half temperature cycle as specified in 4.8.10.1. The frequency-temperature stability shall be determined as follows:

f-T stability = $\pm (f_{max} - f_{min})/(f_{max} + f_{min})$

where f_{max} is the maximum frequency measured during the temperature run, and f_{min} is the minimum frequency measured during the temperature run. If specified, a frequency versus temperature curve shall be generated in the format specified. The test details of 4.8.10.1 shall apply.

4.8.11.2 <u>Frequency-temperature stability including hysteresis (when specified, see 3.1) (see 3.6.10.2)</u>. The oscillator shall be frequency adjusted (when applicable) and then subjected to the complete temperature cycle as specified in 4.8.10.2. The frequency-temperature stability shall be determined as in 4.8.11.1. If specified, a frequency versus temperature curve shall be generated in the format specified. The test details of 4.8.10.1 shall apply.

4.8.11.3 <u>Frequency-temperature stability including trim effect (one-half temperature cycle) (when</u> <u>specified, see 3.1) (see 3.6.10.3)</u>. The oscillator shall be frequency-adjusted and then subjected to a one-half temperature cycle, as specified in 4.8.10.1, with each of the three frequency-adjusted conditions as defined in 4.8.10.3. The frequency-temperature stability shall be determined by:

f-T stability = \pm MAX [δ f1, δ f2, δ f3]

where MAX [] is the maximum value among $\delta f1$, $\delta f2$, and $\delta f3$. $\delta f1$, $\delta f2$, and $\delta f3$ are computed as follows:

 $\delta f1 = (f1_{max} - f1_{min})/(f1_{max} + f1_{min})$

 $\delta f2 = (f2_{max} - f2_{min})/(f2_{max} + f2_{min})$

 $\delta f3 = (f3_{max} - f3_{min})/(f3_{max} + f3_{min})$

where f1, f2, and f3 max are the maximum frequencies measured during the temperature run under conditions 1, 2, and 3, respectively, and f1, f2, and f3 min are the minimum frequencies measured during the temperature runs under conditions 1, 2, and 3, respectively. If specified, a frequency versus temperature curve shall be generated in the format specified. Test details of 4.8.10.1 shall apply.

4.8.11.4 <u>Frequency-temperature stability including hysteresis and trim effect (when specified, see 3.1)</u> (see 3.6.10.4). The oscillator shall be frequency-adjusted and subjected to a complete temperature cycle as specified in 4.8.10.2, with each of the three frequency-adjusted conditions. The frequency-temperature stability shall be determined as in 4.8.11.3. If specified, a frequency-temperature curve shall be generated in the format specified. The test details of 4.8.10.1 shall apply.

4.8.12 <u>Frequency-temperature slope at reference temperature (when specified, see 3.1) (see 3.6.11)</u>. The oscillator shall be frequency-adjusted and subjected to a one-half temperature cycle as specified in 4.8.10.1 with a lower temperature limit of Tref-2°C and upper temperature limit of Tref +2°C, unless otherwise specified. The temperature step shall be less than +1°C. The slope at the reference temperature shall be the slope of the best straight line through the set of data points, obtained by using the method of least squares. This test may be combined with 4.8.11.1, 4.8.11.2, 4.8.11.3, or 4.8.11.4 as applicable.

4.8.13 <u>Frequency-thermal transient stability (when specified, see 3.1) (see 3.6.12)</u>. The thermal response time and overshoot (or undershoot) of the transient frequency excursion resulting from the specified thermal excitation shall be measured in accordance with the following procedure:

- a. The unenergized oscillator shall be placed in the temperature chamber and allowed to reach equilibrium at the specified initial temperature T₁. The oscillator shall then be energized and allowed to stabilize for the specified time interval under normal operating conditions. At the end of this period, the chamber temperature shall be changed at the specified rate to the final temperature T₂. The oscillator output frequency and the environmental temperature (as measured at the reference point) should be continuously recorded during and after this operation, resulting in a plot of both frequency change and temperature similar to that on figure 3 from which the thermal response time and the overshoot may be determined.
 - (1) The overshoot of the transient excursion may be specified either in fractional parts of the nominal frequency (i.e., the overshoot should not exceed 2 x 10⁻⁷), or as a percentage of the steady-state frequency offset, i.e., according to the relation:

overshoot (%) = $\frac{f_{max} - f_{final}}{f_{final} - f_{initial}} \times 100$

- (2) Unless otherwise specified, the thermal response time is the time interval between the instant the frequency has changed 10 percent of the overall change, and the instant the frequency has attained a value within 10 percent (of the change) of its final frequency. There are two possible cases, as shown by the sample recordings on figure 3.
 - (a) When the overshoot is less than 10 percent, the thermal response time is equal to $t_2 t_1$ minutes.
 - (b) When the overshoot is equal to or greater than 10 percent, the thermal response time is equal to $t_3 t_1$ minutes.
- b. The following details shall apply:
 - (1) Initial and final reference point temperatures: As specified (see 3.1).
 - (2) Rate of change of reference point temperature: As specified (see 3.1).
 - (3) Precise location of temperature sensor reference point: As specified (see 3.1).
- c. Precautions:
 - (1) The temperature sensor should be positioned so as to record the reference point temperature at the specified location. Both sensor location and temperature ramp must be accurately defined in order to obtain reproducible results.
 - (2) Response time of the frequency measuring system (whether analogue or digital) must be short compared with the maximum rate of change of frequency exhibited by the oscillator under test.

4.8.14 <u>Frequency-voltage tolerance (see 3.6.13</u>). The frequency-voltage tolerance shall be determined from measurement of output frequency when the oscillator supply voltage and oven supply voltage (when applicable), is adjusted to its specified nominal value, to its minimum value and to its maximum value (see 3.6.2.1 and 3.6.2.2). Sufficient stabilization time shall be allowed between adjustment of supply voltage and measurement of frequency. The frequency-voltage tolerance shall be determined by:

f-V tolerance = \pm MAX [δf_{max} , δf_{min}]

where MAX [] is the maximum value among δf_{max} and δf_{min} . δf_{max} and δf_{min} are computed as follows:

> $\delta f_{max} = |(f_{max} - f_{ref})/f_{ref}|$ $\delta f_{min} = |(f_{min} - f_{ref})/f_{ref}|$

where f_{max} is the maximum frequency measured, f_{min} is the minimum frequency measured and f_{ref} is the reference frequency at nominal supply voltage.

4.8.15 <u>Frequency-load tolerance (when specified, see 3.1) (see 3.6.14)</u>. The frequency-load tolerance shall be determined from measurement of output frequency at specified nominal load conditions, minimum load conditions and maximum load conditions. Any impedance appearing across the output terminals which results from connection to the measurement system must be included in the total electrical load value. The frequency-load tolerance shall be determined as specified in 4.8.14 where f_{ref} is the reference frequency at nominal load.

4.8.16 <u>Retrace (when specified, see 3.1) (see 3.6.15)</u>. The retrace shall be measured in accordance with the procedure illustrated on figure 4. The oscillator shall be operated at the specified test temperature and when stabilized, the frequency, f_1 , shall be recorded. The oscillator shall then be turned off and maintained at the specified test temperature for a specified time period ($t_3 - t_2$). At the end of this period, power shall again be applied and the frequency recorded as a function of time. The retrace error is the frequency difference between the frequency at the time of turn off (f_1 at t_2) and the frequency at the specified time after turn on (e.g., f_3 at t_4 or f_2 at t_5). The measurement temperature shall be as specified (see 3.1).

4.8.17 Short-term stability (when specified, see 3.1) (see 3.6.16).

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4.8.17.1 <u>Phase noise, steady-state (when specified, see 3.1) (see 3.6.16.1)</u>. The phase noise shall be measured in accordance with NIST Technical Note 1337 and the test configuration of figure 5. The single side band ratio of the power in a 1 Hz bandwidth to the power in the carrier shall be determined under quiescent conditions.

Precautions: The presence of amplitude noise (AN noise) on the signal may affect phase noise measurements depending upon the degree of AN noise suppression at the phase detector. After passing through the phase detector, the AN noise should be at least 10 dB below the phase noise in order to allow valid phase noise test results.

4.8.17.2 <u>Phase noise, random vibration (when specified, see 3.1) (see 3.6.16.2)</u>. The oscillator shall be subjected to random vibration (operating) specified in 4.8.39.3. The spectral density of phase fluctuations, $S_{0}(f)$, shall be measured in accordance with NIST Technical Note 1337 and the test configuration of figure 5 for the random vibration levels and spectra specified. The phase noise, expressed as $\mathfrak{P}(f)$, in dBc, as defined in 6.3.27, shall not exceed the values specified.

4.8.17.3 <u>Phase noise, acoustic (when specified, see 3.1) (see 3.6.16.3)</u>. The oscillators shall be subjected to "acoustic noise (operating)" specified in 4.8.40. The spectral density of phase fluctuations $S_{\phi}(f)$, shall be measured in accordance with NIST Technical Note 1337 and the test configuration of figure 5 for the acoustic noise intensities and spectra specified. The phase noise, expressed as I(f), in dBc, as defined in 6.3.27, shall not exceed the values specified.

4.8.17.4 <u>Amplitude noise (when specified, see 3.1) (see 3.6.16.4)</u>. The amplitude noise shall be measured in accordance with the configuration of figure 6 and the following procedure (see F.L. Walls, et al., "Accuracy Model for Phase Noise Measurements," Proc. 21st PTTI Meeting 1989):

Step 1 - Calibration of AM detector and amplifier gain.

The conversion sensitivity of the AM detector and the amplifier gain shall be determined at the nominal frequency and power level of the oscillator under test using a calibration source that is sinusoidally modulated at frequency f_c . Connect the calibration source so that the detected dc level at the detector output (test point A on figure 6) is the same as for the oscillator under test. The calibration signal is of the form,

$$V = V_o [1 + A_o \cos 2\pi f_c t] \cos 2\pi v_o t$$

where 100 x A_0 is the percentage modulation and $A_0^2/2$ is the relative power at the modulation frequency (assuming $A_0 << 1$ and the detector is linear). The power measured by the spectrum analyzer at frequency f_c , denoted by $P_0(v_0, V_0, f_c)$, is given by

$$P_{o}(v_{o}, V_{o}, f_{c}) = \frac{A_{o}^{2}}{2}G^{2}(f_{c}) k_{AM}^{2}(v_{o}, V_{o}, f_{c})$$

where $G^2(f_c)$ is the square of the voltage gain of the amplifier frequency f_c and $k_{AM}^2(v_0, V_0, f_c)$ is the conversion sensitivity of the detector. Therefore,

$$G^{2}(f_{c}) k_{AM}^{2}(v_{o}, V_{o}, f_{c}) = \frac{2P_{c}(v_{o}, V_{o}, f_{c})}{A_{0}^{2}}$$

Step 2 - Oscillator AM measurement.

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Connect the oscillator under test to the detector. Record the spectrum. Correct the measured spectrum to $S_a(f)$ using $G^{2}K_{AM}^{2}$ product measured in step 1, that is

$$S_{e}(f) = \frac{P_{o}(v_{o}, V_{o}, f_{c})}{G^{2}(f_{c}) k_{AN}^{2}(v_{o}, V_{o}, f_{c})}$$

4.8.17.5 <u>Allan variance (when specified, see 3.1) (see 3.6.16.5)</u>. The Allan variance shall be determined in accordance with NIST Technical Note 1337 using 100 samples and the test configuration of figure 6.

Precautions: Systematic effects, if significant and not removed, will bias results in Allan variance measurements (see "Treatment of Systematic Variations," NIST Technical Note 1337). Therefore, the contribution of frequency aging must be properly subtracted from the data for high aging rate oscillators or at long sample times (τ 's) in order for $\sigma_{\gamma}(\tau)$ to be a valid measure of random frequency fluctuations.

4.8.18 Acceleration sensitivity (when specified, see 3.1) (see 3.6.17).

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4.8.18.1 <u>Acceleration sensitivity, steady-state (when specified, see 3.1) (see 3.6.17.1)</u>. The oscillator shall be subjected to "acceleration (operating)" specified in 4.8.42.2. Measurements shall be made at least five equally spaced acceleration levels between 20 percent of the maximum and the maximum specified. The frequency change per unit g of acceleration shall be determined graphically for all acceleration levels to the maximum specified. The following details shall apply:

- a. Test configuration: See figure 5.
- b. Acceleration level: As specified (see 3.1).
- c. Orientation (direction): As specified (see 3.1).

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4.8.18.2 <u>Acceleration sensitivity, 2 g tip-over (when specified, see 3.1) (see 3.6.17.2)</u>. Three mutually perpendicular axes shall be defined relative to the external oscillator package. For each of the three axes, the following procedure shall be followed.

- a. Position the oscillator with the ith axes vertical and the unit vector parallel to the positive ith axis pointing upward.
- b. Record the frequency and call if f_i^+ .
- c. Position the oscillator with the ith axis vertical and the unit vector parallel to the negative ith axis pointing upward.
- d. Record the frequency and call it f_i .

e. Calculate
$$y_{j} = \frac{f_{j}^{*} - f_{j}^{*}}{f_{j}^{*} + f_{j}^{*}}$$
.

After all three axes are measured, calculate the magnitude and direction of the acceleration sensitivity vector, Γ , as follows:

$$|\Gamma| = \sqrt{\gamma_1^2 + \gamma_2^2 + \gamma_3^2}$$

and

$$\overline{\Gamma} = \gamma_1 \mathbf{i} + \gamma_2 \mathbf{j} + \gamma_3 \mathbf{k}$$

where i, j, and k are the unit vectors parallel to the positive direction of axis 1, 2, and 3 respectively.

Precautions:

Care must be taken to ensure that the observed frequency changes are not due to gravitation-induced-thermal-convection-current changes within the oscillator. This condition is guarded against by performing the position change and frequency measurement as rapidly as possible. Verification is obtained by repeatable measured frequency changes following repetitive position changes inasmuch as the changes due to altered convection currents are generally not repeatable.

4.8.18.3 Acceleration sensitivity, vibration (when specified, see 3.1) (see 3.6.17.3).

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4.8.18.3.1 <u>Acceleration sensitivity, sinusoidal vibration</u>. The oscillator shall be subjected to vibration, sinusoidal (operating) specified in 4.8.39.2. A sinusoidal excitation shall be applied to the vibration machine at a level not to exceed 20 g's or the value specified. The frequency of vibration, f_V , shall be varied over the frequency range specified in a logarithmic progression of not fewer than 7 frequencies per decade. At each vibration frequency the relative sideband intensity, i.e., the ratio of the power in the upper vibration induced sideband to the power at the unmodulated signal frequency, shall be determined. The acceleration sensitivity at each vibration frequency shall be determined from the following:

$$y_{i} = \frac{2f_{v}10^{(I_{i}(f_{v})/20)}}{a_{i}v_{0}}$$

where,

- y_i = Acceleration sensitivity along axis i (i = 1, 2, or 3)
- $f_V = Vibration frequency$
- a_j = Acceleration frequency
- $v_0 = Carrier frequency$
- $l_i(f_v)$ = Relative sideband intensity (power ratio) in d8c (see 6.3.27) when the vibration at frequency f_v is along the i axis.

The acceleration sensitivity for each axis is the maximum value measured for any vibration frequency in the range specified. The above procedure is repeated for two other axes such that the three axes are mutually perpendicular. The magnitude and direction of the acceleration sensitivity vector, Γ , shall be calculated as specified in 4.8.18.2.

The following details shall apply:

- a. Test configuration: See figure 5.
- b. Vibration level: As specified (see 3.1).
- c. Vibration frequency range: As specified (see 3.1).

4.8.18.3.2 <u>Acceleration sensitivity, random vibration</u>. It is acceptable to assume that the acceleration sensitivity under random vibration is the same as under sinusoidal vibration. The sinusoidal vibration test method detailed in 4.8.18.3.1 is preferred for measuring the acceleration sensitivity of a crystal oscillator in a vibrating environment.

4.8.19 Magnetic field sensitivity (when specified, see 3.1) (see 3.6.18).

4.8.19.1 <u>Magnetic field sensitivity, dc (see 3.6.18.1)</u>. The energized oscillator shall be subjected to "magnetic field, (operating)" specified in 4.8.44. Maximum sensitivity to dc magnetic field shall be determined from measurement of output frequency as a function of dc magnetic field in the most sensitive (i.e., worst case) direction.

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4.8.19.2 <u>Magnetic field sensitivity, ac (see 3.6.18.2)</u>. The oscillator shall be subjected to the "magnetic field, (operating)" specified in 4.8.44. Maximum sensitivity to an alternating magnetic field shall be determined from measurement of the magnitude of the frequency modulation at the specified field strength and frequencies in the most sensitive (i.e., worst case) direction. At each frequency the relative sideband intensity, $I(f_{\mu})$, shall be measured. The alternating magnetic field sensitivity, $\Gamma_{\rm H}$ shall be determined from:

$$\Gamma_{H} = \frac{2 f_{\mu} 10^{(I(f_{\mu})/20)}}{H v_{o}}$$

where:

 $\Gamma_{\rm M}$ = Magnetic field sensitivity

 f_{μ} = Alternating magnetic field frequency H = Peak magnetic field strength in amperes/meter

 $v_0 = Carrier frequency$

 $I(f_{II}) = \text{Relative sideband intensity in dBc (see 6.3.31).}$

4.8.20 Output waveform (see 3.6.19). The type of output waveform shall be verified.

4.8.21 Output voltage-power (see 3.6.20).

4.8.21.1 Output voltage (see 3.6.20.1). The rms or peak-to-peak output voltage shall be measured across the specified load (see 3.1). For voltage controlled crystal oscillators, the modulation-control input voltage shall be turned off for this measurement and the dc input reference level shall be as specified (see 3.1).

4.8.21.2 Output power (sinusoidal waveform) (see 3.6.20.2). The output power shall be measured across the specified load (see 3.1). The output power is calculated from the rms output voltage and a knowledge of load impedance or, alternately, it may be read directly from an appropriate power meter. For voltage controlled oscillators, the modulation-control input voltage shall be turned off for this measurement and the dc input reference level shall be as specified (see 3.1).

4.8.21.3 Output logic voltage levels (square wave output waveform) (see 3.6.20.3). The output logic voltage levels (see figure 8) shall be measured across the specified load (see 3.1). Unless otherwise specified, test loads for TTL and CMOS compatible oscillators shall be as shown on figure 9.

Note: The measurements shall be referenced from ground (0 V dc) to the flat portion of each level, disregarding overshoot, undershoot, or ringing, if these can be traced to inductance external to the oscillator as shown on figure 8.

4.8.22 Rise and fall times (square wave output waveform) (see 3.6.21). The rise and fall time measurements shall be made between the specified voltage levels (see figure 8). Unless otherwise specified (see 3.1), rise and fall time measurement levels for TTL and CMOS compatible oscillators shall be as specified in table VIII. For ECL and other logic families, the measurement levels shall be as specified (see 3.1).

TABLE VIII.	Rise and	fall tim	e measurement	levels.

Compatible logic	Lower measurement level	el Upper measurement level		
TTL	0.8 volt	2.0 volts		
CMOS	10% of signal level	90% of signal level		

4.8.23 <u>Duty cycle (square wave output waveform) (see 3.6.22</u>). The measurement of duty cycle expressed as a percent of one waveform period shall be made at the 50 percent voltage level (referenced to ground) (see figure 8). Unless otherwise specified (see 3.1), the duty cycle measurement level for TTL and CMOS compatible oscillators shall be as specified in table IX.

ABLE	IX.	Duty	cycl	e m	easurement	level.

Compatible logic	Measurement level	
TTL	1.4 volts	
CNOS	50% V _{peak-to-peak}	

4.8.24 <u>Harmonic and subharmonic distortion (when specified, see 3.1) (see 3.6.23)</u>. The harmonic and subharmonic distortion within the bandwidth, as specified (see 3.1), shall be measured as follows:

The circuit is set up as shown on figure 1; the spectrum analyzer is set to display a frequency range which will embrace the appropriate harmonics and subharmonics of the oscillator.

In an ideal case, the spectrum of the oscillator will appear as on figure 9. The spectrum of an oscillator with severe harmonic distortion only, and one which has severe harmonic and subharmonic distortion is shown on figure 10. The spectra may be measured (usually directly in decibels from the spectrum analyzer) as a power ratio with respect to the carrier power, expressed in decibels or alternatively with percentage distortion of, for example, the third harmonic may be quoted as follows:

$$D_3 = \frac{100}{10^{d3/20}}$$

Where:

 D_{X} = percentage of third harmonic distortion.

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 d_3 = difference in level of fundamental and third harmonic (in decidels) as measured on the spectrum analyzer.

Precautions:

Care must be taken to ensure that the distortion is not produced in the input mixer of the spectrum analyzer.

Nonlinear distortion (having the appearance of harmonic distortion) will be produced if the input mixer is overloaded. This point may be checked by placing an attenuator between the oscillator and the spectrum analyzer and taking measurements at various power levels. The attenuator setting should not effect the percentage of harmonic distortion.

NOTE: The total harmonic distortion may be obtained from a summation of the individual harmonically related responses as follows:

$$D_{\text{TOTAL}} = 100 \left[10^{-d2/10} + 10^{-d3/10} \right]^{-1/2}$$

4.8.25 <u>Spurious response (when specified, see 3.1) (see 3.6.24)</u>. The nonharmonic related spurious response within the bandwidth, as specified (see 3.1), shall be measured similar to that specified in 4.8.24.

Precaution: In the event of high level signals in the environment in which the oscillator is being tested, care should be taken to screen the measurement system to eliminate signal picked up from the operating environment.

4.8.26 <u>Output impedance (when specified, see 3.1) (see 3.6.25)</u>. The output impedance shall be measured as follows:

- a. Load the oscillator output with a precision (\pm 1 percent nonreactive) resistor. R_L = specified load minus 10 percent.
- b. Measure output voltage e_L .
- c. Load the oscillator output with a precision (± 1 percent nonreactive) resistor. $R_{\rm H}$ = specified load plus 10 percent.
- d. Measure output voltage e_{H} .
- e. Calculate the output impedance.

$$Z = \frac{R_L R_H (e_H - e_L)}{e_L R_H - e_H R_L}$$

4.8.27 <u>Re-entrant isolation (multi-output oscillators) (when specified, see 3.1) (see 3.6.26)</u>. The isolation between output ports of an oscillator having two or more outputs shall be measured in accordance with the test configuration on figure 11 and the following procedure:

- a. Connect the 20 dB pads on the output of the RF generator to the 20 dB pad at the input of the spectrum analyzer (or selective voltmeter). Adjust the output of the RF generator to the specified level and frequency. Note the level on the spectrum analyzer.
- b. The 20 dB pads at the output of the RF generator and input of the spectrum analyzer (or selective voltmeter) are connected to their appropriate ports. The level is measured on the analyzer as in 4.8.27a.
- c. The ratio of the two signals measured with and without the shorting link (usually expressed in decibels) is the re-entrant isolation between the appropriate ports, at the re-entrant signal frequency. The following details shall apply:
 - (1) Test configuration: See figure 11.
 - (2) Measurement frequency: As specified (see 3.1).
 - (3) Level of test signal: As specified (see 3.1).

Precaution:

Care must be taken to prevent overloading of the spectrum analyzer (or selective voltmeter) as this will cause signal limiting and an apparent reduction in re-entrant isolation.

If isolation is to be measured at a frequency which is a harmonic of the oscillator, then a pessimistic value of re-entrant isolation will be obtained. However, if the harmonic level is considerably lower than the isolation to be measured, a usable result can still be achieved. Where the harmonic content of the output signal is high, it will be necessary to disable the oscillator (i.e., cause the oscillator to cease oscillation while still remaining energized) before measurements can be made.

4.8.28 <u>Output suppression (gated oscillator) (when specified, see 3.1) (see 3.6.27)</u>. The output suppression for gated oscillators shall be determined by measurement of the reduction in output level when the output stage is cutoff by a gating signal as follows:

- a. The specified signal necessary to gate the output of the oscillator "ON" shall be applied, and the level of the output at its fundamental frequency, and at any harmonic frequency as specified, measured on the spectrum analyzer.
- b. The specified signal necessary to gate the output of the oscillator "OFF" shall then be applied, and the new output level noted.
- c. The output suppression at a particular frequency is the ratio of the output levels in the "ON" and "OFF" states, usually expressed in decibels. The following details shall apply:
 - (1) Test configuration: See figure 12.
 - (2) Measurement frequency: As specified (see 3.1).
 - (3) Details of "ON" and "OFF" gating signals: As specified (see 3.1).

Precaution: Care must be taken to prevent overloading of the spectrum analyzer as this will cause signal limiting and an apparent reduction in output suppression.

4.8.29 <u>Startup time (when specified, see 3.1) (see 3.6.28)</u>. Unless otherwise specified, the startup time shall be measured using an oscilloscope synchronized to the switched supply voltage. The following details shall apply:

- a. Test configuration: See figure 13.
- b. Ramp rate: From 0.0 V dc to nominal supply voltage in 100 microseconds or less, unless otherwise specified, (see 3.1).

4.8.30 <u>Modulation-control input impedance (types 2, 5, and 6) (see 3.6.29)</u>. The modulation-control input impedance shall be determined as follows: The specified modulation-control input voltage (see 3.6.2.3) shall be connected to the input terminals through a series resistance of known value ${}^{\rm HR}_{\rm O}{}^{\rm H}$. The voltage across the series resistor "E_r" and the voltage across the input terminals ${}^{\rm HR}_{\rm O}{}^{\rm HR}$ shall be measured. The magnitude of the input impedance may then be calculated as follows:

$$Z_i = R_o \frac{E_m}{E_r}$$

4.8.31 Frequency deviation (types 2, 5, and 6) (see 3.6.30).

4.8.31.1 <u>Total deviation, dc control (see 3.6.30.1)</u>. The total frequency deviation for the specified static dc control input voltage (see 3.6.2.3) shall be determined as follows:

- a. Assemble test equipment in accordance with figure 14. Connections shall be made at "B", "D", and "G".
- b. Set the variable voltage power supply to the end-point voltages and reference voltage specified.
- c. Record frequencies at each voltage above.
- d. The difference between frequencies in 4.8.31.1c above shall not exceed the deviation limits specified (see 3.1). If the limits are not specified, the specification is considered a minimum.

4.8.31.2 <u>Total deviation, modulation (when specified, see 3.1) (see 3.6.30.2)</u>. The total frequency deviation for the specified modulation control input voltages and frequency (see 3.6.2.3) shall be determined as follows:

- a. Assemble test equipment in accordance with figure 14. Connections shall be made at "A", "D" (or "C" and "E" when the VCXO under test does not possess adequate deviation for reading on the modulation meter), and "F".
- b. Set the modulation signal generator to the input voltage level frequencies specified.
- c. Set the FM modulation meter to the scale and range specified. The FM modulation meter will indicate the total frequency deviation of the VCXO for the modulation voltage and frequencies specified.
- d. The deviation shall not exceed the limits specified (see 3.1). If the limits are not specified, the specification is considered a minimum.

4.8.31.3 <u>Deviation (slope) sensitivity (when specified, see 3.1) (see 3.6.30.3)</u>. The deviation (slope) sensitivity within the total deviation range shall be determined as follows:

- a. Assemble test equipment in accordance with figure 14. Connections are to be made at points "B", "D", and "G".
- b. The control voltage range shall be divided into 10 equally spaced voltage steps or 0.5 volt increments, whichever gives the greatest number of voltage settings.
- c. Record frequencies at each of the voltage steps in 4.8.31.3b above. Deviation sensitivity is determined as follows: Sequentially subtract each frequency reading from the next. This difference, when divided by the voltage increment, will yield the sensitivity in equivalent units per volt. The results of each mathematical operation shall not exceed the limits specified (see 3.1).

4.8.31.4 <u>Deviation slope polarity (see 3.6.30.4)</u>. The frequency deviation slope polarity of the frequency-control voltage transfer characteristic shall be determined as follows:

- a. Assemble the test equipment in accordance with figure 14. Connections are to be made at "B", "D", and "G".
- b. Set the variable voltage power supply to a voltage within the control range of the VCXO under test and record frequency.
- c. Adjust the variable voltage power supply to a voltage more positive than that in 4.8.31.4b above and record frequency.
- d. Subtract frequency obtained in step 4.8.31.4b from step 4.8.31.4c. If the result is positive, the VCXO has positive slope. If the result is negative, the slope is negative.
- e. The slope polarity shall be as specified (see 3.1).

4.8.31.5 <u>Deviation linearity (see 3.6.30.5)</u>. The frequency deviation linearity of the frequency-control voltage transfer characteristic shall be determined by fitting a best straight line as follows:

- a. Assemble test equipment in accordance with figure 14. Connections are to be made at points "B", "D", and "G".
- b. The control voltage range shall be divided into 10 equally spaced voltage steps or 0.5 volt increments, whichever gives the greatest number of voltage settings.

- c. Record frequencies at each of the voltage steps in 4.8.31.5b.
- d. Apply the method of least squares to obtain a "best" straight line through the set of data points obtained in 4.8.31.5c above (see figure 15). The deviation linearity shall be determined from the following:

$$\$ linearity = \pm \frac{F_{MAX} \times 100}{D_T}$$

Where \pm F_{max} is the maximum frequency difference existing between the actual and fitted F-V characteristics and D_T is the actual total frequency deviation.

e. The linearity shall not exceed the value specified.

4.8.31.6 <u>Modulation distortion (when specified, see 3.1) (see 3.6.30.6)</u>. The frequency modulation distortion resulting from the nonlinearity of the dynamic modulation transfer characteristic shall be as follows:

- a. Assemble test equipment in accordance with figure 14. Connections are to be made at point "A", point "D", points "F" and "H".
- b. Set the modulation signal generator to the voltage level and frequency specified.
- c. Set the FM modulation meter to approximate range and scale.
- d. Set the distortion analyzer to range and scale for each frequency to be measured.
- e. The distortion analyzer will indicate the harmonic content of the demodulated waveform from the VXCO under test. The value of harmonic content indicated shall not exceed the limits specified (see 3.1).

Precautions: Any distortion introduced by the detector of the modulation meter must be low compared with that of the oscillator under test.

4.8.31.7 <u>Modulation frequency response (when specified, see 3.1) (see 3.6.30.7)</u>. The modulation frequency response shall be determined as follows:

- a. Assemble test equipment in accordance with figure 14. Connections are to be made at "A", "D", and "F".
- b. Determine an adequate number of modulation frequency settings evenly spaced between the modulation reference and the cutoff frequency or at frequencies specified (see 3.1).
- c. Set the modulation signal generator output signal to those frequencies determined in 4.8.31.7b above and to an amplitude which will result in the required frequency deviation.
- d. Record the readings obtained on the FM modulation meter at each of the frequencies above. A table or plot of the deviation versus modulation frequency will yield the frequency response characteristic of the VCXO under test. The resulting characteristic shall be flat to within 3 dB, unless otherwise specified (see 3.1).

4.8.32 <u>Accumulated time error (when specified, see 3.1) (see 3.6.31)</u>. The oscillator shall be subjected to the specified time variant conditions. The time integral of the induced frequency offset, for the specified time interval shall be determined.

4.8.33 Clock accuracy (type 7) (see 3.6.32).

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4.8.33.1 <u>Clock accuracy (corrected pulse train output) (see 3.6.32.1)</u>. The oscillator shall be subjected to the specified operating conditions (temperature, supply voltage, acceleration, radiation, etc). The clock accuracy shall be determined by measurement of time error (or time errors, if effects are tested for separately) over the specified interval (or fraction thereof, if resulting frequency offset is constant) under the worst case combination of operating conditions.

4.8.33.2 <u>Clock accuracy (digital time-of-day output) (see 3.6.32.2)</u>. The clock accuracy shall be determined as specified in 4.8.33.1.

4.8.34 Built-in-test (BIT) (types 4 and 6) (when specified, see 3.1) (see 3.6.33).

4.8.34.1 <u>BIT, oven operating temperature (when specified, see 3.1) (see 3.6.33.1)</u>. The oven supply current (or total OCXO current if a single supply) and BIT output voltage shall be continuously recorded during warmup until the output frequency has stabilized within the specified tolerance. Unless otherwise specified (see 3.1), the transition from "fault" to "operational" condition shall occur in the region where the oven supply current has decreased to within 10 percent of its final quiescent value. The BIT output voltage shall not exceed the limits specified. The following details shall apply:

a, BIT output load: As specified (see 3.1).

b. Measurement temperature: As specified (see 3.1).

NOTE: The above test provides only a verification of BIT capability for indicating operational-readiness of a satisfactorily performing OCXO. The test does not guarantee BIT capability for indicating a fault condition to result from subsequent oven component failure or degradation. This assurance can be provided by a manufacturing in-process-test simulating oven component failure or degradation, e.g., adjusting OCXO oven temperature and measuring low and high trip temperature. If specified, a manufacturing in-process test shall be performed for each oscillator produced and the measured trip-setpoint temperature differential for the oven fault sensing circuit shall be as specified (see 3.1). The BIT manufacturing in-process test method to be employed shall be approved by the qualifying activity.

4.8.34.2 <u>BIT, oven supply voltage (when specified, see 3.1) (see 3.6.33.2)</u>. The oven supply voltage shall be removed from the energized OCXO to simulate the transition from an "operational" to "fault" condition. The BIT output voltage shall not exceed the limits specified. The test details of 4.8.34.1 shall apply.

4.8.34.3 <u>BIT, R-F output voltage (when specified, see 3.1) (see 3.6.33.3)</u>. Transition from an "operational" to "fault" condition shall be simulated by varying the R-F output circuit load such that the output voltage is decreased through a threshold level as specified (see 3.1). It shall be determined by voltage measurement that the transition occurs at the specified threshold level. The BIT output voltage shall not exceed the limits specified. The test details of 4.8.34.1 shall apply.

4.8.35 Frequency aging (see 3.6.34).

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4.8.35.1 <u>Frequency aging (types 1 and 2) (see 3.6.34.1)</u>. Heasurement of frequency aging for nonoven-nontemperature-compensated crystal oscillators shall be as follows:

The oscillator shall be maintained at the specified temperature, tolerance and stability for a continuous period of 30 days. After insertion into the oven, the oscillator shall be allowed to equilibrate with chamber air temperature. Then the oscillator shall be energized and stabilized for 1 hour prior to beginning the data acquisition cycle. The initial frequency of the oscillator shall be measured immediately after the stabilization period (1 hour) and thereafter at intervals not to exceed 72 hours (except one maximum interval of 96 hours per 30-day period is permitted) for a minimum of 30 days. The frequency change between this initial frequency and all subsequent frequencies measured within the 30-day period shall not exceed the maximum frequency change specified. The following details shall apply:

- a. Aging temperature: +70°C or highest specified operating temperature, whichever is lowest.
- b. Aging temperature tolerance: ±3°C (unless otherwise specified, see 3.1).
- c. Aging temperature measurement tolerance (stability): ±0.2°C (unless otherwise specified, see 3.1).

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- d. Qualification data in support of meeting the projected aging performance requirement shall consist of either of the following:
 - (1) Frequency aging measurements of at least five oscillators of the same or similar design and frequency over the period specified.
 - (2) Total frequency change over the period specified determined on a controlled sample of at least five oscillators, using the curve fitting procedure of 4.8.35.2, where the turnover temperature was selected to correspond to the specified aging temperature.

4.8.35.2 Frequency aging (types 3, 4, 5, 6, 7, and 8) (see 3.6.34.2).

4.8.35.2.1 <u>Frequency aging (types 3, 5, and 7)</u>. Measurement of frequency aging for temperature compensated crystal oscillators shall be for 30 days (unless otherwise specified) as follows:

After insertion into the oven, the crystal oscillators shall be stabilized for 48 hours (unless otherwise specified) at the aging temperature prior to beginning the data acquisition cycle. The frequency of each unit shall be measured immediately after the stabilization period. The frequency of each unit shall be measured a minimum of four times per week for 28 days (unless otherwise specified) at intervals of at least 20 hours. The data obtained shall be fit using the method of least squares to the function:

$$f(t) = A(ln(Bt + 1)) + f_0$$

where f(t) is the frequency of the crystal oscillator, t days after the start of the aging cycle (the time origin for data analysis shall be the beginning of the stabilization period), and A, B, and f_0 are constants to be determined from the least square fit.

If the aging trend is not monotonic, the measurement period shall be extended to 40 days after the extremum (unless otherwise specified) in the aging trend. For the total aging period of n days, the data for the last 28 days (unless otherwise specified) shall be fit to the above function. The total frequency change from day n-30 (unless otherwise specified) to day n and for 1 year (projected), unless otherwise specified (see 3.1), shall be determined from the equation using the above determined constants. The maximum frequency shift between any two successive time periods and aging rate at day 30, if specified, shall be determined from the original data. The square root of the least-square-fit-variance of the data from the function shall not exceed 5 percent of the total aging change allowed during the test period. The test details of 4.8.35.1 shall apply except the aging temperature measurement tolerance (stability) is not specified.

4.8.35.2.2 <u>Frequency aging (types 4, 6, and 8)</u>. Measurements of frequency aging for oven controlled crystal oscillators shall be conducted as specified in 4.8.35.2.1, except for the following:

- a. Unless otherwise specified, OCXO shall be tested at room environment with temperature and tolerance specified (see 3.1).
- b. If specified, the aging rate per day at day 30 shall also be determined from the fitted aging equation.

4.8.36 <u>Input power aging (types 4 and 6) (when specified, see 3.1) (see 3.6.35)</u>. The measurement of input power aging rate for hermetic or high vacuum sealed oven controlled crystal oscillators shall be performed concurrently with the frequency aging test (see 4.8.35.2.2). The test details of 4.8.35.2.2 shall apply.

4.8.37 <u>Conducted interference (when specified, see 3.1) (see 3.6.36)</u>. Unless otherwise specified, the conducted interference appearing on the dc lines shall be measured with adequate decoupling from the power supply by insertion of a suitable value inductor (minimum 10 ohm impedance at f_{min}) in the positive power supply line. If specified for voltage controlled oscillators, the conducted interference shall be measured at the control terminals to ground with the control terminals terminated as specified.

4.8.38 <u>Frequency-environment tolerance (see 3.6.37)</u>. The frequency-environment tolerance shall be determined from measurement of initial and final frequencies for each group C environmental test where specified (see 4.8.39 through 4.8.42, 4.8.45 through 4.8.47, and 4.8.49 through 4.8.51). The frequency-environment tolerance shall be determined by

f - E Tolerance = ±MAX [δf_1 , δf_2 ... δf_n]

where MAX [] is the maximum value among δf_1 , δf_2 ,... δf_n . δf_1 , δf_2 ,... δf_n are computed as follows:

 $\delta f_1 = (f_1 \text{ final } - f_1 \text{ initial})/f_1 \text{ initial}$

 $\delta f_2 = (f_2 \text{ final } - f_2 \text{ initial})/f_2 \text{ initial}$

 $\delta f_n \approx (f_n \text{ final } - f_n \text{ initial})/f_n \text{ initial}$

where f_1 , f_2 ,... f_n initial are the initial frequencies measured before each environmental test (1,2...n) and f_1 , f_2 ... f_n final are the final frequencies measured after each environmental test (1,2,...n).

4.8.39 Vibration (see 3.6.38).

4.8.39.1 <u>Vibration, sinusoidal (nonoperating) (see 3.6.38.1)</u>. The oscillator shall be tested in accordance with MIL-STD-202, method 204. The following details shall apply:

- a. Method of mounting: Unless otherwise specified (see 3.1), the oscillator shall be rigidly mounted to the platform of a vibration machine. There shall be no resonance in the mounting structure, within the range of vibration frequency specified.
- b. Test condition letter: As specified (see 3.1).
- c. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.5, 4.8.21, and 4.8.38.

4.8.39.2 <u>Vibration, sinusoidal (operating) (when specified, see 3.1) (see 3.6.38.2)</u>. The energized oscillator shall be subjected to a sinusoidal vibration test, as follows:

A sinusoidal excitation shall be applied to the vibration machine at the level specified. The frequency of vibration shall be advanced over the frequency range specified in a logarithmic progression of no fewer than 7 frequencies per decade. At each vibration frequency the specified measurements shall be performed. The following details shall apply:

- a. Mounting: As specified in 4.8.39.1a.
- b. Peak vibration level: As specified (see 3.1).
- c. Frequency range: As specified (see 3.1).
- d. Direction of motion: Three mutually perpendicular directions (unless otherwise specified, see 3.1).
- e. Duration: 2 hours maximum (unless otherwise specified, see 3.1).
- f. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5, 4.8.18.3.1, and 4.8.21.
 - (3) After test: As specified in 4.8.38.

4.8.39.3 <u>Vibration, random (nonoperating) (when specified, see 3.1) (see 3.6.38.3)</u>. The oscillators shall be tested in accordance with MIL-STD-202, method 214. The following details shall apply:

- a. Mounting: As specified in 4.8.39.1.
- b. Test condition: As specified (see 3.1).
- c. Duration: As specified (see 3.1).
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.38.

4.8.39.4 <u>Vibration, random (operating) (when specified, see 3.1) (see 3.6.38.4)</u>. The energized oscillator shall be subjected to a random vibration test, as follows:

The oscillator shall be rigidly mounted to the platform of a vibration machine. A random vibration shall be applied at the levels and frequencies of the vibration spectrum specified (see 3.1). The following details shall apply:

- a. Mounting: As specified in 4.8.39.1.
- b. Power-spectral density curve: As specified (see 3.1).
- c. Direction of motion: Three mutually perpendicular directions (unless otherwise specified, see 3.1).
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5, 4.8.18.2, and 4.8.21.
 - (3) After test: As specified in 4.8.38.

4.8.40 <u>Acoustic noise (operating) (when specified, see 3.1) (see 3.6.39)</u>. The energized oscillator shall be tested in accordance with MIL-STD-810, method 515, procedure 1. The following details shall apply:

- a. Category: As specified (see 3.1).
- b. Overall sound pressure: As specified (see 3.1).
- c. Exposure time: As specified (see 3.1).
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5, 4.8.17.3, and 4.8.21.
 - (3) After test: As specified in 4.8.38.

4.8.41 Shock (specified pulse) (see 3.6.40).

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4.8.41.1 <u>Shock (specified pulse) (nonoperating) (see 3.6.40.1)</u>. The oscillator shall be tested in accordance with MIL-STD-202, method 213. The following details shall apply:

- a. Method of mounting: The oscillator shall be attached to a rigid fixture.
- b. Test condition: I (unless otherwise specified, see 3.1).
- c. Number of blows: Two blows in each of the three mutually perpendicular axes.
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.2, 4.8.5, 4.8.10, 4.8.14, 4.8.21, and 4.8.38.

4.8.41.2 <u>Shock (specified pulse) (operating) (when specified, see 3.1) (see 3.6.40.2)</u>. The energized oscillator shall be subjected to a shock pulse test at the pulse shape, intensity and duration specified. The following details shall apply:

- a. Method of mounting: The oscillator shall be attached to a rigid fixture.
- b. Shock pulse waveform: As specified (see 3.1).
- c. Number and direction of shock pulses: One in each of the three mutually perpendicular axes (unless otherwise specified, see 3.1).
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.32.
 - (3) After test: As specified in 4.8.38.

4.8.42 Acceleration (see 3,6.41).

4.8.42.1 <u>Acceleration (nonoperating) (when specified, see 3.1) (see 3.6.41.1)</u>. The oscillator shall be tested in accordance with MIL-STD-202, method 212. The following details shall apply:

- a. Test condition C (unless otherwise specified, see 3.1).
- b. Acceleration level: As specified (see 3.1).
- c. Measurements: Unless otherwise specified, see 3.1.
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.2, 4.8.5, 4.8.21, and 4.8.38.

4.8.42.2 <u>Acceleration (operating) (when specified, see 3.1) (see 3.6.41.2)</u>. The energized oscillator shall be subjected to an acceleration test as follows:

The acceleration shall be produced using a centrifuge or similar machine. A steady-state acceleration shall be applied at the specified level for the specified duration. Measurements shall be made at five equally spaced acceleration levels between 20 percent of the maximum and the maximum specified. The following details shall apply:

- a. Acceleration level: As specified (see 3.1).
- b. Acceleration duration: As specified (see 3.1).
- c. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5, 4.8.18.1, and 4.8.21.
 - (3) After test: As specified in 4.8.2 and 4.8.38.

4.8.43 <u>Explosion (operating) (when specified, see 3.1) (see 3.6.42)</u>. The energized oscillator shall be tested in accordance with MIL-STD-202, method 109. The mechanical and electrical load shall be as specified (see 3.1).

4.8.44 <u>Magnetic field (operating) (when specified, see 3.1) (see 3.6.43)</u>. The energized oscillator shall be placed inside a Helmholtz coil pair and subjected to either a dc or alternating magnetic field, as specified. The following details shall apply:

- a. Helmholtz coil: In accordance with ASTM A-698, the coil should be located at least 10 feet from any large metallic object.
- b. Field calibration: At center of coil without device under test in field.
- c. Magnetic field strength: 50 to 250 amperes/meter (0.6 to 3.2 Gauss) (unless otherwise specified, see 3.1).
- d. Alternating field frequencies: As specified (see 3.1).
- e. Orientation: Worst case direction (unless otherwise specified, see 3.1). A search shall be made in three dimensional space to determine the worst case direction.
- f. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5, 4.8.17.5, 4.8.18.1, 4.8.18.2, and 4.8.21.
 - (3) After test: As specified in 4.8.38.

4.8.45 <u>Thermal shock (nonoperating) (see 3.6.44)</u>. Unless otherwise specified (see 3.1), the oscillator shall be subjected to MIL-STD-202, method 107. The following details shall apply:

- a. Test condition letter B, unless otherwise specified (see 3.1).
- b. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.5, 4.8.11, 4.8.21, and 4.8.38.

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4.8.46 Ambient pressure (see 3.6.45).

4.8.46.1 <u>Ambient pressure (nonoperating) (see 3.6.45.1)</u>. Place the unenergized oscillator in a test chamber and reduce the chamber internal absolute pressure to 1.16 X 10^{-4} Pascal maximum (50,000 feet) (unless otherwise specified) (see 3.1) for 12 hours at -60°C ±2°C. At the end of this time, the test chamber shall be returned to standard atmospheric pressure and temperature. The following details shall apply.

Measurements: Unless otherwise specified (see 3.1).

- (1) Before test: As specified in 4.8.38.
- (2) After test: As specified in 4.8.5, 4.8.21, and 4.8.38.

4.8.46.2 <u>Ambient pressure (operating) (when specified, see 3.1) (see 3.6.45.2)</u>. The energized oscillator shall be tested in accordance with MIL-STD-202, method 105. The following details apply:

- a. Nethod of mounting: Normal mounting means.
- b. Test condition letter: As specified (see 3.1).
- c. Exposure time: As specified (see 3.1).
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) During test: As specified in 4.8.5 and 4.8.21.
 - (3) After test: As specified in 4.8.38.

4.8.47 <u>Storage temperature (see 3.6.46)</u>. The unenergized oscillator shall be placed in the test chamber and subjected to the specified low storage temperature for a minimum of 24 hours. The oscillator shall be removed from the chamber and stored at room ambient conditions for a period of 60 minutes maximum. The unenergized oscillator shall then be placed in a test chamber and subjected to the specified high storage temperature for a minimum of 24 hours. At the end of this time, the oscillator shall be removed from the chamber and stored at room ambient conditions for a period of 1 to 2 hours.

Measurements: Unless otherwise specified (see 3.1).

- (1) Before test: As specified in 4.8.38.
- (2) After test: As specified in 4.8.2, 4.8.5, 4.8.10, 4.8.11, 4.8.14, 4.8.21, and 4.8.38.

4.8.48 <u>Radiation hardness (operating) (when specified, see 3.1) (see 3.6.47)</u>. Frequency and accumulated time error measurements shall be as specified in 4.8.48.1, 4.8.48.2, and 4.8.48.3. Unless otherwise specified (see 3.1), after the tests, measurements shall be as specified in 4.8.5, 4.8.10, 4.8.11, 4.8.14, 4.8.21, 4.8.22, and 4.8.23.

4.8.48.1 <u>Total dose (when specified, see 3.1) (see 3.6.47.1)</u>. The total dose radiation testing shall be performed in accordance with method 1019 of MIL-STD-883. The energized oscillators shall be subjected to the specified total dose. For total dose levels below 1 M Rad, the output frequency shall be measured within four days following irradiation (unless otherwise specified).

4.8.48.2 <u>Dose rate (when specified, see 3.1) (see 3.6.47.2</u>). The energized oscillators shall be subjected to the specified radiation pulse. The output frequency shall be measured during the irradiation and for the specified time subsequent to irradiation. If specified, the accumulated time error shall be measured in accordance with 4.8.32.

4.8.48.3 <u>Neutrons (when specified, see 3.1) (see 3.6.47.3)</u>. The energized oscillators shall be subjected to the specified neutron fluence. The frequency shall be measured during irradiation and for the specified time subsequent to irradiation to allow for annealing of transient neutron effects in semiconductors. The frequency change due to any incidental other-than-neutron irradiation shall be properly accounted for.

4.8.49 Resistance to soldering heat (see 3.6.48).

4.8.49.1 <u>Through-hole mounting packages (terminals or pins)</u>. Unless otherwise specified (see 3.1), each wire-lead terminal of the oscillator shall be tested in accordance with MIL-STD-202, method 210. The following details shall apply:

- a. Test condition: E
- b. Immersion: Leads shall be immersed to a point within .050 ±.005 inch (1.27 ±0.13 mm) of the case.
- c. Cooling time prior to final measurements: 30 minutes.
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.2, 4.8.5, 4.8.10, 4.8.11, 4.8.14, 4.8.21, and 4.8.38.

4.8.49.2 <u>Lead-less chip carriers (LCC)</u>. Unless otherwise specified (see 3.1), each land or pad terminal of the oscillator shall be tested in accordance with MIL-STD-202, method 210. The following details shall apply:

- a. Test condition: B
- b. Immersion: The oscillator shall be immersed to a point where all the solder lands or pads are fully submerged in the molten solder.
- c. Cooling time prior to final measurements: 30 minutes.
- d. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.2, 4.8.5, 4.8.10, 4.8.11, 4.8.14, 4.8.21, and 4.8.38.

4.8.50 <u>Hoisture resistance (see 3.6.49</u>). Oscillators shall be tested in accordance with MiL-STD-202, method 106. The following details shall apply:

- a. Subcycle: Step 7b, the vibration subcycle, shall be omitted.
- b. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.5, 4.8.11, and 4.8.38.

4.8.51 <u>Salt atmosphere (corrosion) (see 3.6.50)</u>. The oscillator shall be tested in accordance with MIL-STD-883, method 1009. The following details shall apply:

- a. Test condition: B
- b. Measurements: Unless otherwise specified (see 3.1).
 - (1) Before test: As specified in 4.8.38.
 - (2) After test: As specified in 4.8.2, 4.8.5, 4.8.21, and 4.8.38.

5.1.1.4.2 <u>Nonhermetically sealed oscillators</u>. Nonhermetically sealed oscillators shall be unit packed in accordance with submethod IA-8 of MIL-P-116. Each unit pack shall be placed in a supplementary container conforming to PPP-B-566 or PPP-B-676.

5.1.1.5 <u>Intermediate packs</u>. Oscillators, unit packed in bags or envelopes in accordance with 5.1.1.4.1, shall be placed in intermediate containers conforming to variety 2 of PPP-B-566, PPP-B-676, or PPP-B-636, class weather resistant. Intermediate containers shall be uniform in size, shape, and quantities, shall be of minimum tare and cube and shall contain multiples of five unit packs, not to exceed 100 unit packs. No intermediate packs are required when the total quantity shipped to a single destination is less than 100 unit packs or when supplementary containers are used.

5.1.2 Level C. The level C preservation for oscillators shall conform to the MIL-STD-2073-1 requirements for this level.

5.2 Packing. Packing shall be level A, B, or C, as specified (see 6.2).

5.2.1 Level A. The packaged oscillators shall be packed in wood boxes conforming to PPP-B-601, overseas type; PPP-B-621, class 2 or PPP-B-585, class 3. Closure and strapping shall be in accordance with the applicable container specification. The requirements for level B packing shall be used when the total quantity of a stock-numbered oscillator for a single destination does not exceed a packed volume of 1 cubic foot.

5.2.2 Level B. The packaged oscillators shall be packed in fiberboard containers conforming to PPP-B-636, class weather resistant, style optional, special requirements. The requirements for box closure, waterproofing, and reinforcing shall be in accordance with method V of the PPP-P-636 appendix.

5.2.3 <u>Level C</u>. The level C packing for oscillators shall conform to the MIL-STD-2073-1 requirements for this level.

5.2.4 <u>Unitized loads</u>. Unitized loads, commensurate with the level of packing specified in the contract or order, shall be used whenever total quantities for shipment to one destination equal 40 cubic feet (1.1328 cubic meters) or more. Quantities less than 40 cubic feet need not be unitized. Unitized loads shall be uniform in size and quantities to the greatest extent practicable.

5.2.4.1 <u>Level A</u>. Oscillators, packed as specified in 5.2.1, shall be unitized on pallets in conformance with MIL-STD-2073-1, load type I, with a wood cap (storage aid 5) positioned over each load.

5.2.4.2 <u>Level B</u>. Oscillators, packed as specified in 5.2.2, shall be unitized as specified in 5.2.4.1 except that weather resistant fiberboard caps (storage aid 4) shall be used in lieu of wood caps.

5.2.4.3 Level C. Oscillators, packed as specified in 5.2.3, shall be unitized as specified in MIL-STD-2073-1.

5.3 <u>Marking</u>. The following marking is mandatory for shipments both to U.S. Government and non-Government activities.

5.3.1 <u>Standard marking</u>. In addition to any special or other identification marking required by the contract (see 6.2), each unit, supplementary, intermediate, and exterior container, and unitized load shall be marked in accordance with MIL-SID-129. The complete military or contractor's type or PIN (including the CAGE), as applicable, shall be marked on all unit, supplementary, and intermediate packs in accordance with the identification marking provisions of MIL-SID-129.

5.3.2 <u>Civil agencies</u>. When specified in the contract or order (see 6.2), the marking of domestic shipments for civil agencies shall be in accordance with FED-STD-123.

5.4 <u>General</u>. The following general requirements apply, as applicable, to levels A, B, and C as well as to shipments to non-Government activities.

5.4.1 <u>Exterior containers</u>. Exterior containers (see 5.2.1, 5.2.2, and 5.2.3) shall be of a minimum tare and cube consistent with the protection required and shall contain equal quantities of identical stock numbered items.

5.4.2 <u>Packaging inspection</u>. The inspection of these packaging requirements shall be in accordance with 4.7.3.

5.4.3 <u>Quality conformance inspections</u>. Quality conformance (visual and dimensional) inspections, rough handling, and leakage tests shall conform to the inspections and tests outlined in MIL-P-116.

5.4.3.1 Functional requirements.

5.4.3.1.1 <u>Rough handling test (when specified, see 6.2)</u>. When packs have been tested in accordance with MIL-P-116, all material and compounds comprising each pack shall be free from damage or evidence of displacement which might affect the use of the preservation method or pack. The devices and associated accessories within the tested packs shall show no visible signs of damage. When specified in the contract (see 6.2), functional tests in accordance with the group A inspection requirements of this specification shall be conducted on those devices subjected to the rough handling test to determine freedom from operational malfunction. The examination of the devices tested under this group A inspection shall be in accordance with the visual and mechanical inspection requirements specified in this specification.

5.4.3.1.2 <u>Leakage test (when applicable</u>). When a barrier enclosed unit pack has been tested in accordance with MIL-P-116, there shall be no evidence of moisture within the unit pack.

5.4.3.1.3 <u>Workmanship</u>. The quality of workmanship shall assure acceptance of the completed preservation, packing, and marking requirements in accordance with the inspections specified in MIL-P-116.

6. NOTES

(This section contains information of a general or explanatory nature that may be helpful, but is not mandatory.)

6.1 Intended use.

6.1.1 <u>Oscillators</u>. Oscillators covered by this specification are intended for use in military and space systems such as communications, navigation, surveillance, identification-friend-or-foe, and electronic fuses.

6.1.2 <u>Packaging requirements</u>. The preservation, packing, and marking herein are intended for direct shipments to the Government. Unless otherwise designated, the marking requirements (see 5.3) and general requirements (see 5.4) are applicable for the preparation of these oscillators for shipment from the parts manufacturer to non-Government activities.

6.2 Acquisition requirements.

6.2.1 <u>Acquisition requirements (crystal oscillators covered by specification sheets)</u>. Acquisition documents must specify the following:

- a. Title, number, and date of the specification.
- b. Issue of DODISS to be cited in the solicitation, and if required, the specific issue of individual documents referenced (see 2.1).
- c. Title, number, and date of the applicable specification sheet, and the military PIN (see 1.2.1).
- d. Levels of preservation and packing required (see 5.1 and 5.2).
- e. If special or other identification marking is required (see 5.3).
- f. Data requirements.

6.2.2 <u>Acquisition requirements (crystal oscillators not covered by specification sheets)</u>. Acquisition documents must specify the following:

- a. Title, number, and date of the specification.
- b. Issue of DODISS to be cited in the solicitation, and if required, the specific issue of individual documents referenced (see 2.1).
- c. Item definition and frequency or frequencies required.
- d. Applicable design and construction requirements (see 3.5).
- e. Applicable performance and environmental requirements (see 3.6).
- f. Levels of preservation and packing required (see 5.1 and 5.2).
- g. If special or other identification marking is required (see 5.3).

6.3 <u>Definitions</u>. For the purpose of this specification, the following definitions apply.

6.3.1 <u>Crystal oscillators (XO)</u>. The simplest and most general-purpose-type of crystal oscillator where the principal control element is the crystal unit. Because the XO employs no means of temperature control or compensation, it exhibits a frequency-temperature characteristic determined mainly by the crystal unit employed.

6.3.2 <u>Voltage controlled crystal oscillators (VCXO)</u>. A crystal oscillator whose output frequency can be offset or modulated by application of an external control voltage. Similar to the XO, the frequency-temperature characteristic of a VCXO is determined mainly by the crystal unit employed.

6.3.3 <u>Temperature compensated crystal oscillator (TCXO)</u>. A crystal oscillator whose frequency-temperature deviation is reduced from that of the crystal unit by an electronic (analog or digital) means of compensation within the device. TCXO-type devices are crystal oscillators in which compensation is achieved by a temperature-dependent variation of the crystal load reactance in a manner that compensates for the crystal unit's frequency-temperature characteristic.

6.3.4 <u>Oven controlled crystal oscillator (OCXO)</u>. A crystal oscillator in which at least the crystal unit is temperature controlled within a thermally insulated enclosure, i.e., an oven, so that the temperature of the crystal is maintained substantially constant.

6.3.5 <u>Temperature compensated/voltage controlled crystal oscillator (TCVCXO)</u>. A combination of TCXO and VCXO.

6.3.6 Oven controlled/voltage controlled crystal oscillator (OCVCXO). A combination of OCXO and VCXO.

6.3.7 <u>Microcomputer compensated crystal oscillator (MCXO)</u>. A microcomputer based crystal oscillator system employing external means of temperature compensation, i.e., correction is performed external to the crystal oscillator's feedback loop using techniques such as pulse deletion, digital phase shifting, etc. The MCXO output may provide either a clock driver signal, e.g., a time corrected pulse train or a spectrally clean RF reference signal, digital Time of Day (TOD) or combinations of these.

6.3.8 <u>Rubidium-crystal oscillator (RbXO</u>). A crystal oscillator combined with a rubidium (Rb) frequency reference. The frequency of the crystal oscillator is controlled by a digital tuning memory which is continuously or intermittently syntonized by the high stability rubidium atomic reference.

6.3.9 <u>Overall frequency accuracy</u>. The maximum permissible frequency deviation of the oscillator frequency from the assigned nominal value due to all combinations of specified operating and non-operating parameters within a specified period of time. In the general case, overall accuracy of an oscillator is the sum of the absolute values assigned to the following:

- a. The initial frequency-temperature accuracy (see 6.3.19).
- b. Frequency-tolerances due to supply voltage changes (see 6.3.24) and other environmental effects (see 6.3.44).
- c. Total frequency change from an initial value due to frequency aging (see 6.3.42) at a specified temperature.

6.3.10 <u>Frequency offset</u>. The frequency difference, positive or negative, which should be added to the specified nominal frequency when adjusting the oscillator frequency at specified reference temperature and operating conditions. The purpose is to minimize the frequency deviation from nominal frequency over the operating temperature range (also called setpoint).

6.3.11 <u>High vacuum seal</u>. A package seal capable of maintaining an internal pressure of 1×10^{-3} TORR or lower.

6.3.12 <u>Syntonization</u>. The process of adjusting the frequency of a crystal oscillator to that of a reference source, e.g., a rubidium reference standard.

6.3.13 <u>Initial accuracy at reference temperature</u>. The maximum permissible offset of the oscillator frequency from the assigned nominal value at specified reference temperature and nominal supply voltage and load conditions, other conditions constant. For non-frequency-adjustable (manufacturer calibrated) oscillators, the initial accuracy at reference temperature applies at the time of manufacture and for a specified period following shipment. For frequency adjustment (manufacturer-user calibrated) oscillators, the initial accuracy at reference temperature applies at the time immediately following calibration by the manufacturer or user.

6.3.14 <u>Mechanical-frequency-adjustment</u>. Frequency adjustment means requiring physical manipulation of an oscillator variable circuit element, e.g., trimmer capacitor, potentiometer, etc.

6.3.15 <u>External-frequency-adjustment oscillator</u>. An oscillator whose mechanical-frequency-adjustment element is located external to the oscillator package and is usually not supplied by the oscillator manufacturer.

6.3.16 <u>Electrical-frequency-control</u>. Frequency adjustment means requiring application of an externally derived voltage to the circuit control terminals of the oscillator.

6.3.17 <u>Frequency warmup</u>. The time, measured from the initial application of power, required for a crystal oscillator to stabilize its mode of operation within specified limits of final frequency. Final frequency is defined to occur at a specified period of time and is expressed in minutes or hours depending on the oscillator type.

6.3.18 <u>Initial frequency aging</u>. The relationship between OCXO frequency and time for a specified period following warmup. Initial frequency aging in crystal oscillators may be caused by various crystal and oscillator-circuit-related mechanisms, e.g., contamination transfer and stress relief inside the resonator enclosure, and changes in the thermistor. The initial frequency aging should be expressed as the maximum frequency change or maximum rate of frequency change over the specified period(s).

6.3.19 <u>Initial frequency-temperature accuracy</u>. The initial maximum permissible deviation of the oscillator frequency from the assigned nominal value due to operation over the specified temperature range at nominal supply voltage and load conditions, other conditions remaining constant. For nonfrequency-adjustable (manufacturer calibrated) oscillators, the initial frequency-temperature accuracy applies at the time of manufacture and for a specified period following shipment. For frequency adjustable (manufacture-user calibrated) oscillators, the initial frequency-temperature accuracy applies at the time immediately following calibration by the manufacturer or user. Initial frequency-temperature accuracy considers the combination of frequency-temperature stability and calibration related errors, and is the preferred general method for specifying the frequency-temperature performance of crystal oscillators.

6.3.20 <u>Hysteresis</u>. When an oscillator is subjected to a complete quasistatic temperature cycle between the specified temperature limits, hysteresis is the difference between the up-cycle and the down-cycle frequency-temperature characteristics. The measure of hysteresis is the maximum value of the difference, expressed as ±1/2 of the maximum fractional frequency difference. (For example, when the worst-case difference is 6X10⁻⁷, the hysteresis is expressed as ±3X10⁻⁷.) For purposes of MIL-0-55310, when hystersis is included in the requirements, it is included in the specification of either the initial frequencytemperature accuracy (see 6.3.19) or the frequency-temperature stability (see 6.3.22). "Quasistatic," means that the temperature is changed during frequency-temperature measurements in such a manner as to ensure that the frequency offsets due to thermal gradients are much smaller than the specified frequency-temperature stability, including hysteresis, or the specified initial frequency-temperature accuracy.

6.3.21 <u>Trim effect</u>. The degradation of crystal oscillator frequency-temperature stability and marked frequency offset as a result of frequency adjustment which produces a rotation or distortion, or both, of the initial frequency-temperature characteristic.

6.3.22 <u>Frequency-temperature stability</u>. The maximum permissible deviation of the oscillator frequency, with no reference implied, due to operation over the specified temperature range at nominal supply and load conditions, other conditions constant.

6.3.23 <u>Frequency-temperature slope at reference temperature</u>. The slope of an oscillator frequency-temperature characteristic at the specified reference temperature. A maximum F-T slope (e.g., $\pm 1 \times 10^{-8}$ /°C) is usually specified in applications where the difference between the specified reference temperature and the actual temperature at which calibration is performed may result in significant frequency error and degraded initial frequency-temperature accuracy (see 6.3.19).

6.3.24 <u>Frequency-voltage tolerance</u>. The maximum permissible deviation of the oscillator frequency from the frequency at specified nominal supply voltage due to changes in supply voltage over the specified range, other conditions remaining constant.

6.3.25 <u>Frequency-load tolerance</u>. The maximum permissible deviation of the oscillator frequency from the frequency at specified nominal load impedance due to changes in load impedance over the specified range, other conditions remaining constant.

6.3.26 <u>Retrace</u>. When an oscillator operating in a stable condition at a specified test temperature, is turned off for a specified time period, maintained at the specified test temperature, and again turned on, retrace is the difference between the frequency at a specified time after oscillator turn-on and the frequency immediately prior to oscillator turn-off.

6.3.27 Phase noise and phase angle modulation.

6.3.27.1 <u>Phase noise (random process)</u>. The short term frequency stability of an oscillator in the frequency domain, characterized by g(f), where,

 $\mathfrak{L}(f) = 10 \log[(1/2)S_{\bullet}(f)]$ (units dBc in a 1 Hz bandwidth)

where: $S_{dd}(f)$ is the spectral density of phase fluctuations (see IEEE Standard 1139).

6.3.27.2 <u>Phase angle modulation (deterministic process)</u>. Discrete "bright lines" induced by external influences such as sinusoidal vibration or by internal effects such as harmonic generation are quantified by the ratio of the power in the sideband being measured to the power at the frequency of the unmodulated signal, v_0 . In terms of voltages, the relative sideband intensity at offset frequency f, 1(f), is given by:

 $I(f) = 10 \log(V^2(f)/V^2(v_0))$ (units dBc)

6.3.28 <u>Amplitude noise</u>. The short term amplitude stability of an oscillator in the frequency domain, characterized by the power spectral density of amplitude fluctuations, $S_a(f)$. $S_a(f)$ is defined by:

$$S_{a}(f) = \frac{\delta e^{2}(f)}{V_{o}^{2} B W}$$

where $\delta \epsilon^2(f)$ is the mean-squared amplitude fluctuation measured at a Fourier frequency separation, f, from the carrier in a measurement bandwidth, BW. The unit of measure of $S_a(f)$ is Hz^{-1} (e.g., 1×10^{-11} per Hz), or when expressed as 10 log $S_a(f)$, the unit of measure is in dBc/Hz (e.g., -110 dBc/Hz). (see F.L. Walls, et al., "Accuracy Model for Phase Noise Measurement," Proc. 21st PTTI Meeting 1989.)

6.3.29 <u>Allan variance</u>. The preferred definition in the time domain of the oscillator short-term stability is as follows:

$$\sigma_{y}(\tau) = \sqrt{\frac{1}{2(M-1)} \sum_{k=1}^{M-1} (\overline{y}_{k+1} - \overline{y}_{k})^{2}}$$

where $(\overline{y}_{k+1} - \overline{y}_k)$ are the kth average fractional frequency fluctuation obtained sequentially, with no systematic dead time between measurements; τ is the sample time over which each measurement M is averaged; k is the number of frequency samples; $\sigma_y(\tau)$ is the square root of the Allan variance.

6.3.30 <u>Acceleration sensitivity</u>. A vector property of the frequency-acceleration relationship for a crystal oscillator which is characterized by a single magnitude and direction. The acceleration sensitivity of a crystal oscillator is the magnitude of the acceleration sensitivity vector and is expressed as a frequency change per unit acceleration (e.g., 1 x 10^{-9} /g). The magnitude of the acceleration sensitivity vector $|\Gamma|$, is obtained by, for example, measuring the acceleration sensitivity along three mutually perpendicular directions, e.g., y_x , y_y , and y_z , and taking the square root of the sum of the squares, i.e.,

$$\mid \Gamma \mid = \sqrt{(y_X^2 + y_y^2 + y_z^2)}$$

6.3.31 <u>Magnetic field sensitivity</u>. The frequency-magnetic field relationship for a precision oscillator. The magnetic field sensitivity is expressed as a frequency change per unit of field strength (e.g., 1X10⁻¹¹/mT).

6.3.32 <u>Rise time</u>. The time observed for a logic "O" to logic "1" transition, when measured on the leading edge of a rectangular waveform pulse, between two specified voltage levels (see figure 8).

6.3.33 <u>fall time</u>. The time observed for a logic "1" to logic "0" transition, when measured on the trailing edge of a rectangular waveform pulse, between two specified voltage levels (see figure 8).

6.3.34 <u>Duty cycle</u>. The percent of time above a specified reference level (referenced to ground) with respect to the waveform period, as shown on figure 8 (also called symmetry).

6.3.35 <u>Harmonic and subharmonic distortion</u>. Harmonic distortion is a nonlinear distortion characterized by the generation of undesired spectral components harmonically related to the desired signal frequency. In an oscillator whose output signal is derived by multiplying a lower frequency signal to the desired output frequency, harmonics of the primary oscillator are the subharmonics of the output frequency. Each component is usually expressed as a power ratio (in decibels) relative to the output power of the desired signal (e.g., second harmonic is suppressed 30 dB, the subharmonics are all below - 40 dBc).

6.3.36 <u>Spurious response</u>. Discrete frequency spectral components, nonharmonically related to the desired output frequency (except for subharmonics), appearing at the output terminal of an oscillator. These components may appear as symmetrical sidebands, or as single spectral components, depending upon the mode of generation. Spurious components in the output spectrum are usually expressed as a power ratio (in decibels) with respect to the signal power.

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6.3.37 <u>Total frequency deviation</u>. Defines the minimum peak frequency deviation from center frequency for a voltage controlled crystal oscillator under specified modulation or dc control voltage conditions. Total deviation is usually expressed in ± parts per million; ± percent or ± hertz changes from center frequency for specified control voltage ranges or modulation voltage.

6.3.38 <u>Deviation linearity</u>. A measure of the output frequency-input control voltage transfer characteristic as compared to an ideal (straight line) function. It is expressed as an allowable nonlinearity in percent of specified full range deviation. This definition assumes that the actual transfer characteristic need not pass through nominal frequency at reference voltage. It is further assumed that monotonicity is present, e.g., no frequency reversals occur within the specified deviation range caused by unidirectional input voltage changes.

6.3.39 <u>Modulation distortion</u>. A measure of the nonlinearity of the dynamic output frequency-modulation voltage transfer characteristic of a voltage controlled crystal oscillator. It is expressed as an allowable percentage distortion in the demodulated output signal when frequency modulated with signals of specified amplitude and frequency.

6.3.40 <u>Modulation frequency response</u>. Defines the relationship between peak frequency deviation and modulation frequency as the modulation frequency is varied. It is usually expressed in dB down at a specified modulation frequency relative to a specified modulation reference frequency.

6.3.41 <u>Clock accuracy (type 7)</u>. The degree of conformity of a clock's rate with that of a time standard. Clock accuracy, expressed as the worst case time error that can accumulate over specified operating conditions and over a specified duration following clock synchronization (e.g., 10 milliseconds per day) is defined as follows:

$$T(t) = T_o + \int_0^t R(t) Dt + e(t) = T_o + (R_o t + 1/2 At^2 + ...) + \int_0^t E_1(t) Dt + e(t)$$

where T_0 is the synchronization error at t = o; R(t) is the rate (fractional frequency) difference between the two clocks under comparison which is equal to:

$$R_{o} + At + \ldots \int_{0}^{t} E_{1}(t) Dt;$$

 R_0 is R(t) at t = 0; A is the linear aging rate; $E_1(t)$ is the rate difference due to environmental effects (temperature, radiation, acceleration, etc.); $\epsilon(t)$ is the error due to random fluctuations (white noise, flicker noise, etc.) which can be estimated statistically if the power laws of the noise processes are known; T is the time error at elapsed time (t) after synchronization.

6.3.42 <u>Frequency aging (long-term stability</u>). The relationship between oscillator frequency and time when the oscillator frequency is measured under constant environmental conditions. This long-term frequency drift is caused by secular changes in the crystal unit and other elements of the oscillator circuit, and should be expressed as either a maximum rate after a specified time period (e.g., 1 x 10⁻¹⁰/day after 30 days) or maximum total frequency change over a specified time period (e.g., 1 x 10⁻⁸/month) or both.

Note: "Drift" is sometimes used incorrectly to express frequency change over a period of time. In previous usage, there had been a lack of standardization in specifying the operating conditions, including environment, under which "drift" is measured. "Frequency aging" shall be the term for specifying frequency change over a period of time under constant environment, load and supply voltage. Other parameters, e.g., frequency-temperature stability, frequency-supply voltage tolerance, etc. should be used to separately specify a performance as a function of a single variable, which lends itself to ease in measurement. Therefore, the term "drift" shall not be used to specify oscillator performance.

6.3.43 <u>Input power aging</u>. The relationship between input power and time for a high-efficiency oven-controlled crystal oscillator, (e.g., a high-vacuum-sealed OCXO) which is a measure of thermal insulation degradation. It is usually expressed as a maximum percent increase in power consumption over a specified period of time (e.g., 0.1 percent/month).

6.3.44 <u>Frequency-environment tolerance</u>. The maximum permissible deviation of the oscillator frequency from an initial reference frequency due to any and all specified standard environmental effects. In the general case, the frequency-environment tolerance is specified as a single magnitude. In applications where an unusual environmental condition may produce a significant permanent change in frequency, e.g., shock at a 10,000 G level, a frequency tolerance is assigned separately to the specified environmental effect.

6.3.45 <u>Terms, definitions, methods, and symbols</u>. For the purposes of this specification, the terms, definitions, methods, and symbols of IEEE STD 1139, CCIR Recommendation No. 686, MIL-STD-883, MIL-STD-202, and those contained herein apply and will be used in applicable acquisition documents wherever they are pertinent. The Government qualifying activity should interpret the definitions of 6.3 for use wherever pertinent.

Institute for Electrical and Electronic Engineers.

IEEE STD 1139 - IEEE Standard Definition of Physical Quantities for Fundamental Frequency and Time Metrology.

(Applications for copies should be addressed to the Institute of Electrical and Electronic Engineers, Inc., 345 East 47th Street, New York, NY 10017)

International Radio Consultative Committee(CCIR).

Recommendation No. 686, Glossary. In: CCIR 17th Plenary Assembly, Vol. 7, Standard Frequencies and Time Signals (Study Group 7), CCIR, Geneva, Switzerland, 1990.

(Applications for copies should be addressed to the International Telecommunications Union, General Secretariat-Sales Section, Place des Nations, CH1211 Geneva, Switzerland.)

6.4 <u>Qualification</u>. With respect to products requiring qualification, awards will be made only for products which are, at the time of award of contract, qualified for inclusion in the applicable Qualified Products List whether or not such products have actually been so listed by that date. The attention of the contractor is called to these requirements, and manufacturers are urged to arrange to have the products that they propose to offer to the Federal Government tested for qualification in order that they may be eligible to be awarded contracts or purchase orders for the products covered by this specification. The activity responsible for the Qualified Products List is U.S. Army Research Laboratory, ATTN: AMSRL-EP-RD, Fort Mormouth, NJ 07703-5601; however, information pertaining to qualification of products may be obtained from the Defense Electronics Supply Center (DESC-ELS), 1507 Wilmington Pike, Dayton, OH 45444.

6.5 Subject term (key word) listing.

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Acceleration sensitivity Allan variance Amplitude noise Calibration Crystal oscillator Clock accuracy Design for nuclear survivability Duty cycle Frequency adjustment Frequency aging Frequency offset Frequency warmup Frequency-environment tolerance Frequency-load tolerance Frequency-temperature stability Frequency-voltage tolerance Harmonic and subharmonic distortion Hysteresis Initial accuracy Initial frequency aging Initial frequency-temperature accuracy Input power aging

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Magnetic field sensitivity Oscillator Output waveform Output voltage-power Output voltage Output power Output logic voltage levels Overall frequency accuracy Phase noise Retrace Rise and fall time Startup time Short-term stability Spurious response Trim effect

6.6 <u>Changes from previous issue</u>. Asterisks are not used in this revision to identify changes with respect to the previous issue due to the extensiveness of the changes.

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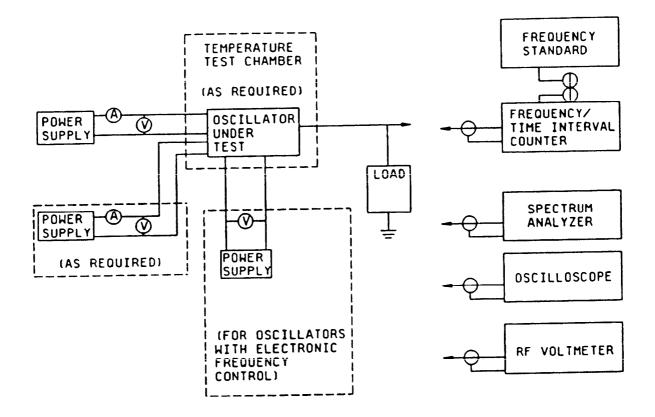


FIGURE 1. Basic bench test configuration.

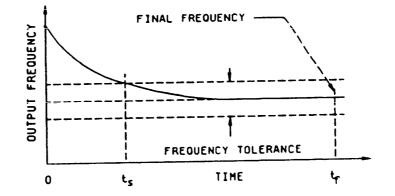
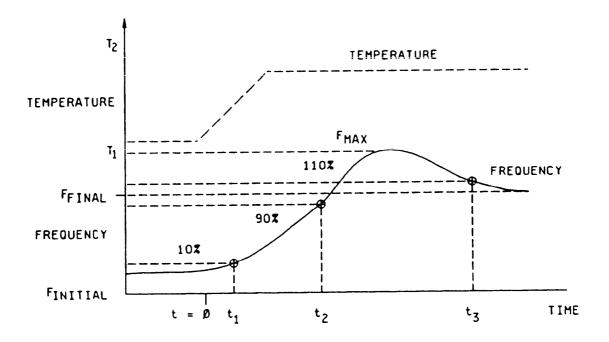


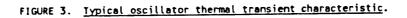
FIGURE 2. Typical oscillator warmup characteristic.





NOTE: t = # = End of stabilization time.

t1 = Time for frequency to change 10 percent of the steady-state increment. t2 = Time for frequency to change 90 percent of the steady-state increment. t3 = Time for frequency to reach 110 percent of the steady-state increment on the recovery from overshoot (in the case where overshoot is greater than 10 percent).



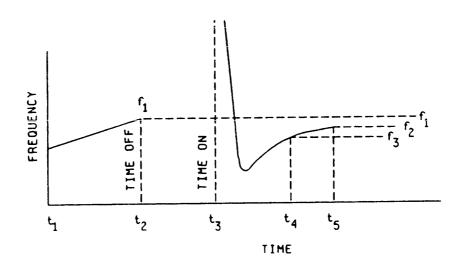


FIGURE 4. Typical oscillator retrace characteristic.

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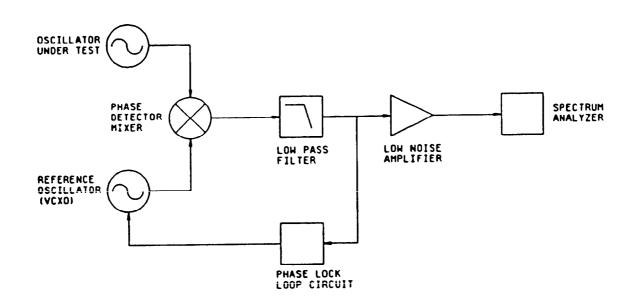


FIGURE 5. Quadrature phase detection method.

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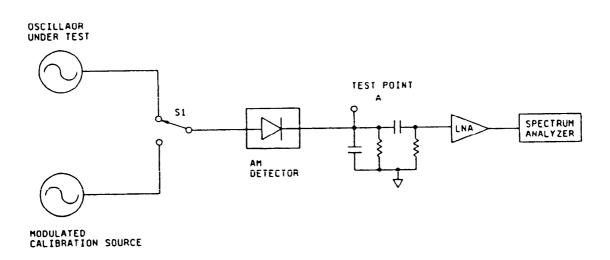


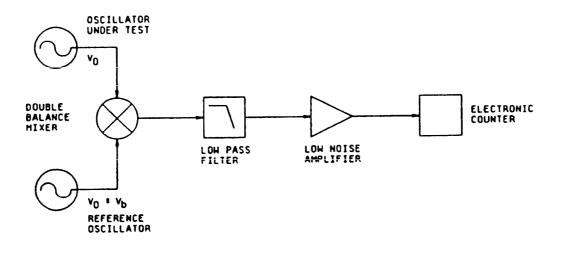
FIGURE 6. Test configuration for amplitude noise measurement.

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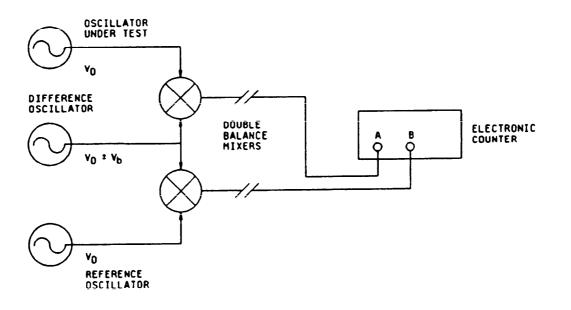
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Heterodyne down-conversion method.



Dual mixer time difference method.

FIGURE 7. Short-term stability Allan variance test procedure.



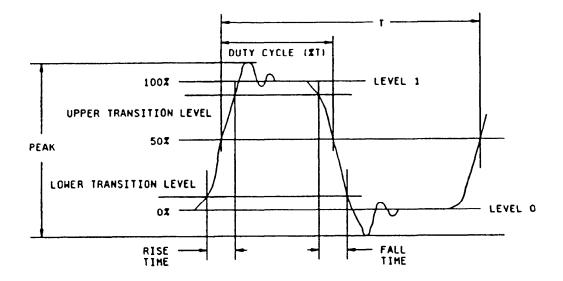
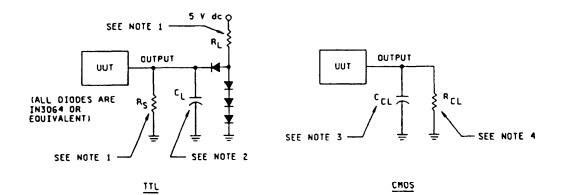


FIGURE 8. Rectangular output waveform.



NOTES:

- 1. For 16 mA sink (10 TTL), $R_L = 270\Omega \pm 5$ percent. ($R_S = 6 k\Omega$). For 9.6 mA sink (6 TTL), $R_L = 430\Omega \pm 5$ percent ($R_S = 10 k\Omega$). 2. C_L (including probe and fixture capacitance) = 2 pF per specified TTL load. Example: C_L (10 TTL) = 20 pF.
 For CHOS: C_{LL} (including probe and fixture capacitance) = 20 pF ±5 percent.
 For CHOS: R_{CL} = 100 kΩ ±5 percent.

FIGURE 9. TTL and CMOS test loads.

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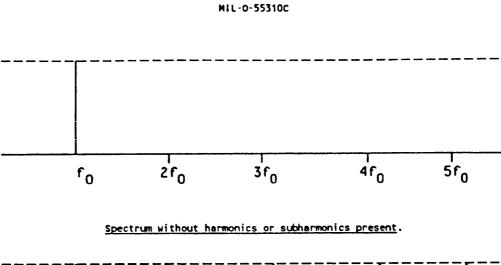
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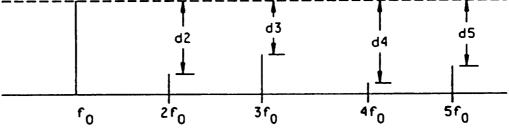
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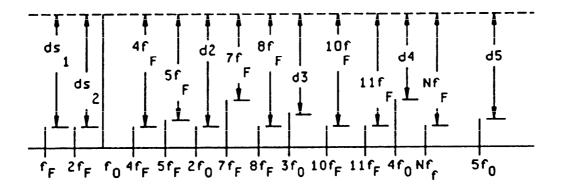
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Spectrum with harmonics only present.



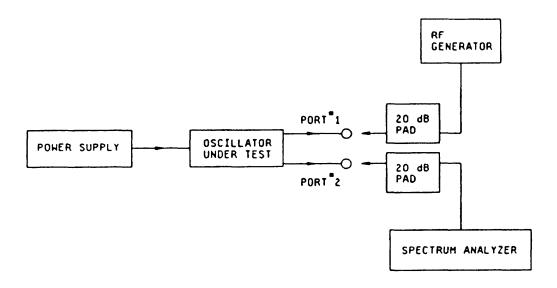
Spectrum with harmonics and subharmonics present.

LEGEND

 $\begin{array}{rcl} f_F &=& basic frequency which is multiplied.\\ 2f_F \ldots Nf_F &=& subharmonics.\\ f_0 &=& output frequency.\\ 2f_0 \ldots Nf_0 &=& harmonics level difference.\\ ds_1 \ldots ds_n &=& level difference of fundamental and subharmonic.\\ d2 \ldots dn &=& level difference of fundamental and harmonic.\\ \end{array}$

FIGURE 10. Harmonic and subharmonic distortion measurements.





NOTE: The 20 dB pads must be of the proper terminating impedance for the oscillator ports. They can consist of a matching network and attenuator with a total insertion loss of 20 ±2 dB.

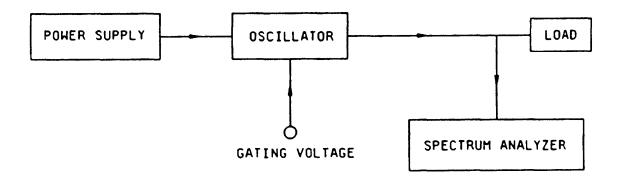


FIGURE 12. Test configuration for determining suppression of gated oscillators.

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FIGURE 11. Test configuration for determining isolation between output ports.



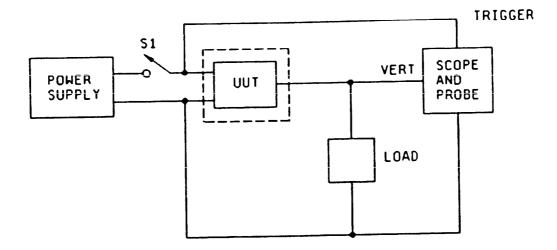


FIGURE 13. Test configuration for startup time measurement.

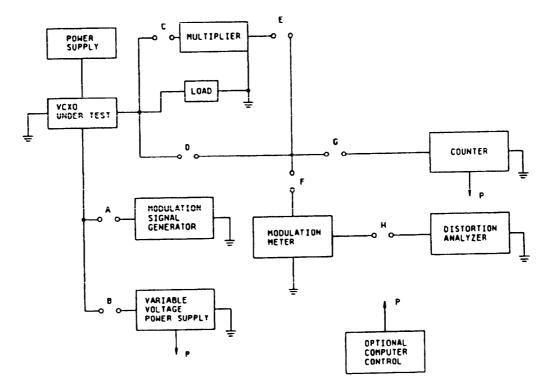
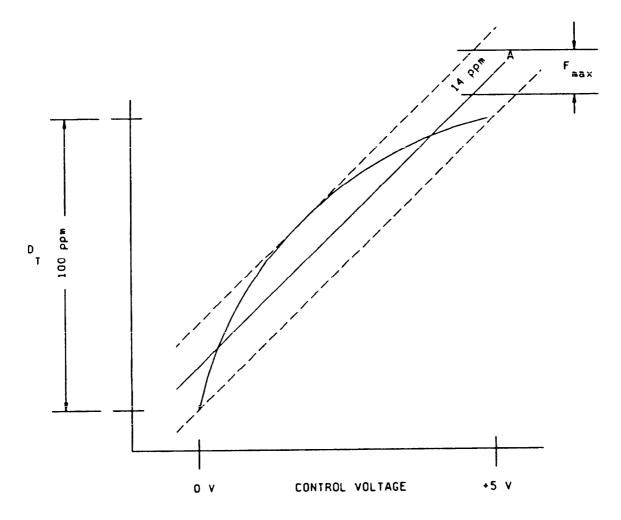


FIGURE 14. VCXO test configurations.



NOTE: The maximum deviation, F_{max} , from Best Straight Line "A" is ±14 ppm and the total deviation, D_T , is 100 ppm, so the linearity is ±14 ppm/100 ppm = ±14%

FIGURE 15. Deviation linearity.

APPENDIX A

REQUIREMENTS FOR HYBRID MICROCIRCUITS ELEMENTS

10. SCOPE

10.1 <u>Statement of scope</u>. This appendix establishes the procedures for the testing of the elements used in hybrid construction Class B and Class S oscillators to assist in achieving a level of quality and reliability commensurate with the intended application. It shall be used in conjunction with other documentation such as MIL-STD-883, the oscillator specification sheet (see 3.1) and an applicable element detail specification to establish the design, material, performance, control, and documentation requirements which are needed to achieve prescribed levels of quality and reliability. This appendix is a mandatory part of the specification. The information contained herein is intended for compliance only.

20. APPLICABLE DOCUMENTS

SPECIFICATIONS

MILITARY

MIL-M-38510 -	Microcircuits, General Specification for.
MIL-R-55342 -	Resistors, Fixed, Film, Chip, Established Reliability General Specification for.
MIL-C-55681 -	Capacitor, Chip Multiple Layer, Fixed, Unencapsulated, Ceramic Dielectric, Established Reliability, General Specification for.

STANDARDS

MILITARY

MIL-STD-750	•	Test Methods	for	Semiconductor	Device	:5.		

MIL-STD-977 - Test Methods & Procedures for Microcircuit Line Certification.

30. PROCEDURE

30.1 <u>Oscillator element evaluation requirements</u>. Herein, "oscillator" refers to the hybrid or multichip microcircuit and hybrid/integrated circuits. Six phases of oscillator element evaluation are required (see table X).

Requirement	Reference Paragraph	Table	
Nicrocircuit and semiconductor dice	30.2.2	XI	
Passive elements	30.2.3	XII	
Adhesives	30.2.4	N/A	
Ceramic substrate printed wiring	30.2.5	XIII	
Crystal element	30.2.6	N/A	
Process control	30.3	VIX	

TABLE X. Oscillator element evaluation summary.

APPENDIX A

30.1.1 <u>Precedence</u>. Unless otherwise specified in the specification sheet, the test requirements and conditions shall be as given herein.

30.1.2 <u>Sequence of testing</u>. Subgroups within a group (table) of tests may be performed in any sequence, but individual testing within a subgroup shall be performed in the sequence indicated.

30.1.3 <u>Protection from electrostatic discharge</u>. For elements and oscillators that are sensitive to electrostatic discharge, suitable handling precautions and grounding procedures shall be taken to protect the elements and oscillators from accidental damage.

30.2 Element evaluation.

30.2.1 General.

30.2.1.1 <u>Element</u>. Herein, "element" refers to materials for oscillator assembly. Before oscillator assembly, element characteristics shall be evaluated to assure their compatibility with oscillator requirements and assembly procedures (see table X).

30.2.1.2 <u>Characteristics</u>. Characteristics to be verified shall be those necessary for compatibility with the element specification and assembly procedures, and at least those which cannot be verified after assembly but could cause functional failure of the oscillator.

30.2.1.3 Location of element evaluation. Element evaluation may be performed at either the element supplier or oscillator manufacturing facility.

30.2.2 Evaluation of microcircuit and semiconductor dice.

30.2.2.1 <u>Electrical test specifications</u>. Electrical test parameter, values, limits (including deltas), and conditions shall be as specified in the microcircuit or semiconductor dice detail specification.

30.2.2.2 <u>Evaluation of die</u>. At the option of the manufacturer and with the approval of the qualifying activity of this specification, the evaluations of 30.2.2.2.1 and 30.2.2.2.2 can be waived provided the dice used in the oscillator assembly are JANC discrete semiconductors which have been tested in accordance with MIL-S-19500, Appendix H.

30.2.2.2.1 <u>Electrical testing of die</u>. Each die shall be electrically tested, which may be done at the wafer level provided all failures are identified and removed from the lot when the dice are separated from the wafer. The minimum requirements shall include static testing at +25°C (see MIL-M-38510, group A, subgroup 1 for microcircuits and MIL-S-19500, group A, subgroup 2, for semiconductors).

30.2.2.2.2 <u>Visual inspection of die</u>. Each die shall be visually inspected to assure conformance with the applicable die related requirements of MIL-STD-883, method 2010; MIL-STD-750, methods 2072 and 2073; and the die specification.

30.2.2.3 <u>Evaluation of assembled die</u>. From each wafer lot, a sample shall be evaluated in accordance with table XI and 30.2.2.3.1 through 30.2.2.3.4. Each sample shall be assembled into suitable packages that simulate the assembly methods and functional conditions of the element within the intended application.

30.2.2.3.1 Subgroup 1 and subgroup 2.

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30.2.2.3.1.1 <u>Sample size</u>. The class S sample requires 3 dice from each wafer, and a total of at least 10 dice from each wafer lot. The class B sample requires at least 10 dice from each wafer lot.

30.2.2.3.1.2 <u>Internal visual</u>. Internal visual inspection shall be performed to assure conformance with the applicable die related requirements of MIL-STD-883, method 2010; MIL-STD-750, methods 2072 and 2073; and the element specification.

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APPENDIX A

30.2.2.3.1.3 <u>Electrical testing</u>. For interim, post burn-in, and final electrical testing, the minimum requirements for microcircuits and for semiconductors shall include static tests at +25°C, at maximum rated operating temperature, and at minimum rated operating temperature.

30.2.2.3.2 <u>Subgroup 3</u>.

30.2.2.3.2.1 <u>Sample size</u>. From each wafer lot, a sample of at least 5 dice requiring 10 bond wires minimum shall be selected.

30.2.2.3.2.2 <u>Wire bond strength testing</u>. For wire bond strength testing:

- a. A minimum of 10 wires, consisting of chip to package bonds shall be destructively pull tested. An equal number of bonds shall be tested on each sample die.
- b. For beam lead and flip-chips, five dice shall be tested.
- c. The die metallization shall be acceptable if no failure occurs. If only one wire bond fails, another sample shall be selected in accordance with 30.2.2.3.2.1 and subjected to subgroup 3 evaluation. If the second sample contains no failures, the bonding test results are acceptable. If the second sample contains one or more failures, or if more than one failure occurs in the first sample, the lot of dice shall be rejected.
- d. The rejected wafer lot may be resubmitted to subgroup 3 evaluation if the failure was not due to defective die metallization.

30.2.2.3.3 Subgroup 4.

30.2.2.3.3.1 <u>Sample selection and reject criteria</u>. Sample selection and reject criteria shall be in accordance with method 2018 of MIL-STD-883.

30.2.2.3.4 <u>Subgroup 5</u>.

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30.2.2.3.4.1 <u>Class S sample size</u>. The class S sample requires 3 dice from each wafer, and a minimum of 10 dice from each wafer lot.

30.2.2.3.4.2 <u>Radiation testing requirement</u>. Radiation testing is required when applicable to the microcircuit device.

- a. For dose rate and latchup, photo current and latchup effects are functions of circuit configurations and thus should be simulated during tests.
- b. The sample shall be equally divided between methods 1017 and 1019 of NIL-STD-883.

30.2.3 Evaluation of passive elements.

30.2.3.1 <u>Electrical test specifications</u>. Electrical test parameters, values, limits, and conditions shall be as specified in the passive element specification.

30.2.3.2 <u>Evaluation of passive element lots</u>. At the option of the manufacturer and with the approval of the qualifying activity of this specification, the evaluations of 30.2.3.2.1 and 30.2.3.2.2 can be waived provided the passive elements used in the oscillator assembly are procured from the established reliability (ER) series of military specifications (e.g., MIL-R-55342, MIL-C-55681); however, the passive elements must meet a minimum established failure rate level of P for class B oscillators and a minimum established failure rate level of R for class S oscillators. These established reliability elements must be JAN devices and must be listed on the applicable QPL.

30.2.3.2.1 <u>Electrical testing of passive element lots</u>. Each passive element shall be 100 percent electrically tested at +25°C, or as specified in the passive element specification.

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APPENDIX A

	Cla	22	MIL-STD-883		STD-883	Quantity	Reference
Subgroup	s	8	Test	Method	Condition	(accept no.)	paragraph
1	×	x	Internal visual	2010 2072 2073 <u>1</u> /		10 (0)	30.2.2.3.1.2
2	×		Stabilization bake	1008	С	10 (1)	
	x		Temperature cycling	1010	С		
	×		Mechanical shock or	2002 2001	C, Y1 direction B, Y1		
			Constant acceleration	2001	direction		
	X		Interim electrical				30.2.2.1
	×		Burn-in	1015	240 hours min. at +125°C		30.2.2.1
	x		Postburn-in electrical				30.2.2.1
	×		Steady-state life	1005			30.2.2.1
	x	x	Final electrical				30.2.2.1
3	x	x	Wire bond evaluation	2011		10(0) wires or 20(1) wires	30.2.2.3.2.2
4	x		Scanning electron microscope (SEM)	2018		See method 2018	30.2.2.3.3
5	x		Radiation				
	x		Dose rate and latchup	1020		10 (0)	30-2-2-3-4
	x		Total dose	1019		5 (0)	
	x		Neutron irradiation	1017		5 (0)	

TABLE XI. Assembled dice evaluation requirements.

1/ MIL-STD-750 methods.

APPENDIX A

30.2.3.2.2 <u>Visual inspection of passive elements lots</u>. Each class S element shall be visually inspected to assure conformance with the applicable element related requirements of MIL-STD-883, method 2032, and the detail/acquisition specification. For class B, sample inspect using a sample of 22(0) to assure conformance with the applicable element related requirements of MIL-STD-883, method 2032, and the detail/acquisition specification.

30.2.3.3 <u>Evaluation of assembled passive elements</u>. From each inspection lot of passive elements, the randomly selected sample shall be evaluated in accordance with table XII and 30.2.3.3.1 through 30.2.3.3.3.

- a. Each sample shall be assembled into suitable packages when required to perform the applicable testing that simulate the assembly methods and functional conditions of the element within the intended application.
- b. The sample shall contain at least 20 wire bonds (an equal number on each element) if the operation is applicable.

30.2.3.3.1 <u>Visual inspection (subgroup 1)</u>. Passive elements shall be visually inspected in accordance with MIL-SID 883, method 2017, for evidence of corrosion or damage attributable to the test and conditioning sequence.

30.2.3.3.2 <u>Electrical testing of passive elements (subgroup 1)</u>. Passive elements shall be electrically tested, using a sample of 10, at +25°C \pm 5°C for the following characteristics (minimum).

- a. Resistors: DC resistance.
- b. Capacitors: Ceramic type Dielectric withstanding voltage, insulation resistance, capacitance, and dissipation factor.
- c. Capacitors: Tantalum type DC leakage current, capacitance, and dissipation factor.
- d. Capacitors: Netal insulation semiconductor type (MIS) DC leakage current, capacitance, dielectric withstanding voltage.
- e. Inductors: DC resistance, inductance, and Q.

30.2.3.3.3 <u>Wire bond strength testing (subgroup 2)</u>. Wire bond strength testing applies to elements which are wire bonded during the oscillator assembly operation. The sample shall include at least 5 elements and 10 bond wires minimum.

- a. At least 10 wires, consisting of element to substrate and package bonds shall be destructively pull tested. An equal number of bonds shall be tested on each sample element.
- b. The element metallization shall be acceptable if no failure occurs. If only one wire bond fails, a second sample shall be selected from the remaining elements in the evaluation sample, and subjected to the test as specified in 30.2.3.3.3a. If the second sample contains no failures the bonding test results are acceptable. If the second sample contains one or more failures, or if more than one failure occurs in the first sample, the element lot shall be rejected.
- c. The element inspection lot may be resubmitted to evaluation if the failure was not due to defective element metallization.

30.2.4 <u>Evaluation of adhesives</u>. The polymeric adhesives used in microelectronic applications shall be subjected to and pass the evaluation procedures detailed in method 5011 of MIL-STD-883.

30.2.5 Evaluation of ceramic substrate printed wiring (substrates).

30.2.5.1 <u>Definition</u>. For the purpose of substrate evaluation, a substrate inspection lot shall consist of homogeneous substrates having the same number of layers, manufactured using the same facilities, processes, materials, and vacuum deposited, plated or printed as one lot.

APPENDIX A

	cı	ass		MIL-	STD-883	Quantity	Reference
Subgroup	s	В	Test	Nethod	Condition	(accept no.)	paragraph
1	x	x	Visual inspection	2017		10(1)	30.2.3.3.1
	x		Stabilization bake	1008	с	10 (1)	
	x		Temperature cycling	1010	с		
	x		Mechanical shock or	2002	C, Y1 direction		
	×		Constant acceleration	2001	B, Y1 direction		
	x		Voltage conditioning or				30.2.3.1
	×		ageing (capacitors)				
	×	ĺ	Visual inspection	2017			30.2.3.3.1
	×	×	Electrical				30.2.3.3.2
2	x		Wire bond evaluation	2011		10(0) wires or 20(1) wires	30.2.3.3.3

TABLE XII. Assembled passive element evaluation requirements.

30.2.5.2 <u>Electrical test specifications</u>. Electrical test parameters, values, limits, and conditions shall be as specified in the applicable substrate detail specification.

30.2.5.3 Evaluation of substrate element lots.

30.2.5.3.1 <u>Electrical testing</u>. Each substrate shall be electrically tested at +25°C, as specified in the applicable substrate detail specification.

30.2.5.3.2 <u>Visual inspection</u>. Each substrate shall be visually inspected to assure conformance with the applicable requirements of MIL-STD-883, method 2032, and the applicable substrate detail specification.

30.2.5.4 <u>Evaluation of assembled substrate elements</u>. From each inspection lot of substrates, a randomly selected sample shall be evaluated in accordance with table XIII and 30.2.5.4.1 through 30.2.5.4.3. With preparing activity approval, destructive tests may be performed on test coupons which provide the required test data. The test coupons must be made with the same materials that were used in the manufacturing of the inspection lot and processed at the same time as the inspection lot.

30.2.5.4.1 <u>Subgroup 1</u>. A minimum of five samples shall be submitted to subgroup 1 testing.

30.2.5.4.1.1 <u>Physical dimension</u>. Inspect in accordance with MIL-STD-883, method 2016, and the applicable substrate detail specification.

30.2.5.4.1.2 <u>Visual inspection</u>. Inspect in accordance with MIL-STD-883, method 2032, and the applicable substrate detail specification.

APPENDIX A

Subgroup	Test	HIL-	STD-883	Quantity	Reference
		Nethod	Condition	(accept no.)	paragraph
1	Physical dimension	2016		5 (0)	30.2.5.4.1.1
	Visual inspection	2032			30.2.5.4.1.2
	Electrical				30.2.5.4.1.3
2	Conductor thickness or conductor resistivity			3 (0)	30.2.5.4.2.1 30.2.5.4.2.2
	Film adhesion				30.2.5.4.2.3
	Solderability				30.2.5.4.2.4
3	Temperature coefficient of resistance			2 (0)	30.2.5.4.3.1
	Wire bond evaluation	2011		10 wires (0) 30 wires (1)	30.2.5.4.3.2
	Die shear evaluation	2019		2 (0)	30.2.5.4.3.3

TABLE XIII. Assembled substrate evaluation requirements.

30.2.5.4.1.3 <u>Electrical</u>. Substrates shall be electrically tested at 25°C for the following characteristics (minimum). Requirements shall be as specified in the applicable substrate detail specification.

a. Resistors: DC resistance.

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- b. Capacitors: Capacitance. If specified in the applicable substrate detail specification, test for dielectric withstanding voltage, insulation resistance, and dissipation factor.
- c. For multilayered substrates, continuity and isolation testing shall be performed to verify the interconnection of conductors as specified in the applicable substrate detail specification.

30.2.5.4.2 <u>Subgroup 2</u>. A minimum of three samples that have been subjected to, and passed, subgroup 1 testing shall be submitted to subgroup 2 testing.

30.2.5.4.2.1 <u>Conductor thickness</u>. Measure conductor thickness in accordance with the applicable substrate detail specification. Conductor thickness shall meet the requirements specified in the applicable substrate detail specification.

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APPENDIX A

30.2.5.4.2.2 <u>Conductor resistivity</u>. Measure conductor resistivity in accordance with the applicable substrate detail specification. Conductor resistivity shall meet the requirements specified in the applicable substrate detail specification.

30.2.5.4.2.3 <u>Film adhesion</u>. Perform film adhesion testing in accordance with MIL-STD-977, method 4500. The substrate and tape shall show no evidence of peeling or flaking of metallization.

30.2.5.4.2.4 <u>Solderability</u>. For solderable substrates only, perform solderability testing if specified in the applicable substrate detail specification in accordance with the applicable substrate detail specification.

30.2.5.4.3 <u>Subgroup 3</u>. A minimum of two samples that have been subjected to, and passed, subgroup 1 testing shall be submitted to subgroup 3 testing.

30.2.5.4.3.1 <u>Temperature coefficient of resistance (TCR)</u>: When specified in the applicable detail specification, perform temperature coefficient of resistance (TCR) testing for resistors in accordance with MIL-STD-202, method 304. TCR shall meet the requirements specified in the applicable detail specification.

- a. Thick film type: Test as a minimum, two resistors from each resistor paste sheet resistance value.
 One from the smallest and one from the largest area resistors at -55°C, and +125°C using a reference reading at +25°C, or temperatures as specified in the substrate detail specification.
- b. Thin film type: Test as a minimum, the highest value resistor at +125°C using a reference reading at +25°C or temperatures as specified in the substrate detail specification.
- c. If specified in the applicable detail specification, TCR tracking testing shall be performed. TCR tracking shall meet the requirements specified in the applicable substrate detail specification.

30.2.5.4.3.2 <u>Wire bond strength testing</u>. For wire bondable substrates, perform wire bond strength testing in accordance with MIL-STD-883, method 2011. The sample shall include at least 2 substrates and 10 bond wires minimum.

For gold metallized class S substrates that at the hybrid level are intended to contain aluminum wire bonds, aluminum wires shall be placed as specified in the detail specification and these wire bond samples shall be baked for 1 hour at +300°C in either an air or inert atmosphere prior to the performance of wire bond strength testing.

- a. At least 10 wires, consisting of substrate to substrate bonds, shall be destructively pull tested. An equal number of bonds shall be tested on each sample substrate.
- b. The substrate metallization shall be acceptable if no failure occurs. If only 1 wire bond fails, a second sample of a minimum of 20 wires shall be prepared using the same wire type/size and the same type equipment as the failed bond. If the second sample contains one or more failures, or if more than one failure occurs in the first sample, then the substrate inspection lot shall be rejected.
- c. The substrate inspection lot may be resubmitted to evaluation if the failure(s) was not due to defective substrate metallization.

30.2.5.4.3.3 <u>Die shear strength testing</u>. Perform shear strength testing in accordance with MIL-STD-883, method 2019. At least two dice per substrate shall be attached and tested for each die attachment method, as specified in the applicable substrate detail specification. If a failure occurs at less than the specified force and is not due to defective substrate materials, the lot shall be resubmitted to die shear evaluation and the failure mode documented.

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APPENDIX A

30.2.6 <u>Evaluation of crystals</u>. The manufacturer shall document a crystal evaluation program plan as part of the product assurance program as specified in 3.2.1.2.1. The plan shall define the acceptance criteria used to evaluate crystals at the following stages as a minimum:

a. The crystal as a blank prior to metallization, or as part of receiving inspection.

b. At a post metallization and pre-mount stage.

30.3 <u>Control of critical process and procedure (process control)</u>. The indicated process shall be controlled in accordance with table XIV and 30.3.1.

Operation		-883 method Condition	Paragraph
Wire bonding	2011 2023		30.3.1

TABLE XIV. Process control summary.

30.3.1 Wire bonding.

30.3.1.1 <u>General</u>. A process machine/operator evaluation shall be performed:

- a. When a machine is put into operation. In addition for class S, an evaluation shall be performed when the machine is taken out of operation, unless an evaluation was performed within the last hour.
- b. Periodically while in operation, not to exceed 4 hours.
- c. When the operator is changed.
- d. When any machine part or an adjustment has been made.
- e. When the spool of wire is changed.
- f. When a new oscillator device is started. (Unless the machine was evaluated using test samples that also simulate the new oscillator device.)

30.3.1.2 <u>Test samples</u>. Test samples that simulate the production oscillator may be destructively evaluated in lieu of the product.

30.3.1.3 Process machines. Process machines not meeting the evaluation requirements shall not be used.

30.3.1.4 <u>Corrective action of process machine</u>. A process machine may be returned to operation only after appropriate corrective action has been implemented and the machine has been evaluated and passed testing in accordance with table XIV as required.

30.3.1.5 <u>Data record</u>. A data record shall be maintained and identifiable to each machine, operator, shift, and date of test.

30.3.1.6 <u>Wire bonding</u>. Wire bond strength testing shall be performed as follows.

APPENDIX A

30.3.1.6.1 <u>Process machine/operator evaluation</u>. A minimum sample of 10 wires total from 3 devices shall be destructively pull tested in accordance with MIL-STD-883, method 2011, for class B.

- a. The sample shall consist of bonds to elements typical of oscillator assembly operation for class B. For class S, a sample of 15 wires minimum from 3 devices shall be pulled on each sample and shall include as a minimum one wire each from a typical transistor, diode, capacitor, and resistor chip and 5 wires from a header to substrate, as applicable. If more than one wire size or type is present at least 4 samples of each size and type shall be tested and pull strength data shall be read and recorded.
- b. Evaluation results are acceptable if no failure occurs below the present value given in table I of MIL-STD-883, method 2011. If any of the sample wires fail, the bonder shall be deactivated and corrective action taken. When a new sample has been prepared, tested, and passed this procedure, the machine/operator has been certified or recertified, it can be returned to production.

30.3.1.7 Lot sample bond strength. From each wire bonding lot, a sample of at least two oscillators shall be nondestructively tested in accordance with M1L-STD-883, method 2023. Oscillators with known visual wire bonding rejects shall not be excluded from this sample.

- a. A wire bonding lot consist of oscillators that are consecutively bonded using the same set-up and wire, by one machine/operator during the same period not to exceed 4 hours.
- b. In each sample oscillator, at least 15 wires shall be tested including 1 wire from each type of transistor, diode, capacitor, and resistor chips, 3 wires from each type of integrated circuit, and 5 wires connecting package leads, as applicable. If there are less than 15 wires in the oscillator, all wires shall be tested. Sample oscillators shall be inspected for lifted wires. Lifted wires shall be counted as nondestructive pull test failures.
- c. The wire bonding lot shall be acceptable if no failure occurs. If one wire/bond fails another sample of two oscillators shall be selected and 100 percent nondestructively tested. If the second sample contains no failures, the wire bonding lot is acceptable. If the second sample also contains failure(s), or more than one wire/bond fails in the first sample, the bonding machine/operator shall be removed from operation.
- d. The failures shall be investigated and appropriate corrective action shall be implemented. The machine/operator shall be recertified in accordance with 30.3.1.6.1 before being returned to operation. All oscillators bonded since the previous certification (lot sample bond strength test) shall be subjected to 100 percent nondestructive bond strength testing.

APPENDIX B

PROCEDURE FOR QUALIFICATION INSPECTION

10. SCOPE

10.1 <u>Statement of scope</u>. This appendix contains the details of the quality assurance program which serves as the basis for qualification. This appendix is a mandatory part of the specification. The information contained herein is intended for compliance only.

20. APPLICABLE DOCUMENTS. This section is not applicable to this appendix.

30. SUBMISSION

30.1 Sample.

30.1.1 <u>Single-type submission</u>. A sample consisting of eight sample units of the specific crystal oscillator for which qualification is sought shall be submitted. For hybrid construction oscillators, an additional three samples (or five samples, see table IV) shall be submitted for qualification in order to perform the internal water vapor content test. Alternatively, the manufacturer may use samples which have previously been subjected to other qualification inspections for internal water vapor content testing.

30.1.2 <u>Combined-type submission</u>. To obtain qualification for the frequency and temperature range for an individual specification sheet for which qualification is sought, samples for testing shall be selected on the following basis:

- a. Four sample units at the lowest frequency, widest operating temperature range and most stringent temperature stability over that temperature range for which qualification is sought shall be submitted.
- b. Four sample units of the highest frequency, widest operating temperature range and most stringent temperature stability over that temperature range for which qualification is sought shall be submitted. For hybrid construction oscillators, an additional three samples (or five samples, see table IV) shall be submitted for qualification in order to perform the internal water vapor content test. Alternatively, the manufacturer may use samples which have previously been subjected to other qualification inspections for internal water vapor content testing.

30.1.3 <u>Information to be submitted to the qualifying activity</u>. The following information along with that required by 6.4 shall be submitted to the qualifying activity.

- a. A program outlining compliance with this appendix.
- b. A list of all PINs for which qualification is desired.
- c. Drawings covering the design of these items, including the components and materials used.
- d. A sample of the in-process inspections performed for each device type for which qualification is requested.
- e. Test results demonstrating that at least eight oscillators of the type for which qualification is requested have met the requirements of the applicable screening tests of table II or table III and the qualification inspection requirements of table IV.

30.1.4 <u>Listing on the QPL</u>. Listing on the QPL shall be granted after approval of the information submitted by the manufacturer (see 30.1.3).

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APPENDIX B

40. EXTENSION OF QUALIFICATION

40.1 <u>Extent of qualification</u>. Extent of qualification shall be restricted to the individual specification sheet unless otherwise specified herein. Qualification of one crystal oscillator may be the basis for qualification of another crystal oscillator within the original frequency range and as indicated in tables XV, XVI, and XVII.

TABLE XV.	Extent of	qualification	of	product	assurance	level.

Qualification of product assurance level	Will qualify product assurance level
B	8
S	8,5

TABLE XVI.	Extent of	fqualif	ication	for te	mperature	range.

Qualification of temperature range <u>1</u> /	Will qualify temperature range
A	A, B, C, D, E
B	B, C, D, E
C	C
D	C, D, E
E	C, E

1/ S level qualification samples, which have been

final-frequency tested over both the A and B temperature ranges, will qualify level B to the A temperature range.

TABLE XVII. Extent of gualification by specification sheet.

Qualification of specification sheet	Will qualify specification range
MIL-0-55310/11	MIL-0-55310/11, /15, and /18
MIL-0-55310/15	N N
HIL-0-55310/18	86
MIL-0-55310/8	MIL-0-55310/8, /14, /16, and /17
MIL-0-55310/14	N N
MIL-0-55310/16	
MIL-0-55310/17	

<u>Title</u>	Paragraph/Table/Figure	Page
"JAN" brand	3.7.3	22
Acceleration	3.6.41	20
	4.8.42	55
Acceleration (nonoperating)	3.6.41.1	20
	4.8.42.1	55
Acceleration (operating)	3.6.41.2	20 56
	4.8.42.2 3.6.17	16
Acceleration sensitivity	4.8.18	42
	6.3.30	65
Acceleration sensitivity, 2 g tip-over	3.6.17.2	16
······································	4.8.18.2	43
Acceleration sensitivity, random vibration	4.8.18.3.2	44
Acceleration sensitivity, sinusoidal vibration	4.8.18.3.1	44
Acceleration sensitivity, steady-state	3.6.17.1	16 43
	4.8.18.1 3.6.17.3	45
Acceleration sensitivity, vibration	4.8.18.3	43
Accumulated time error	3.6.31	18
Accumulated time error	4.8.32	50
Acoustic noise (operating)	3.6.39	20
	4.8.40	54
Acquisition requirements	6.2	61
Acquisition requirements (crystal oscillators		
covered by specification sheets)	6.2.1	61
Acquisition requirements (crystal oscillators	()]	62
not covered by specification sheets)	6.2.2 4.3.9	24
Air flow conditions for temperature tests	3.6.16.5	16
Allan variance	4.8.17.5	42
	6.3.29	65
Ambient pressure	3.6.45	20
	4.8.46	57
Ambient pressure (nonoperating)	3.6.45.1	20
	4.8.46.1	57
Ambient pressure (operating)	3.6.45.2	20
	4.8.46.2 3.6.16.4	57 16
Amplitude noise	4.8.17.4	42
	6.3.28	65
APPLICABLE DOCUMENTS	2.	2
	20. (Appendix A)	79
	20. (Appendix B)	89
Assembled dice evaluation requirements	TABLE XI	82
Assembled passive element evaluation requirements	TABLE XII	84
Assembled substrate evaluation requirements	TABLE XIII	85
Basic bench test configuration	FIGURE 1	69 27
Basic test conditions	4.3.7	24 22
Beryllium oxide package identifier	3.7.5 3.6.33.1	18
BIT, oven operating temperature	4.8.34.1	51
BIT, oven supply voltage	3.6.33.2	18
BIT, oven supply voltage	4.8.34.2	51
BIT, R-F output voltage	3.6.33.3	18
	4.8.34.3	51
Built-in-test (BIT) (types 4 and 6)	3.6.33	18
	4.8.34	51
Burn- in	4.5.3	27
Calibration	3.5.10	13
Changes from previous issue	6.6	68

.

-

Title	Paragraph/Table/Figure	Page
Characteristics	30.2.1.2	80
Civil agencies	5.3.2	60
Class B oscillators	4.7.1.2.1.1	30
	4.7.1.3.1	32
	4.7.1.2.2.1	30
Class S oscillators	4.7.1.2.1.2	30
	4.7.1.2.2.2	30
	4.7.1.3.2	32
Class S sample size	30.2.2.3.4.1	81
Classification	1.2	1
Classification of inspections	4.2	23
Cleaning	5.1.1.1	59
Cleanliness and atmosphere control in work areas	3.2.1.2.2	5
Clock accuracy (corrected pulse train output)	3.6.32.1	18
	4.8.33.1	51
Clock accuracy (digital time-of-day output)	3.6.32.2	18
	4.8.33.2 3.6.32	51 18
Clock accuracy (type 7)	3.0.32 4.8.33	50
	6.3.41	50 66
	30.1.2	89
Combined-type submission	3.5.7	12
Components Compound bonding	3.2.1.2.4.4	6
Compound Bonding Conducted interference	3.6.36	19
	4.8.37	52
Conductor resistivity	30.2.5.4.2.2	86
Conductor thickness	30.2.5.4.2.1	85
Construction technology	3.5.6	12
Control of critical process and procedure (process control)	30.3	87
Corrective action of process machine	30.3.1.4	87
Crystal oscillators (XO)	6.3.1	62
Crystal unit	3.5.7.1.1	12
Cultured guartz	3.4.1.1	8
Dash number	1.2.1.2	1
Data record	30.3.1.5	87
Definition	30.2.5.1	83
Definitions	6.3	62
Design and construction	3.5	8
Design for nuclear survivability	3.5.12	13
Design, processing, manufacturing equipment, and materials instructions	3.2.1.2.1	4
Deviation (slope) sensitivity	3.6.30.3	18
	4.8.31.3	49
Deviation linearity	3.6.30.5	18 49
	4.8.31.5 6.3.38	
	6.3.36 FIGURE 15	66 78
• The second s	3.6.30.4	18
Deviation slope polarity	4.8.31.4	49
	30.2.5.4.3.3	86
Die shear strength testing	3.2.1.1	4
Discrete construction	3.5.1.1	8
	3.5.6.1	12
Discrete or mixed construction	3.6.1.2.1	13
Discrete or mixed construction	4.8.2.2.1	34
Disposition of sample units	4.7.1.2.4	30
Disposition of sample units	4.7.1.3.3	32
	4.7.2.1.3	33
Dose rate	3.6.47.2	21
NA22 1812	4.8.48.2	57
Drying	5.1.1.2	59
עוווי קוע		

.

. . .

.

1

1

Paragraph/Table/Figure Page Title 17 3.6.22 Duty cycle 6.3.34 65 4.8.23 46 Duty cycle (square wave output waveform) 46 TABLE IX Duty cycle measurement level 30.2.5.4.1.3 85 Electrical 80 30.2.2.1 Electrical test specifications 81 30.2.3.1 30.2.5.2 84 81 30.2.2.3.1.3 Electrical testing 30.2.5.3.1 84 80 30.2.2.2.1 Electrical testing of die 81 30.2.3.2.1 Electrical testing of passive element lots 83 Electrical testing of passive elements (subgroup 1) 30.2.3.3.2 14 3.6.6.2 Electrical-frequency-control 4.8.7.2 36 63 6.3.16 8 3.2.4 Electrostatic discharge (ESD) control program 80 30.2.1.1 Element 30.2 80 Element evaluation 7 3.2.1.2.4.5 Element replacement 6 3.2.1.2.4.2 Element wire rebonding 3.2.1.2.3 5 Environment control 24 4.3.4 Equilibrium conditions 30.2.4 83 Evaluation of adhesives 80 30.2.2.3 Evaluation of assembled die 30.2.3.3 83 Evaluation of assembled passive elements 84 30.2.5.4 Evaluation of assembled substrate elements 30.2.5 83 Evaluation of ceramic substrate printed wiring (substrates) 87 30.2.6 Evaluation of crystals 80 30.2.2.2 Evaluation of die 80 Evaluation of microcircuit and semiconductor dice 30.2.2 81 30.2.3.2 Evaluation of passive element lots 81 30.2.3 Evaluation of passive elements 84 Evaluation of substrate element lots 30.2.5.3 20 3.6.42 Explosion (operating) 56 4.8.43 90 40. EXTENSION OF QUALIFICATION 90 40.1 Extent of qualification 90 TABLE XVII Extent of qualification by specification sheet TABLE XVI 90 Extent of qualification for temperature range TABLE XV 90 Extent of qualification of product assurance level 60 5.4.1 Exterior containers 63 6.3.15 External-frequency-adjustment oscillator 32 4.7.1.3.1.1 Failed sample(s) 4.5.5 27 Failures 28 4.6.3 33 4.7.2.1.2 65 6.3.33 Fall time 30.2.5.4.2.3 86 Film adhesion 36 4.8.7 Frequency adjustment 14 Frequency adjustment (frequency-adjustable oscillators) 3.6.6 19 3.6.34 Frequency aging 51 4.8.35 6.3.42 66 Frequency aging (long-term stability) 19 3.6.34.1 Frequency aging (types 1 and 2) 51 4.8.35.1 19 3.6.34.2 Frequency aging (types 3, 4, 5, 6, 7, and 8) 52 4.8.35.2 52 4.8.35.2.1 Frequency aging (types 3, 5, and 7) 4.8.35.2.2 52 frequency aging (types 4, 6, and 8)

93

ı.

Title	Paragraph/Table/Figure	Page
Frequency deviation (types 2, 5, and 6)	3.6.30	18
	4.8.31	48
Frequency offset	6.3.10	63
Frequency offset at reference temperature	3.7.2	22
Frequency warmup	3.6.7	14
	4.8.8	36
	6.3.17	63
Frequency-environment tolerance	3.6.37	19
	4.8.38	53
	6.3.44	67
Frequency-load tolerance	3.6.14	16
	4.8.15	41
	6.3.25	64
Frequency-temperature slope at reference temperature	3.6.11	15
	4.8.12	39
	6.3.23	64
Frequency-temperature stability	3.6.10	15
	4.8.11	38
	6.3.22	64
Frequency-temperature stability (one-half temperature cycle)	3.6.10.1	15
	4.8.11.1	39
Frequency-temperature stability including hysteresis	3.6.10.2	15
	4.8.11.2	39
Frequency-temperature stability including hysteresis and trim effect	3.6.10.4	15
·····	4.8.11.4	39
Frequency-temperature stability including trim effect		
(one-half temperature cycle)	3.6.10.3	15
	4.8.11.3	39
Frequency-thermal transient stability	3.6.12	15
	4.8.13	40
Frequency-voltage tolerance	3.6.13	16
	4.8.14	41
	6.3.24	64
Functional requirements	5.4.3.1	61
Fungus	3.6.54	21
	4.8.55	59
General	30.2.1	80
	30.3.1.1	87
	5.4	60
General rework provisions	3.2.1.2.4.1	5
Government documents	2.1	2
Group A inspection	4.7.1.2	30
	TABLE V	31
Group B inspection	4.7.1.3	32
Group C inspection	4.7.2.1	32
	TABLE VII	34
Groups A and B, zero defect sampling plan	TABLE VI	31
Harmonic and subharmonic distortion	3.6.23	17
	4.8.24	46
	6.3.35	65
Harmonic and subharmonic distortion measurements	FIGURE 10	75
Hermetic seal	3.6.1.2	13
	4.8.2.2	33
Hermetically sealed oscillators	5.1.1.4.1	59
High vacuum seal	6.3.11	63
High vacuum seal (types 4 and 6)	3.6.1.3	13
······································	4.8.2.3	35

Title	Paragraph/Table/Figure	Page
N decid concernation	3.2.1.2	4
Hybrid construction	3.5.1.2	8
	3.5.6.2	12
	3.6.1.2.2	13
	4.8.2.2.2	35
		13
Hybrid microcircuit elements	3.5.7.5	
Hysteresis	6.3.20	64
Information to be submitted to the qualifying activity	30.1.3	89
Initial accuracy at reference temperature	3.6.5	14
	4.8.6	36
	6.3.13	63
Initial frequency aging	6.3.18	63
Initial frequency aging (types 4 and 6)	3.6.8	14
	4.8.9	37
Initial frequency-accuracy including trim effect		
(one-half temperature cycle)	4.8.10.3	38
Initial frequency-temperature accuracy	3.6.9	15
	4.8.10	37
	6.3.19	63
Initial frequency-temperature accuracy (one-half temperature cycle)	3.6.9.1	15
mittat requercy temperature accuracy (one math temperature syster)	4.8.10.1	37
t-idial formulation provident including hypersis	3.6.9.2	15
Initial frequency-temperature accuracy including hysteresis	4.8.10.2	38
		15
Initial frequency-temperature accuracy including hysteresis and trim eff	4.8.10.4	38
	4.0.10.4	50
Initial frequency-temperature accuracy including trim effect		45
(one-half temperature cycle)	3.6.9.3	15
Input current-power	3.6.4	14
	4.8.5	35
Input power aging	6.3.43	66
Input power aging (types 4 and 6)	3.6.35	19
	4.8.36	52
Inspection conditions	4.3	23
Inspection lot	4.7.1.1.2	30
Inspection of packaging	4.7.3	33
Inspection of product for delivery	4.7.1	28
Intended use	6.1	61
Intermediate packs	5.1.1.5	60
Internal conductors (hybrid construction only)	3.5.3	9
Internal visual	30.2.2.3.1.2	80
Internal visual inspection for crystal oscillators of hybrid constructio		27
Internal water vapor content	4.8.56	59
Lead finish	3.5.4.2	10
	3.5.4.1	10
Lead or terminal material	4.8.49.2	58
Lead-less chip carriers (LCC)	5.4.3.1.2	61
Leakage test	5.1.1	59
Level A		60
	5.2.1	
	5.2.4.1	60
Level B	5.2.2	60
	5.2.4.2	60
Level C	5.1.2	60
	5.2.3	60
	5.2.4.3	60
Lid seal rework	3.2.1.2.4.6.1	7
Listing on the QPL	30.1.4	89
	3.5.11	13
Load test circuit	30.2.1.3	80
Location of element evaluation	30.3.1.7	88
Lot sample bond strength		27
Lots resubmitted for burn-in	4.5.4	č 1

.

~~~ ·

# NIL-O-55310C INDEX

| <u>Title</u>                                                       | Paragraph/Table/Figure | Page |
|--------------------------------------------------------------------|------------------------|------|
| Magnetic field (operating)                                         | 3.6.43                 | 20   |
|                                                                    | 4.8.44                 | 56   |
| Magnetic field sensitivity                                         | 3.6.18                 | 16   |
|                                                                    | 4.8.19                 | 44   |
|                                                                    | 6.3.31                 | 65   |
| Magnetic field sensitivity, ac                                     | 3.6.18.2               | 16   |
|                                                                    | 4.8.19.2               | 45   |
| Magnetic field sensitivity, dc                                     | 3.6.18.1               | 16   |
|                                                                    | 4.8.19.1               | 44   |
| Manufacturer and user frequency offset calibrated                  | 3.5.10.2               | 13   |
| Nanufacturer and user nominal frequency calibrated                 | 3.5.10.3               | 13   |
| Manufacturer calibrated                                            | 3.5.10.1               | 13   |
| Marking                                                            | 3.7                    | 22   |
|                                                                    | 5.3                    | 60   |
| N . A                                                              | 3.4                    | 8    |
| Materials                                                          | 4.4                    | 24   |
| Materials inspection                                               | 3.6.6.1                | 14   |
| Mechanical-frequency-adjustment                                    |                        |      |
|                                                                    | 6.3.14                 | 63   |
| Mechanical-frequency-adjustment (frequency-adjustable oscillators) | 4.8.7.1                | 36   |
| Metals                                                             | 3.5.2                  | 9    |
| Methods of inspection                                              | 4.8                    | 33   |
| Microcomputer compensated crystal oscillator (MCXO)                | 6.3.7                  | 62   |
| Military Part or Identifying Number (PIN)                          | 1.2.1                  | 1    |
| Nixed construction                                                 | 3.5.6.3                | 12   |
| Modulation distortion                                              | 3.6.30.6               | 18   |
|                                                                    | 4.8.31.6               | 50   |
|                                                                    | 6.3.39                 | 66   |
| Modulation frequency response                                      | 3.6.30.7               | 18   |
|                                                                    | 4.8.31.7               | 50   |
|                                                                    | 6.3.40                 | 66   |
| Modulation-control input impedance (types 2, 5, and 6)             | 3.6.29                 | 17   |
|                                                                    | 4.8.30                 | 48   |
| Modulation-control input voltage (types 2, 5, and 6)               | 3.6.2.3                | 14   |
| Hoodtation-control input voltage (types 2, 3, and 0)               | 4.8.3.3                | 35   |
| Maintuna anaiotana                                                 | 3.6.49                 | 21   |
| Moisture resistance                                                | 4.8.50                 | 58   |
|                                                                    | 3.4.1.3                | 8    |
| Natural quartz                                                     |                        | 21   |
| Neutrons                                                           | 3.6.47.3               |      |
|                                                                    | 4.8.48.3               | 58   |
| Nickel plate or undercoating                                       | 3.5.4.4.1              | 12   |
| Non-Government publications                                        | 2.2                    | _4   |
| Noncompliance                                                      | 4.7.2.1.4              | 33   |
| Nonhermetically sealed oscillators                                 | 5.1.1.4.2              | 60   |
| NOTES                                                              | 6.                     | 61   |
| O-ring-solder seal (nonhermetic)                                   | 3.6.1.1                | 13   |
|                                                                    | 4.8.2.1                | 33   |
| Order of precedence                                                | 2.3                    | 4    |
| Oscillator element evaluation requirements                         | 30.1                   | 79   |
| Oscillator element evaluation summary                              | TABLE X                | 79   |
|                                                                    | 3.6.4.1                | 14   |
| Oscillator input current-power                                     | 4.8.5.1                | 35   |
|                                                                    |                        | 14   |
| Oscillator supply voltage                                          | 3.6.2.1                |      |
|                                                                    | 4.8.3.1                | 35   |
| Oscillators                                                        | 6.1.1                  | 61   |
| Other Government documents, drawings, and publications             | 2.1.2                  | 3    |
| Output impedance                                                   | 3.6.25                 | 17   |
|                                                                    | 4.8.26                 | 47   |
| Output logic voltage levels                                        | TABLE I                | 17   |
| Output logic voltage levels (square wave output waveform)          | 3.6.20.3               | 17   |
| eacher redio rerrede rerere reder a unit onther unit reserves      | 4.8.21.3               | 45   |
|                                                                    |                        |      |

#### Paragraph/Table/Figure Page <u>Title</u> 17 3.6.20.2 Output power (sinusoidal waveform) 45 4.8.21.2 17 3.6.27 Output suppression (gated oscillator) 4.8.28 48 17 3.6.20.1 Output voltage 4.8.21.1 45 17 3.6.20 Output voltage-power 45 4.8.21 3.6.19 17 Output waveform 45 4.8.20 6.3.4 62 Oven controlled crystal oscillator (OCXO) 62 6.3.6 Oven controlled/voltage controlled crystal oscillator (OCVCXO) 14 3.6.4.2 Oven input current-power (types 4 and 6) 35 4.8.5.2 14 3.6.2.2 Oven supply voltage (types 4 and 6) 35 4.8.3.2 13 3.5.9 Overall frequency accuracy 63 6.3.9 3.6.3 14 Overvoltage survivability 35 4.8.4 3.5.1 8 Package 9 3.5.4 Package and lead materials and finishes 11 3.5.4.4 Package body finish 3.5.7.4 13 Packaged integrated circuits 12 Packaged passive discrete parts 3.5.7.2 12 3.5.7.3 Packaged semiconductor devices 59 5. PACKAGING 61 5.4.2 Packaging inspection 6.1.2 61 Packaging requirements 60 5.2 Packing 3.6 13 Performance 32 4.7.2 Periodic inspection 64 6.3.27.2 Phase angle modulation (deterministic process) 64 6.3.27.1 Phase noise (random process) 64 6.3.27 Phase noise and phase angle modulation 16 3.6.16.3 Phase noise, acoustic 4.8.17.3 41 16 3.6.16.2 Phase noise, random vibration 41 4.8.17.2 3.6.16.1 16 Phase noise, steady-state 41 4.8.17.1 30.2.5.4.1.1 84 Physical dimension 21 3.6.51.2 Pins 59 4.8.52.2 8 3.4.2.1 Polymeric adhesives 8 3.4.2 Polymeric materials 4.3.6 24 Power supplies 27 4.5.2 Pre burn-in electrical testing 24 4.3.8 Precautions 30.1.1 80 Precedence 24 4.3.10 Precision of measurement 59 5.1 Preservation 59 5.1.1.3 Preservation application 13 3.5.8 Printed wiring 79 30. PROCEDURE 87 TABLE XIV Process control summary 30.3.1.6.1 88 Process machine/operator evaluation 87 30.3.1.3 Process machines 1 1.2.1.1 Product assurance level

| Title                                                        | Paragraph/Table/Figure | Page |
|--------------------------------------------------------------|------------------------|------|
| Product assurance program (PAP)                              | 4.1.2.1                | 23   |
| Product assurance program (1967                              | 3.2.1                  | 4    |
| Production and inspection lot                                | 4.7.1.1                | 28   |
| Production lot                                               | 4.7.1.1.1              | 28   |
| Protection from electrostatic discharge                      | 30.1.3                 | 80   |
| Quadrature phase detection method                            | FIGURE 5               | 71   |
| Qualification                                                | 3.3                    | 8    |
| edatification                                                | 6.4                    | 67   |
| Qualification inspection                                     | 4.6                    | 28   |
| wattheatton inspection                                       | TABLE IV               | 29   |
| Quality                                                      | 3.2                    | 4    |
| euatity                                                      | 4.1.2                  | 23   |
| QUALITY ASSURANCE PROVISIONS                                 | 4.                     | 23   |
| Quality conformance inspection                               | 4.7                    | 28   |
| Quality conformance inspections                              | 5.4.3                  | 61   |
| Quartz                                                       | 3.4.1                  | 8    |
| Quartz crystal                                               | 3.5.7.1                | 12   |
| Radiation hardness (operating)                               | 3.6.47                 | 21   |
|                                                              | 4.8.48                 | 57   |
| Radiation testing requirement                                | 30.2.2.3.4.2           | 81   |
| Re-entrant isolation (multi-output oscillators)              | 3.6.26                 | 17   |
| Re-entrant isotation (mattr output oscittato.)               | 4.8.27                 | 47   |
| Rectangular output waveform                                  | FIGURE 8               | 74   |
| Rejected lots                                                | 4.7.1.3.2.1            | 32   |
| REQUIREMENTS                                                 | 3.                     | 4    |
| Resistance to soldering heat                                 | 3.6.48                 | 21   |
|                                                              | 4.8.49                 | 58   |
| Resistance to solvents                                       | 3.6.53                 | 21   |
| RESISTANCE TO SOLVENUS                                       | 4.8.54                 | 59   |
| Responsibility for compliance                                | 4.1.1                  | 23   |
| Responsibility for inspection                                | 4.1                    | 23   |
| Retention of qualification                                   | 4.6.4                  | 28   |
| Retrace                                                      | 3.6.15                 | 16   |
| KELFACE                                                      | 4.8.16                 | 41   |
|                                                              | 6.3.26                 | 64   |
| Rework provisions                                            | 3.2.1.2.4              | 5    |
| Rise and fall time measurement levels                        | TABLE VIII             | 45   |
| Rise and fall times                                          | 3.6.21                 | 17   |
| Rise and fall times (square wave output waveform)            | 4.8.22                 | 45   |
| Rise time                                                    | 6.3.32                 | 65   |
|                                                              | 5.4.3.1.1              | 61   |
| Rough handling test<br>Rubidium-crystal oscillator (RbXO)    | 6.3.8                  | 62   |
|                                                              | 3.6.50                 | 21   |
| Salt atmosphere (corrosion)                                  | 4.8.51                 | 58   |
|                                                              | 30.1                   | 89   |
| Sample                                                       | 4.6.1                  | 28   |
|                                                              | 30.2.2.3.3.1           | 81   |
| Sample selection and reject criteria                         | 30.2.2.3.1.1           | 80   |
| Sample size                                                  | 30.2.2.3.2.1           | 81   |
|                                                              | 4.7.2.1.1              | 33   |
| Sampling plan                                                | 4.7.1.2.1              | 30   |
| Sampling procedure (subgroup 1).                             | 4.7.1.2.2              | 30   |
| Sampling procedure (subgroup 2)                              | 4.7.1.2.3              | 30   |
| Sampling procedure (subgroup 3)                              |                        | 1    |
| SCOPE                                                        | 1.<br>10. (Annualis A) | 79   |
|                                                              | 10. (Appendix A)       | 89   |
|                                                              | 10. (Appendix B)       |      |
| Screening                                                    | 4.5                    | 24   |
| Screening for oscillators of discrete component construction | TABLE II               | 25   |
| Screening for oscillators of hybrid construction             | TABLE III              | 26   |
|                                                              |                        |      |

.

r.

.

| Title                                                                  | Paragraph/Table/Figure | Page |
|------------------------------------------------------------------------|------------------------|------|
| Seal                                                                   | 3.6.1                  | 13   |
|                                                                        | 4.8.2                  | 33   |
| Seal rework                                                            | 3.2.1.2.4.6            | 7    |
| Sequence of testing                                                    | 30.1.2                 | 80   |
| Serial number                                                          | 3.7.1                  | 22   |
| Shock (specified pulse)                                                | 3.6.40                 | 20   |
|                                                                        | 4.8.41                 | 54   |
| Shock (specified pulse) (nonoperating)                                 | 3.6.40.1               | 20   |
|                                                                        | 4.8.41.1               | 55   |
| Shock (specified pulse) (operating)                                    | 3.6.40.2               | 20   |
|                                                                        | 4.8.41.2               | 55   |
| Short-term stability                                                   | 3.6.16                 | 16   |
|                                                                        | 4.8.17                 | 41   |
| Short-term stability Allan variance test procedure                     | FIGURE 7               | 73   |
| Single-type submission                                                 | 30.1.1                 | 89   |
| Solder dip (retinning) leads                                           | 3.5.4.3                | 11   |
| Solder pads                                                            | 3.6.51.3               | 21   |
|                                                                        | 4.8.52.3               | 59   |
| Solderability                                                          | 3.6.52                 | 21   |
|                                                                        | 30.2.5.4.2.4           | 86   |
|                                                                        | 4.8.53                 | 59   |
| Special test methods                                                   | 4.3.3                  | 23   |
| Specification sheets                                                   | 3.1                    | 4    |
| Specifications, standards, and handbooks                               | 2.1.1                  | 2    |
| Specified nominal frequency                                            | 1.2.1.4                | 2    |
| Spurious response                                                      | 3.6.24                 | 17   |
|                                                                        | 4.8.25                 | 47   |
|                                                                        | 6.3.36                 | 65   |
| Standard environmental conditions                                      | 4.3.5                  | 24   |
| Standard marking                                                       | 5.3.1                  | 60   |
| Standard test conditions                                               | 4.3.1                  | 23   |
| Startup time                                                           | 3.6.28                 | 17   |
|                                                                        | 4.8.29                 | 48   |
| Statement of scope                                                     | 1.1                    | 1    |
|                                                                        | 10.                    | 89   |
|                                                                        | 10.1                   | 79   |
| Statistical process control (SPC)                                      | 3.2.2                  | 7    |
|                                                                        | 4.1.2.2                | 23   |
| Storage temperature                                                    | 3.6.46                 | 21   |
|                                                                        | 4.8.47                 | 57   |
| Subject term (key word) listing                                        | 6.5                    | 67   |
| SUBMISSION                                                             | 30.                    | 89   |
| Substrate wire rebonding                                               | 3.2.1.2.4.3            | 6    |
| Supply voltage                                                         | 3.6.2                  | 14   |
|                                                                        | 4.8.3                  | 35   |
| Swept cultured quartz                                                  | 3.4.1.2                | 8    |
| Syntonization                                                          | 6.3.12                 | 63   |
| Syntonization energy (type 8)                                          | 3.6.4.3                | 14   |
|                                                                        | 4.8.5.3                | 35   |
| Temperature coefficient of resistance (TCR)                            | 30.2.5.4.3.1           | 86   |
| Temperature compensated crystal oscillator (TCXO)                      | 6.3.3                  | 62   |
| Temperature compensated/voltage controlled crystal oscillator (TCVCXO) | 6.3.5                  | 62   |
| Temperature range                                                      | 1.2.1.3                | 1    |
| Terminal strength (lead integrity)                                     | 3.6.51                 | 21   |
|                                                                        | 4.8.52                 | 59   |
| Terminals                                                              | 3.6.51.1               | 21   |
|                                                                        | 4.8.52.1               | 59   |
| Terms, definitions, methods, and symbols                               | 6.3.45                 | 67   |
| Test configuration for amplitude noise measurement                     | FIGURE 6               | 72   |
| Test configuration for determining isolation between output ports      | FIGURE 11              | 76   |
| ter settigenetion for motermiting formation methods safet barto        |                        |      |

~--

| <u>litle</u>                                                        | Paragraph/Table/Figure | Page |
|---------------------------------------------------------------------|------------------------|------|
| Test configuration for determining suppression of gated oscillators | FIGURE 12              | 76   |
| Test configuration for startup time measurement                     | FIGURE 13              | 77   |
| Test equipment and inspection facilities                            | 4.1.3                  | 23   |
| Test fixture                                                        | 4.3.2                  | 23   |
| Test routine                                                        | 4.6.2                  | 28   |
| Test samples                                                        | 30.3.1.2               | 87   |
| Thermal shock (nonoperating)                                        | 3.6.44                 | 20   |
| inermat shock (nonoperating)                                        | 4.8.45                 | 56   |
| Through-hole mounting packages (terminals or pins)                  | 4.8.49.1               | 58   |
| Total deviation, dc control                                         | 3.6.30.1               | 18   |
| local deviation, de control                                         | 4.8.31.1               | 48   |
| Total deviation, modulation                                         | 3.6.30.2               | 18   |
|                                                                     | 4.8.31.2               | 49   |
| Total dose                                                          | 3.6.47.1               | 21   |
|                                                                     | 4.8.48.1               | 57   |
| Total frequency deviation                                           | 6.3.37                 | 66   |
| Trim effect                                                         | 6.3.21                 | 64   |
| TTL and CMOS test loads                                             | FIGURE 9               | 74   |
| Types                                                               | 1.2.2                  | 2    |
| Typical oscillator retrace characteristic                           | FIGURE 4               | 70   |
| Typical oscillator thermal transient characteristic                 | FIGURE 3               | 70   |
| Typical oscillator warmup characteristic                            | FIGURE 2               | 69   |
| Uncased guartz resonators                                           | 3.5.7.1.2              | 12   |
| Unitized loads                                                      | 5.2.4                  | 60   |
| Units packs                                                         | 5.1.1.4                | 59   |
| VCX0 test configurations                                            | FIGURE 14              | 77   |
| Vibration                                                           | 3.6.38                 | 19   |
| VIDFACTOR                                                           | 4.8.39                 | 53   |
| Vibertien render (nononersting)                                     | 3.6.38.3               | 19   |
| Vibration, random (nonoperating)                                    | 4.8.39.3               | 54   |
| Vibration, random (operating)                                       | 3.6.38.4               | 19   |
| Albracton, faituon (operating)                                      | 4.8.39.4               | 54   |
| Vibration, sinusoidal (nonoperating)                                | 3.6.38.1               | 19   |
| Albiacton, shusotdat (nonoperating)                                 | 4.8.39.1               | 53   |
| Vibration, sinusoidal (operating)                                   | 3.6.38.2               | 19   |
| Albiation, shusoidat (operating)                                    | 4.8.39.2               | 53   |
| Visual and mechanical inspection                                    | 4.8.1                  | 33   |
| Visual inspection                                                   | 30.2.5.3.2             | 84   |
| Visual inspection                                                   | 30.2.5.4.1.2           | 84   |
| Visual inspection (subgroup 1)                                      | 30.2.3.3.1             | 83   |
| Visual inspection of die                                            | 30.2.2.2.2             | 80   |
| Visual inspection of passive elements lots                          | 30.2.3.2.2             | 83   |
|                                                                     | 6.3.2                  | 62   |
| Voltage controlled crystal oscillators (VCXO)                       | 3.5.5                  | 12   |
| Weight                                                              | 30.2.2.3.2.2           | 81   |
| Wire bond strength testing                                          | 30.2.5.4.3.2           | 86   |
| tion hand attempt testing (subgroup 2)                              | 30.2.3.3.3             | 83   |
| Wire bond strength testing (subgroup 2)                             | 30.3.1                 | 87   |
| Wire bonding                                                        | 30.3.1.6               | 87   |
|                                                                     | 3.8                    | 22   |
| Workmanship                                                         | 5.4.3.1.3              | 61   |
|                                                                     | 2.7.2.1.2              |      |